

High Voltage Engineering Techniques For Space Applications

Day 1 of 2

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Appreciation...

- *First and foremost, thanks to you all for making the effort to come. I sure hope we put on a fun and useful workshop for you!*
- *Special thanks to Dave Kusnierkiewicz and APL as our hosts for providing this fantastic facility. Thanks also to Sandy Rosenberger, Brad Carson, Bill Ligget, LaTosha Hill and John Sommerer of APL for their time and effort in making this event happen so smoothly.*
- *Personal thanks to Eric Young, Denney Keys and, in particular, Julian Ramirez of GSFC for their guidance and great support.*
- *And... thanks to our NESC friends, in particular Hope Venus and Ian Batchelder, for their support with the preparations for this meeting and their efforts to provide a quality webcast.*

2 + 2 = 4 Day Strategic Plan...

- *The complete seminar consists of two 2 day sessions with the first 2 days here at APL and the subsequent 2 days at JPL in October (tentatively on 10/22-23).*
- *The two sessions are stand-alone although complementary.*
 - *This session concentrates on theory, component application and design practices.*
 - *October session will consist of discussing 5-6 specific flight design cases covering a range of applications.*
 - *A detailed and useful report from this session will come out in the June-July timeframe.*

2 Day Timeline

| Start time | DAY 1 TOPIC |
|-------------|---|
| 0830 | INTRODUCTORY STUFF |
| 0845 | GROUNDWORK FOR DISCUSSIONS |
| 0900 | APPROACH TO HIGH RELIABLE HIGH VOLTAGE SYSTEM DESIGN- PART 1 |
| 0955 | BREAK |
| 1005 | APPROACH TO HIGH RELIABLE HIGH VOLTAGE SYSTEM DESIGN- PART 2 |
| 1120 | QUESTIONS/DIALOGUE |
| 1200 | LUNCH |
| 1300 | OVERVIEW OF HIGH VOLTAGE COMPONENTS AND TECHNOLOGIES |
| 1330 | HIGH VOLTAGE CAPACITOR TUTORIAL |
| 1350 | HIGH VOLTAGE RESISTOR TUTORIAL |
| 1405 | HIGH VOLTAGE CONNECTORS AND CABLES |
| 1440 | BREAK |
| 1450 | QUESTIONS/DIALOGUE |
| 1535 | HIGH VOLTAGE INSULATORS AND ELECTRIC FIELD CONTROL TECHNIQUES |
| 1635 | E-FIELD ANALYSIS METHODS AND SOFTWARE |
| 1700 | QUESTIONS/DIALOGUE |
| 1730 | RECEPTION |
| 1900 | ADJOURN |

| Start time | DAY 2 TOPIC |
|-------------|---|
| 0830 | INTRODUCTORY STUFF |
| 0840 | LEIDECKER ON WIEBULL METHODS |
| 0900 | HENNING LEIDECKER'S GALLERY OF FAILURES |
| 0915 | SYSTEM DESIGN CHOICES- PART 1 - CLEANING AND CONTAMINATION - VENTING CONSIDERATIONS - CHOICE OF INSULATING MEDIA - PREFERRED ENGINEERING PLASTICS - OTHER SOLID INSULATING MATERIALS - ENCAPSULATION METHODS |
| 1015 | BREAK |
| 1025 | SYSTEM DESIGN CHOICES- PART 2 - SHIELDING APPROACHES - INSULATING COATINGS - GROUNDING APPROACHES - PC BOARD DESIGN CONSIDERATIONS - HIGH VOLTAGE SOLDER JOINTS - PACKAGING AND CONSTRUCTION |
| 1135 | ELEMENTAL DESIGN APPROACHES- PART 1 - OSCILLATOR DESIGN |
| 1200 | LUNCH |
| 1240 | ELEMENTAL DESIGN APPROACHES- PART 2 - MAGNETICS DESIGN AND MANUFACTURE - HIGH VOLTAGE MULTIPLIER DESIGN - MONITOR AND FEEDBACK APPROACHES - REGULATORS AND MODULATORS - OUTPUT FILTER DESIGN APPROACHES - OUTPUT TERMINATION APPROACHES - HIGH VOLTAGE CABLES - MATCHING UP TO THE "USER" END - "SHRINKING" A DESIGN |
| 1515 | BREAK- EARLY ADJOURN POINT |
| 1530 | QUESTIONS/DIALOGUE |
| 1600 | MEASUREMENT METHODS |
| 1630 | OTHER IMPORTANT STUFF - RADIATION EFFECTS - GSE AND SIMULATOR DESIGN - SAFETY IS ALWAYS FIRST - SUMMARY THOUGHTS - PLANNING FOR OCTOBER |
| 1730 | QUESTIONS/DIALOGUE |
| 1800 | ADJOURN |

Thanks to Special Visitors...

- *We have several vendors who specialize in the high voltage business who have come to participate.*
 - *CalRamic Capacitors*
 - *Ohmcraft Resistors (Micropen)*
 - *Teledyne-Reynolds*
 - *Micropac*
 - *RJR*
- *Many of you also know Eric Hertzberg and Dr. Henning Leidecker. Eric will be speaking later today and Henning will speak tomorrow morning.*

Dedications...

- *Scientists and Engineers in aerospace are the product of both what they learn and who has taught them. My own personal and professional thanks goes to:*
 - *John Maurer (Michigan)*
 - *Art Ruitberg (GSFC)*
 - *Helmut Rosenbauer (Max Planck Institute)*
 - *Eric Hertzberg (Lockheed)*
 - *Tom Sanders (Lockheed)*
 - *Doug Simpson (Lockheed)*
 - *Henning Leidecker (GSFC)*
 - *Bill Dunbar (Boeing)*

A Surprising Space Fact...

***Fact:** All of the equipment launched in the 55 year history of the space program equates to less than 1 day of worldwide auto production.*

***Conclusion:** At a fundamental level, statistical process control principles associated with mass production do not apply to the space business.*

***Lesson:** The space workforce is fundamentally a craft-based “guild” where key knowledge is passed from generation to generation.*

Our Starting Point...

- *4 years ago I committed myself to giving back 20% of my work time to the country by doing teaching and mentoring on engineering.*
- *It is my way of “**paying back by paying forward**” for the benefit of the next generation of engineers in our profession.*
- *When Eric Young approached me a year ago about doing this high voltage engineering workshop I thought it would be a fun and useful way of making good on a part of my commitment.*
- *So here we are... There are many rules and rule books plus other excellent informational resources related to the development of high voltage systems. However, very few provide a practical **connection between the “how to” and the “here’s why”**.*
- *My personal hope during this workshop is to relate 35 years of mistakes and practical lessons learned in developing more than 50 different flight high voltage system designs.*

Becoming a High Voltage “Expert”...

- *The space hardware development business is best described as a learning process consisting of uncountable hours of slogging occasionally interrupted by a few exciting minutes of true insight.*
- *The “**pay back**” component of our time together is to share these key insights so that you will come away with a more complete understanding of what it takes to engineer reliable high voltage systems.*
- *The “**pay forward**” component is the hope that this effort can snag a few of young energetic engineers who are willing to commit themselves to the process of becoming the next generation of experts.*

High Voltage Resources...

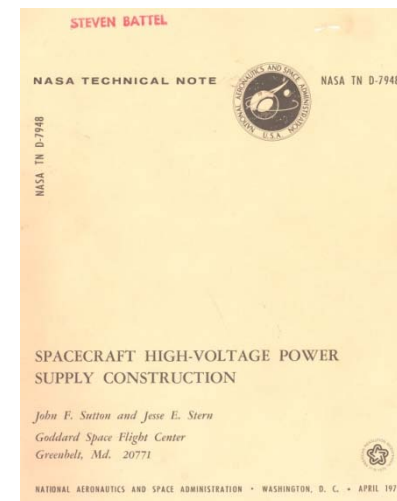
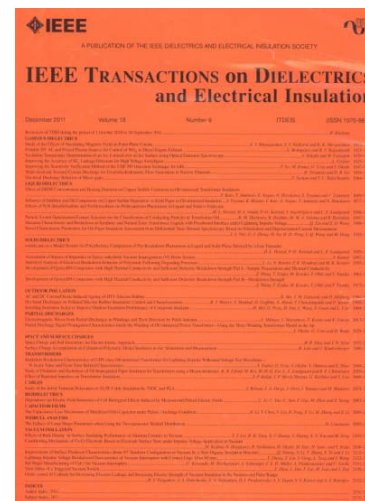
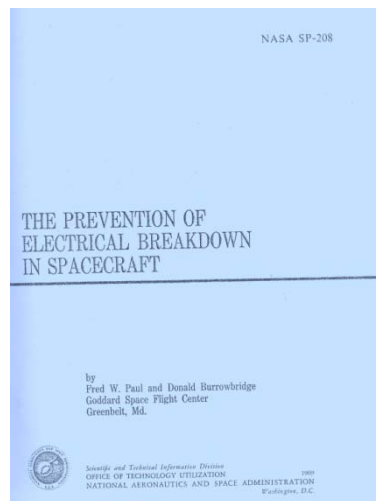
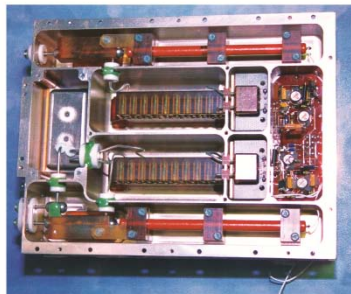


NASA/TP-2006-214133



High Voltage Power Supply Design Guide for Space

Renato S. Bever, Arthur P. Bulberg, Carl W. Kallenberg, and Sandra M. Irish



But Wait... There's More!

- Electronic Packaging and Interconnection Handbook, Charles A. Harper, McGraw-Hill, 2000
- J.C. Martin on Pulsed Power, J.C. Martin, Plenum Press, 1996
- High Voltage and Electrical Insulation Engineering, Ravindra Arora & Wolfgang Mosch, John Wiley and Sons, 2011
- Magnetic Components: Designs and Applications, Steve Smith, Van Nostrand Reinhold Company, 1985
- Handbook of Transformer Design and Applications, William M. Flanagan, McGraw-Hill, 1993
- Electroceramics, A. J. Moulson & J. M. Herbert, Chapman and Hall, 1993
- Passive Electronic Component Handbook, Charles A. Harper, McGraw-Hill, 1997
- High Voltage Engineering Fundamentals, E. Kuffel & W.S. Zaengal & J. Kuffel, Newnes, 2001
- High Voltage Vacuum Insulation: Basic Concepts and Technological Practice, Rod Latham, Academic Press, 1995
- Partial Discharge Detection in High-Voltage Equipment, F.H. Kreuger, Anchor Press, 1989

... and More!

- *Handbook of Electrical and Electronic Insulating Materials*, W. Tillar Shugg, IEEE Press, 1995
- *Microwave Tubes*, A. S. Gilmour, Jr., Artech House, 1986
- *Dielectric Phenomena in High Voltage Engineering*, F. W. Peek, Jr., Rough Draft Printing, 1915 (2008)
- *Corona Onset Voltage of Insulated and Bare Electrodes in Rarified Air and Other Gases*, W. G. Dunbar, 1966
- *Design Guide: Designing and Building High Voltage Power Supplies*, W. G. Dunbar, 1988, Volumes I-II
- *Space Transportation System Orbiter Upgrades Program: Electrical Auxilary Power Unit (EAPU) Corona Design Guideline*, 2000
- *High Voltage Design Criteria*, MSFC-STD-531, 1978

There are also JPL and NASA Design Rules and documents and handbooks that I have not cited but are also useful and consistent with what is presented.

You Learn From Your Mistakes...

The Early Years (7000 pages)



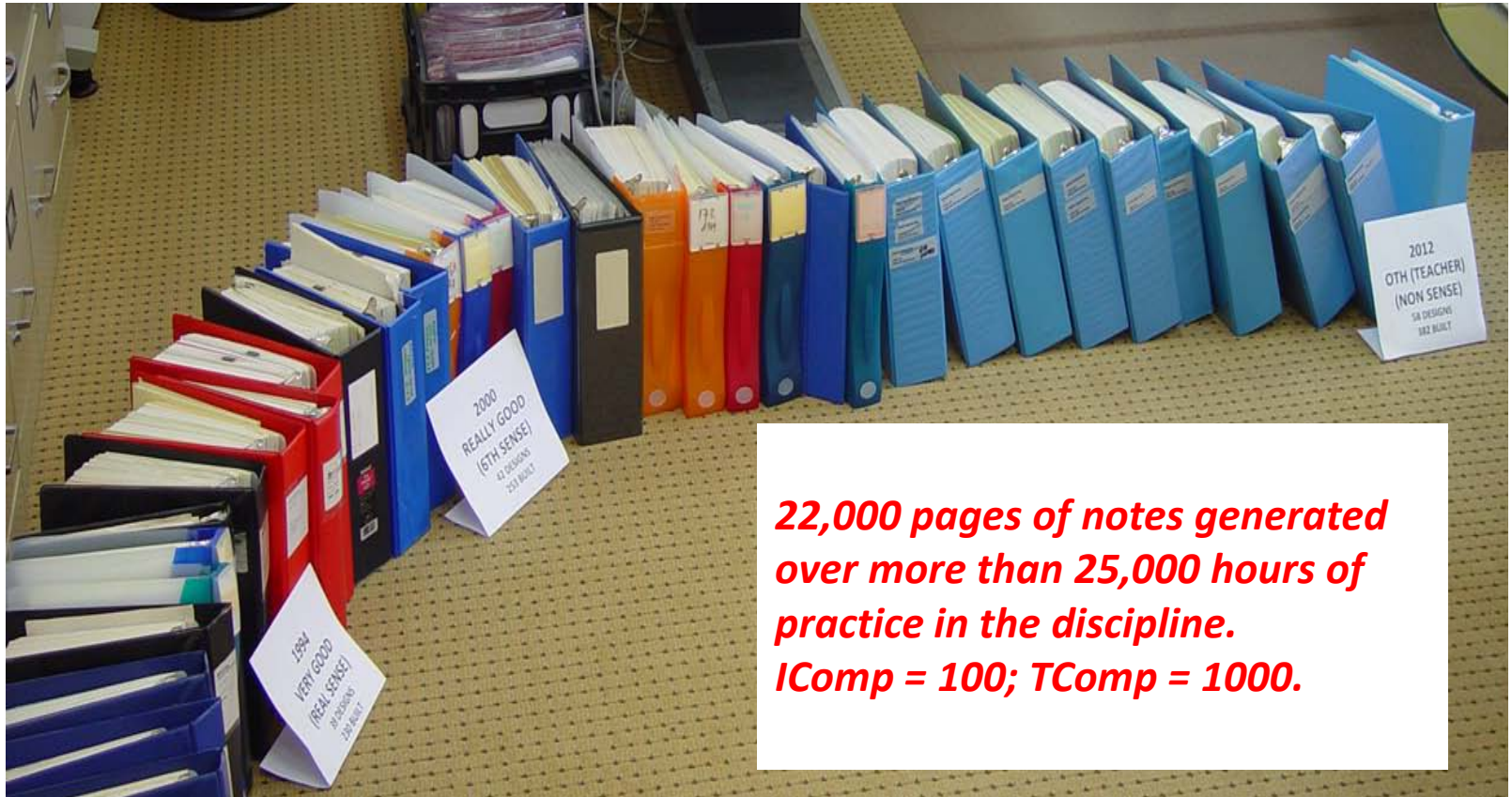
You Are What You Learn...

The Middle Years (8000 pages)



You Become What You Remember...

End of the Line and OTH (7000 pages)



***22,000 pages of notes generated
over more than 25,000 hours of
practice in the discipline.
IComp = 100; TComp = 1000.***

Core Message...

- *Reality is more complex than theory! **It takes time, patience and perseverance** (and good notes) to become an expert at translating the right set of key physics and engineering principles into high voltage “art”.*
- *Practitioners must have a broad understanding of physics, engineering principles, materials and component technologies if reliable optimal designs are to be achieved.*
- *A long-term institutional commitment is required if an expert engineering team is to be developed and then sustained.*
- *An engineering team should develop 1-2 designs per year over if its expertise is expected to grow and remain current.*

Achieving “Goodness” in a Design...

- *Become a master the “elements” we will be discussing.*
- *Constantly learn and improve by constantly doing.*
- *Value mentoring as a two-way mode of engineering interaction with the goal of achieving creative ideas, simplified designs and optimized implementations.*
- *At a personal level, develop the **ability to critically self-assess as part of the design process** (inside-out pressure).*
- *At an institutional level develop **the ability to be self-critical as part of the review process** (outside-in pressure).*

The Approach...

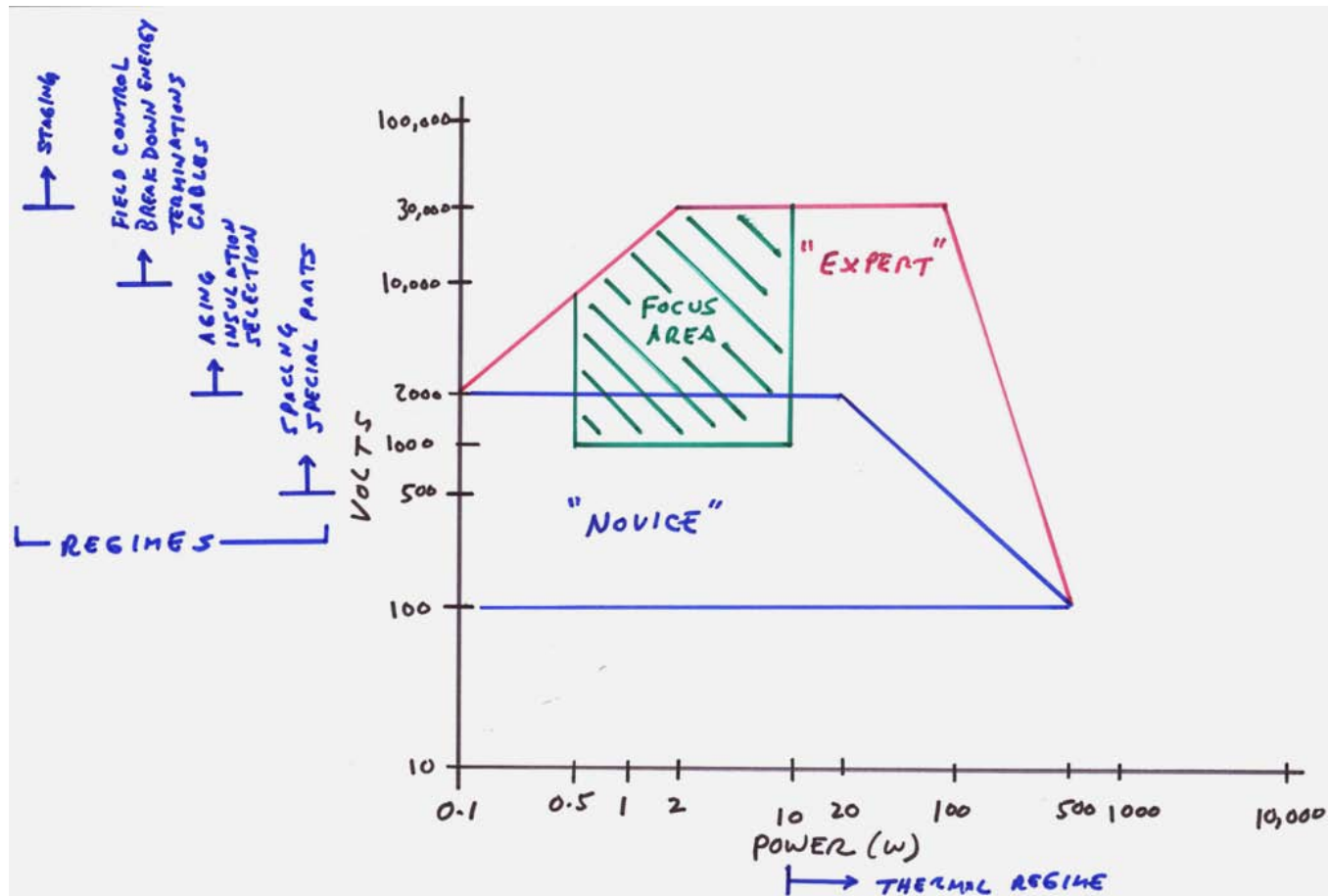
The views expressed here are entirely my own and do not reflect the views of NASA management or any rational person!

- *The design and implementation approaches presented here are based on a personal perspective and personal approach developed over 35 years of practice in the field.*
- *There are many other equally good approaches so look at this recipe as one means of achieving a “connected” and reliable design.*
- *The key to any successful approach is to ensure that it is derived from correct physical principles that have been systematically investigated and understood.*
- *Hopefully by presenting the details of my approach you can then apply some of the ideas to your own designs.*

Types of High Voltage Systems...

- *Although the design considerations are similar or even identical over a wide range of high voltage system applications, we will be concentrating on smaller high voltage systems in the 0.5 to 10 watt range used in single output and multiple output instrumentation applications.*
 - ***Detector Bias Systems (Silicon, CEM, MCP etc.)***
 - ***Mass Spectroscopy/Time of Flight***
 - ***Spacecraft Charge Control***
 - ***Propulsion and Special Instrumentation Applications***

The High Voltage "Scale"...



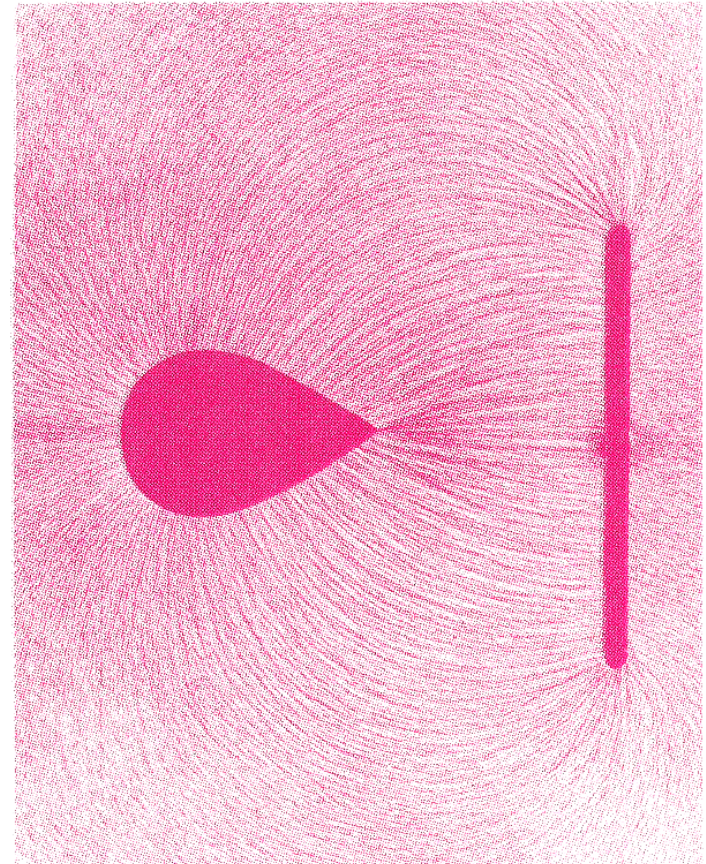
The Equation...

Maxwell's Electric Field Equation is Gauss's Law for the Electric Field described in differential form.

$$\nabla \cdot \mathbf{E} = \frac{\rho}{\epsilon_0}$$

In the electrostatic case the Electric Field can be expressed in a more useful form as the gradient of the electrostatic potential.

$$\mathbf{E} = -\nabla V$$



The Physics of High Voltage Breakdown...

- *Eric Hertzberg will talk more on the details later but it is important to geometrically manage the relationship between V , E , and relative permittivity with an insulating medium.*
- *The simple view is that the reliable generation of high voltage is dependent on limiting the resulting E-Field stress as expressed by the localized voltage gradient created in the isolating dielectric medium.*
- *Failure to properly manage the E-Field stress via geometry, spacing, material selection and control of defects can result in immediate voltage breakdown or time dependent dielectric failures depending on many primary and secondary factors.*
- *High voltage systems for space often have an additional dielectric issue associated with the need for both ground operations vs. space operations that must also be managed to assure that ground operations do not reduce in-space reliability.*

Some Definitions... 1

- **Arc-** *A self-sustaining electrical discharge.*
- **Breakdown-** *The temporary or permanent loss of normal insulating properties by a dielectric material.*
- **Corona-** *Luminous usually localized discharge with a low current flow due to a deionization release of energy. Typically a “point” breakdown with a negative electrode and a “film” breakdown with a positive electrode.*
- **Discharge-** *Any conducting mechanism between two electrodes separated by a dielectric.*
- **Flashover-** *A discharge around or over the surface of a liquid or solid dielectric.*
- **Field Emission-** *Current emitted from an electrode (typically a point).*

Some Definitions... 2

- ***Multipactor-*** Breakdown in hard vacuum at certain RF frequencies and in certain geometries due to secondary emission of electrons.
- ***Partial Discharge-*** Localized discharge due to transient gaseous ionization within an insulating system typically due to gaps or voids in combination with a dielectric transition.
- ***Surface Breakdown-*** Development of conducting channels between two electrodes on a conducting surface.
- ***Surface Leakage-*** Passage of current over the boundary surface of an insulator.
- ***Tracking-*** Development of conducting channels primarily on a dielectric surface where the surface is damaged by the process.
- ***Treeing-*** A cumulative failure where hollow channels branch slowing through a dielectric material resulting in permanent failure.

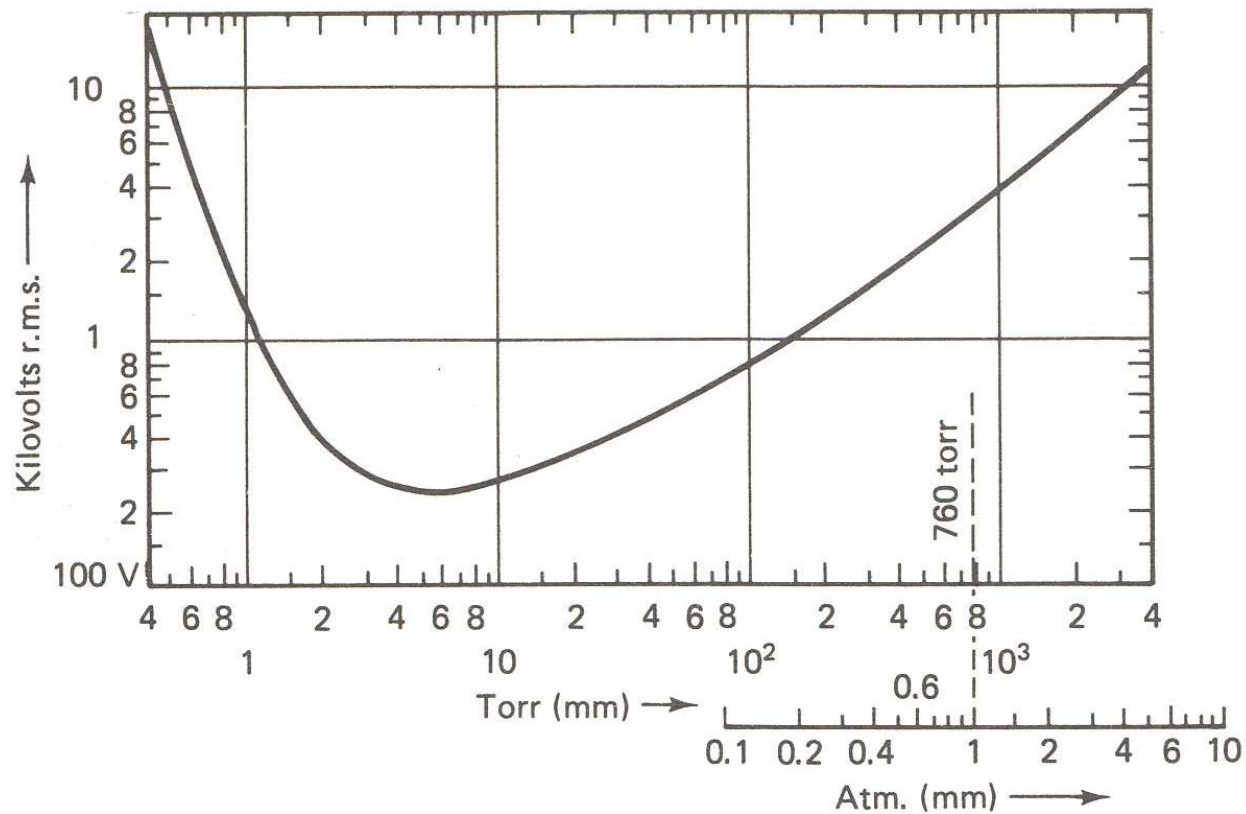
Intrinsic Dielectric Strength Limits...

- *The breakdown of Gasses at **STP** is dependent on type.*
 - *Air : ~3 kV/mm (75 V/mil)*
 - *He : ~0.37 kV/mm (9.3 V/mil)*
 - *SF₆ : ~9 kV/mm (222 V/mil)*
- *High Vacuum breakdown is surface and configuration dependent but is in the range of 20 to 40 kV/mm (500 to 1000 V/mil)*
- *Ignoring surface effects, Liquids and Solids bulk properties are generally similar in the same range of 15 to 20 kV/mm (375 V/mil to 500 V/mil).*

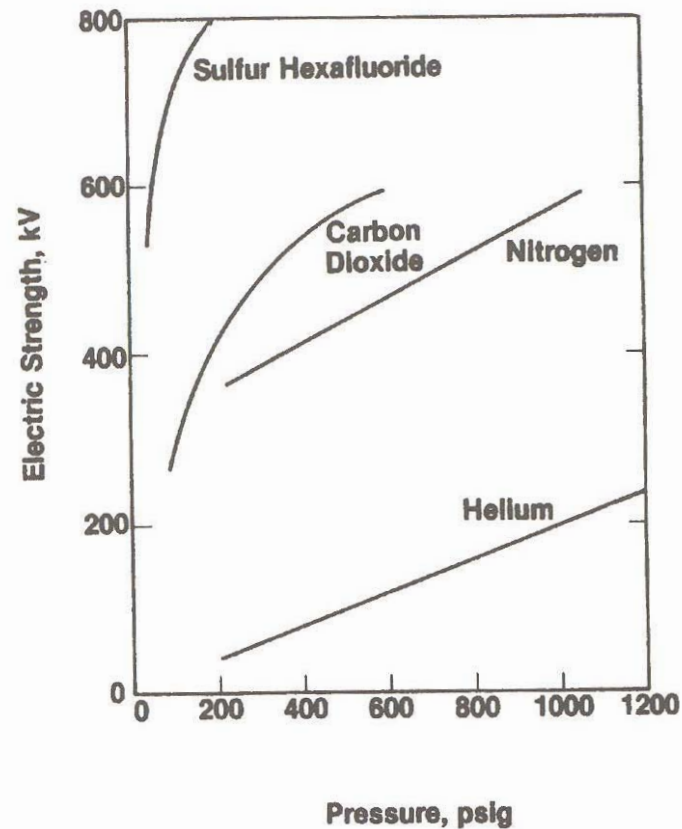
Operational Dielectric Strength Limits...

- *Maximum recommended DC design voltages:*
 - Vacuum gaps: 3 kV/mm in general; lower preferred
 - Along insulator surfaces: 1 kV/mm
 - Within bulk insulator material: 4 kV/mm (*depends on life requirement; thermal runaway also ignored*)
 - In atmosphere at **STP**: 1.5 to 2 kV/mm
- *Stay tuned... There is much more to this story!*

Paschen Curve for Air...

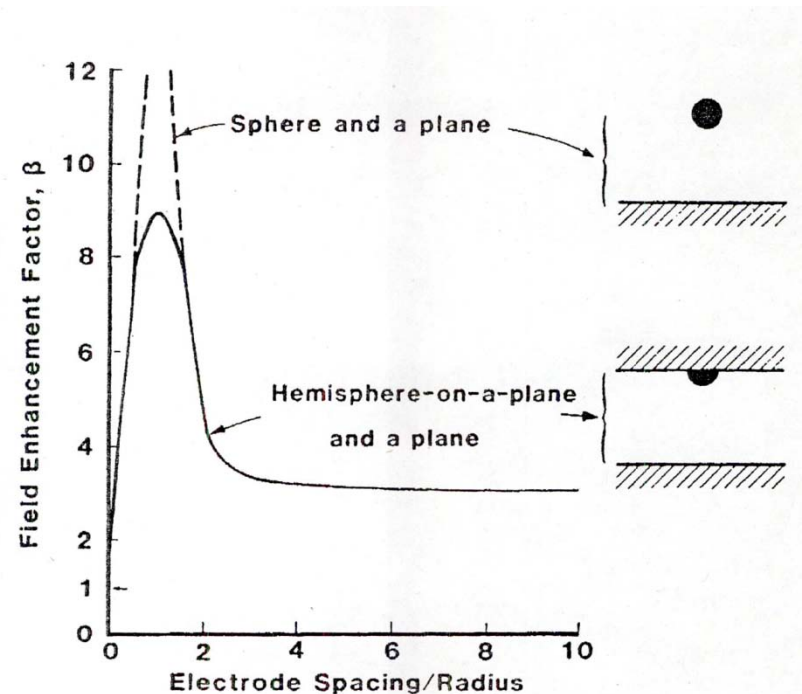


Affect of Pressure...

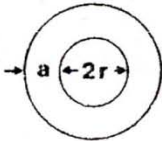
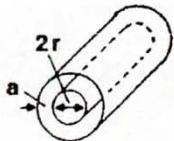
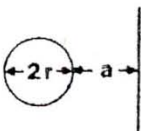
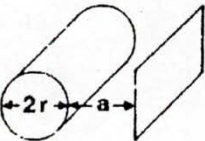
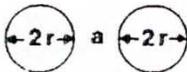
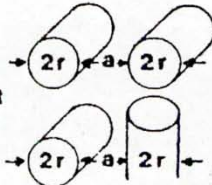


Geometry and the E-Field...

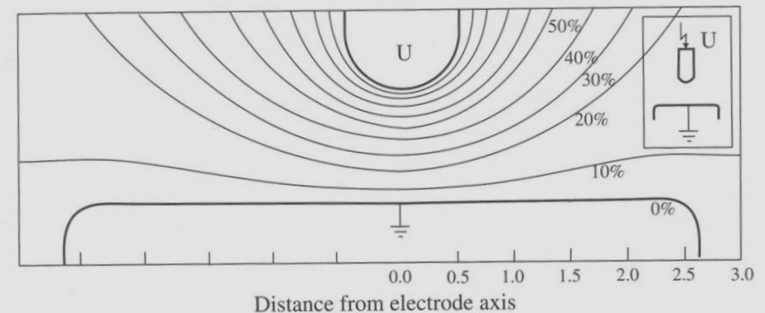
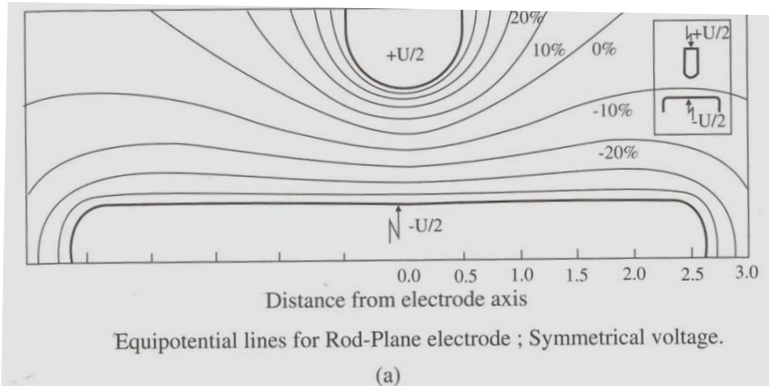
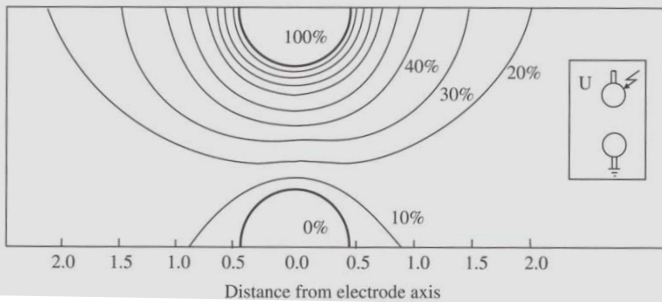
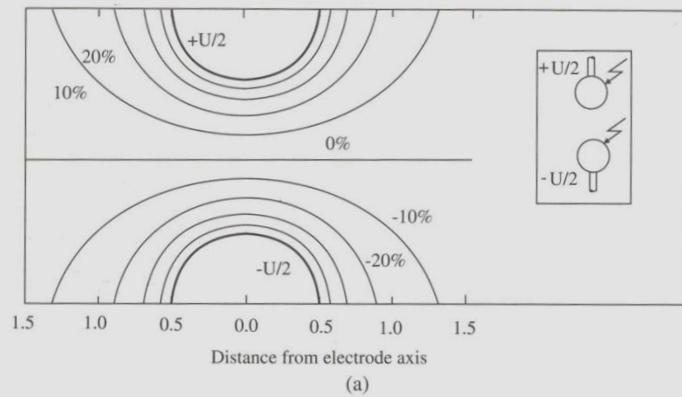
- Simple factors do not tell the entire story of dielectric breakdown since geometry of the conductors play a strong role.
- In carefully designed systems B_{eta} is generally 3 or lower.



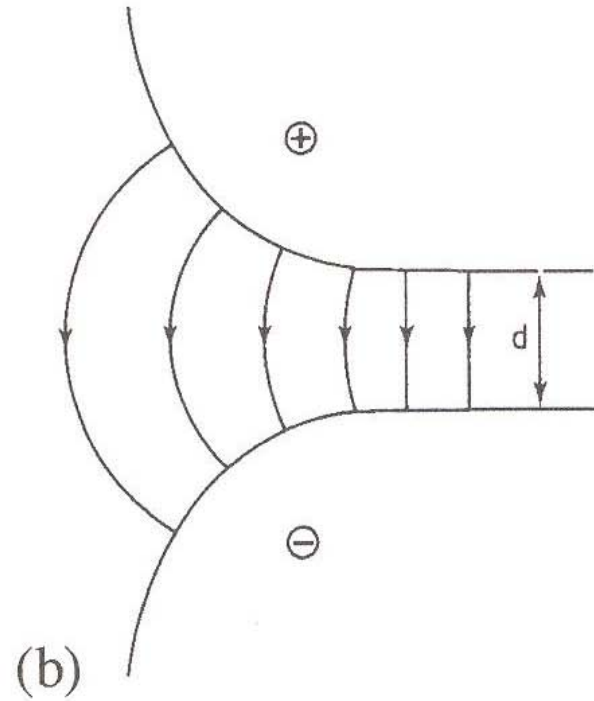
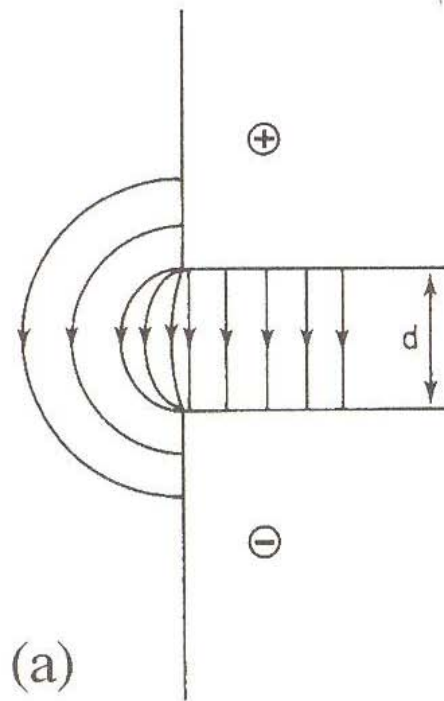
Simple Examples of E-Field Enhancement...

| Configuration | β | Configuration | β |
|---|-------------------------|--|--|
| CONCENTRIC SPHERES  | $1 + \frac{a}{r}$ | COAXIAL CYLINDERS  | $\frac{\frac{a}{r}}{\ln(1 + \frac{a}{r})}$ |
| SPHERE AND PLANE  | $0.9(1 + \frac{a}{r})$ | CYLINDER AND PLANE  | $\frac{0.9 \frac{a}{r}}{\ln(1 + \frac{a}{r})}$ |
| TWO SPHERES  | $0.9(1 + \frac{a}{2r})$ | PARALLEL OR PERPENDICULAR CYLINDERS  | $\frac{0.9 \frac{a}{2r}}{\ln(1 + \frac{a}{2r})}$ |

Effect of Asymmetrical Potential...



Effect of Poor Field Control...



AC and DC Gradients Act Different...

- **AC (top) and DC (bottom) gradient stress manifest themselves through capacitive and resistive ratios.**
- **DC gradients also have a time constant that must be managed especially in bi-polarity cases where space charge can amplify the field intensity.**
- **Matching up materials in an insulating stackup is important for both mechanical and electrical reasons.**

$$G_x = \frac{E}{\epsilon_x(T_1/\epsilon_1 + T_2/\epsilon_2 + \dots + T_n/\epsilon_n)}$$

where

E = Total voltage across all insulation

G_x = Gradient (electric stress) in V/mil

T = Thickness in mils

ϵ = Dielectric constant

Subscript $x = 1, 2, \dots, n$

$$G_x = \frac{\rho_x E}{(T_1\rho_1 + T_2\rho_2 + \dots + T_n\rho_n)}$$

where

E = Total voltage across all insulation

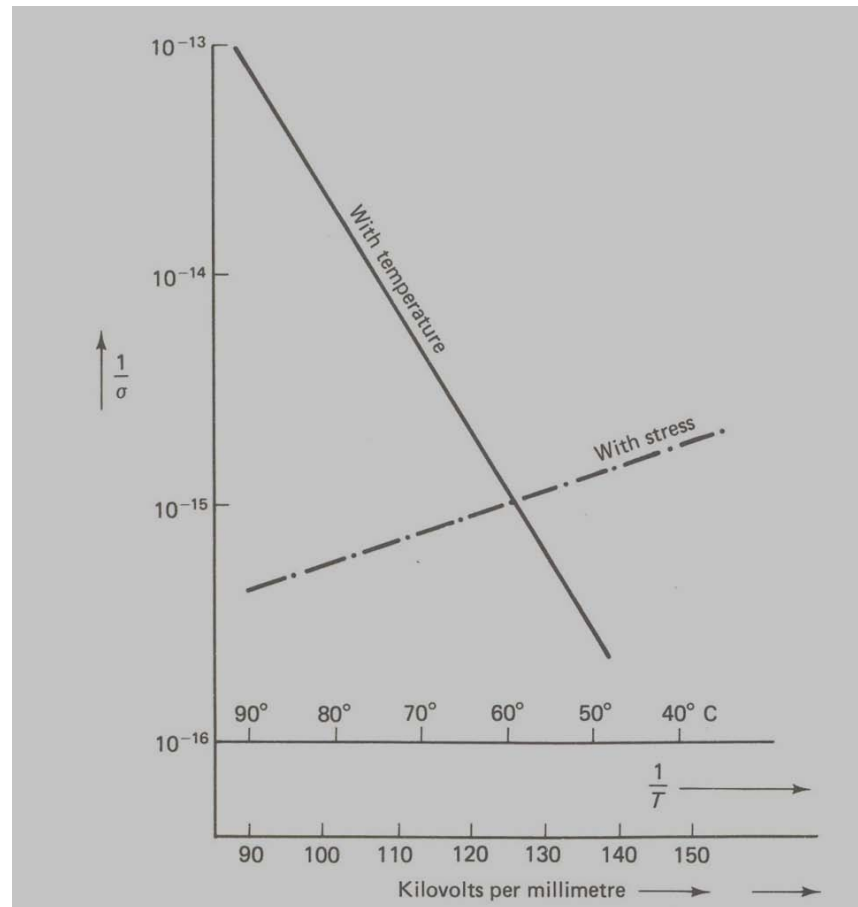
G_x = Gradient (electric stress) in V/mil

T = Insulation thickness in mils

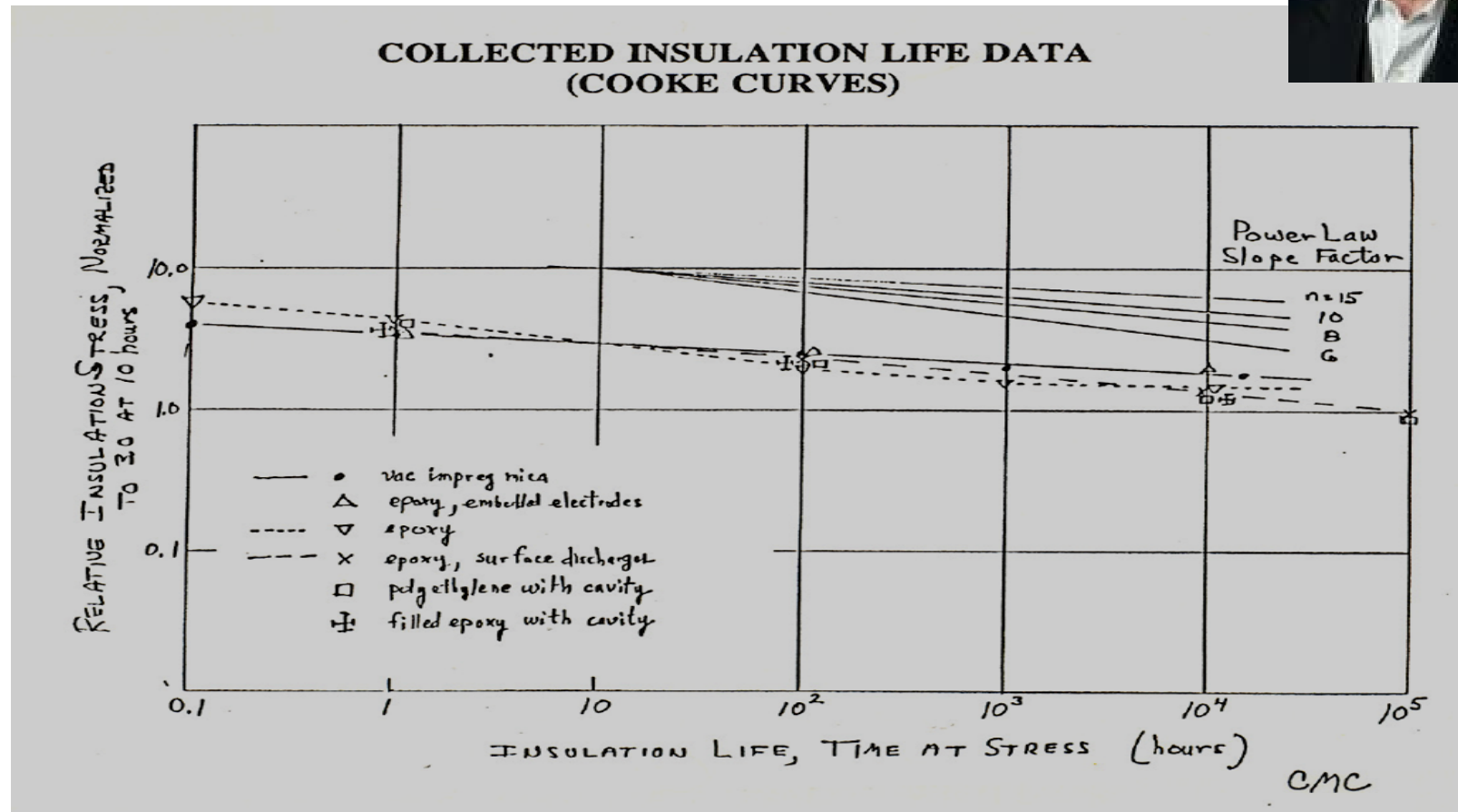
ρ = Volume resistivity

Subscript $x = 1, 2, \dots, n$

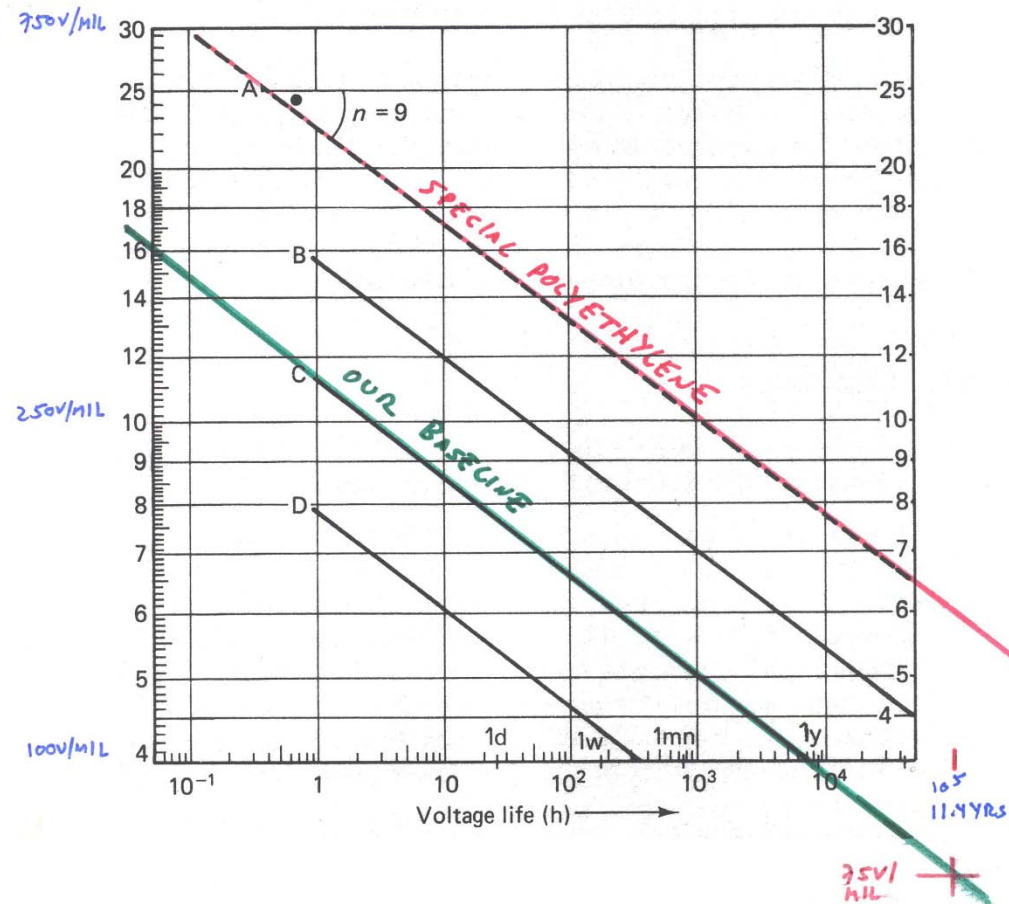
Effect of Temperature and Voltage on Insulator Volume Resistivity...



The “Eureka” Moment (1986)...



9th Power Aging Curve...



Managing the Race to Failure... 1

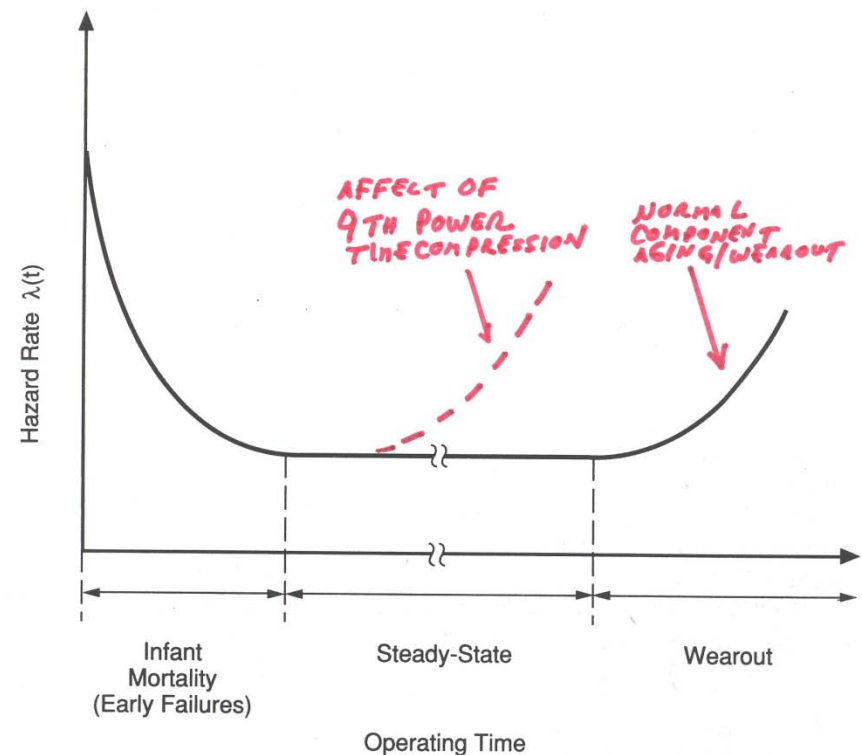
- *Many factors affect the performance and reliability of insulating media used in high voltage systems with the most important being E-Field stress, temperature, porosity and contaminants.*
- *Ceramics and Polymers are chemically different as well as different in their response to an electric field when used as a bulk dielectric.*
- *Plastic and epoxy polymer formulations are the most common building blocks for high voltage insulation systems.*
- *Required operating lifetime must be accounted for when derating dielectric materials.*

Managing the Race to Failure... 2

- The “Infinite life” stress factors for polymers are in the range of **20 to 75 V/mil** with **50 V/mil generally considered to be a reasonable design value for a 10 year life.**
 - Represents range of 10:1 and 7:1 ratio against dielectric strength limits.
- Voltage acceleration Factors vary but are generally considered to range between the 8th and 10th power with a **9th power acceleration** considered a good value for most plastic dielectrics.
- **Defects can result in premature aging and/or failure** due to corona and/or partial discharges and must be accounted for in the design and processing.
- A dimensionally minimized design must account for the geometric amplification of E-Field stress as component spacing is reduced as well as the amplification effect of potential defects introduced by either design or process.

Rethinking the “Bathtub Curve”...

- *Standard NASA reliability assumptions are predicated on the elimination of infant mortality through parts screening combined with process control and burn-in at the unit level.*
- *Unit wearout is considered to be far in the future resulting in a long steady-state lifetime.*
- ***E-Field stress-induced aging can result in a significant shortening of the steady-state life unless carefully managed in every susceptible element of a design.***

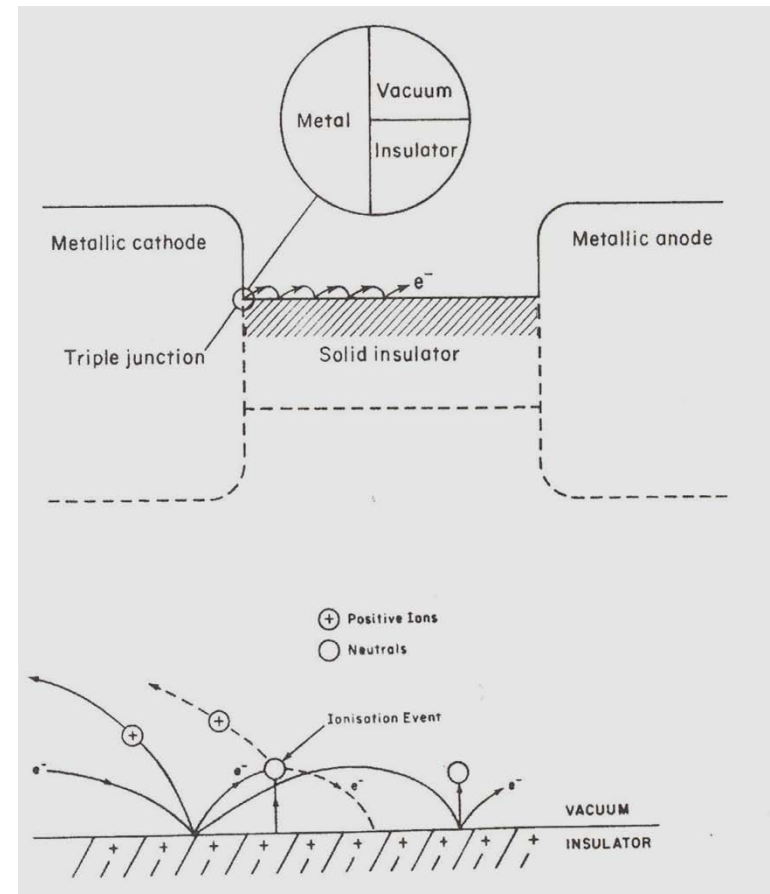


Formulating an Insulation Strategy...

- *System reliability will ultimately be set by the insulation strategy chosen for each system element in combination with the **true E-field stress ratio** and the quality of the processes used in implementation.*
- *Insulation strategy **must be achievable** as well as matched to operating and test regimes, lifetime requirement, field control approach, volume and mass constraints, thermal requirements, material restrictions and the **skill of implementer**.*
- *Insulation strategy may (and probably should) vary by system element with the intent of optimizing reliability of each element within its unique requirements and process constraints.*

Managing Flashover, Arcing and Corona...

- *Designs that appear derated often have a triple-junction creating a high field point as a source of electrons to initiate a cascade that results in flashover, arcing or corona.*
- *Eric Hertzberg will address design approaches for minimizing these effects within an insulation system.*

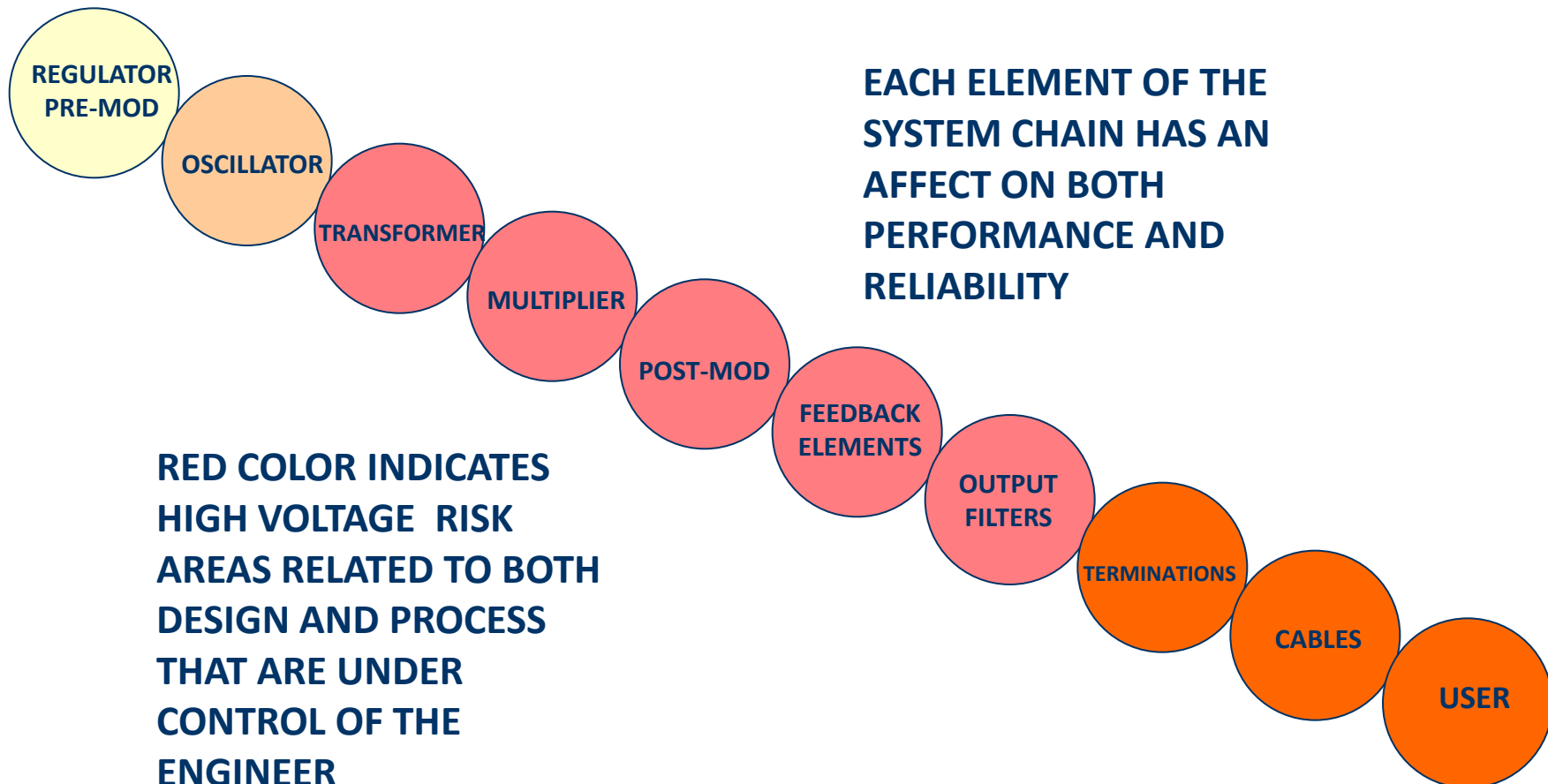


Progressive Design and Test Margins...

- *Testing can simply be pushing your design closer to failure such that survival does not necessarily mean the design is either qualified or reliable.*
- *Progressive design and test factors are essential to achieving a reliable and optimized design.*
 - *2X Margin for design*
 - **1.5X Margin for Accelerated Qual ($1.5^9 = 38$; 1 Yr = 10 days)*
 - *1.25X Flight Unit Over-Test and Operational Margin*
 - *1.0X Max Flight Operation*
- *1.25X flight operational margin can be traded for performance against life in some life extension scenarios.*

**Acceleration factors above ~1.5 may not yield trusted results due to secondary factors.*

The “Elemental” Picture...



Achieving a “Connected” Design...

- *An **end-to-end “holistic” approach** is essential to the successful design, development, test and deployment of a reliable high voltage system.*
- ***Key requirements should be dissected and fully understood** within the performance and reliability trade space for the particular system.*
- *Each “element” of the design chain should be matched to the specific application and derived from **proven components and processes**.*
- ***Push back on requirements to achieve simplicity** through the elimination of all non-essential elements.*

Connecting the Elements...

- *A reliable high voltage system design is the product of a systematic design approach where each system element is operated within its proven performance and reliability limits.*
- *Mixing and matching the system elements must be based on fundamental confidence derived from a combination of testing and experience.*
- *Extrapolations should be fully based on testing confirmed by appropriate analyses.*

Developing Confidence and Trust in Your Fundamental Processes...

- *“Heritage” is about applying trusted engineering techniques and process methods within an understood and appropriate operating regime.*
- *The fundamental elements and processes we will be discussing become your toolbox.*
- *Continuity in personnel, processes, components and test methods are the necessary basis of confidence and trust.*
- *End-to-end ownership of the design and participation in all key processes is essential for successful implementation.*
- *Total involvement also yields the comprehensive knowledge required to achieve future improvements.*

Why are we having problems? ₁

- *Project and engineering organizations tend to encourage their experts to focus within a narrow discipline area rather than develop experience cutting across many disciplines.*
- *Organizational funding and training strategies are typically not consistent with the long-term commitment necessary to develop and maintain expert practitioners and the needed support facilities.*
- *Simulation-based design approaches together with reliance on marginally applicable risk-based (rather than physics-based) rule sets have resulted in engineers **at both the design level and review level** having relatively little practical experience dealing with the unique design and developmental challenges that occur in high voltage systems.*

Why are we having problems? 2

- *DOORS, as a system engineering tool, works best as a “**one-way**” top-down pathway for the development of requirements. Unless carefully done, it will not fully capture the unique cross-cutting design and reliability challenges that occur in high voltage designs. High voltage designs should be implemented in a “**two-way**” or “**up-down**” approach that achieves robustness through push-back and simplification.*
- *The above 4 drivers, combine to create requirements and associated designs that tend to over-reach the skill level of the designer. The potential consequence is the introduction of time-dependent failure modes that surface late in the development process, in the test process, or on-orbit.*

The TRL Dilemma...

- *TRL 6 readiness means nothing in a low production environment for high voltage systems except that the unit design at the beginning of its life built using standard processes can successfully survive the relevant flight environments.*
- *The heritage and development readiness of a high voltage system is rooted in the design, engineering and process robustness of the individual elements rather than in the high voltage system itself.*
- *High voltage systems are most reliable and also use the least system resources when they are uniquely engineered to be as simple and robust as practical for the specific application.*
- *Designs resulting in excess capability or that are excessively complicated are often less reliable (especially at the system level) and can use up system resources better spent in other areas.*

Seeking the Optimum Middle...

- *Requirements if worked in concert with a selected design approach can be enforced in ways that make the design implementation simpler or more complex (or both!).*
- *The designer must always seek the “optimum middle” by focusing on meeting key requirements while pushing back on everything else.*
- *Choose trusted design approaches and implementation methods and employ appropriate design and test factors.*
- *Design synthesis should match each element of the design to the requirements such that resources are applied in a way that balances system reliability between the elements.*
- *Focus on robust simple designs for all key hardware elements and across all key processes (parts, manufacture, testing, ops).*

Frequent Challenges...

- *Slow leaks in hollow resistors or other components.*
- *Use of film resistors in arc sensitive applications.*
- *Voids due to design or bonding delamination issues.*
- *Unvented volumes.*
- *Improper venting.*
- *Floating conductors and particles.*
- *Reliance on insulating properties of solder mask.*
- *Inadequate trace spacing.*
- *Unaccounted for field compression due to thermal gradients or space charge.*
- *PC board voids due to improper design or manufacturing problems.*
- *Ink and markings in potted areas.*
- *Microphonic susceptibility.*
- *Device heating in encapsulated areas.*
- *Retroactive improvements.*

Design Checklist... 1

- *Is the design consistent with safe operation in both the operational and test regimes?*
- *What is the lifetime requirement including test time at full voltage?*
- *Are key design elements as simple as practical?*
- *Do key design elements use proven approaches and processes?*
- *Do the design and processes control voids and gaps?*
- *Have the critical spacing's been identified and analyzed to assure that all gradients are consistent with the unit lifetime requirement?*
- *Do high voltage joints use properly sized solder balls or other methods or controlling the local field gradient?*
- *Does the box venting design sized to be consistent with required pumpdown time constant?*

Design Checklist... 2

- *Is sleeving used or can wire insulation debond in a way that creates an insulation gap or void?*
- *Do the high voltage resistors or other components with applied high voltage have a hollow core that can break down?*
- *Are the encapsulated areas designed to allow for priming of bare metal and/or processing of the bare surfaces?*
- *Does the design incorporate a V/10 function or some other means of achieving safe test of both the HVPS and downstream circuitry?*
- *Are the design and test setups consistent with appropriate safety standards?*
- *Does the design employ effective arc suppression and protection that are consistent with the grounding approach.*
- *Is headroom and control range consistent with test margins?*

Progressive Development Process...

- A high voltage system approach intended to achieve a high level of performance and reliability requires a progressive series of design and implementation steps to be fully successful.
 - Early and rapid **iterative process to develop optimal system requirements** through selective breadboarding and critical demonstrations.
 - Detailed design plan that documents the requirements and basis of both hardware and process qualification for each system element **including** the interface to the user.
 - **Functional Brassboard that allows early demonstration** of design and full quantitative understanding of elemental performance.
 - Life test Brassboard of EM that **allows early accelerated high voltage life verification. DO NOT TRY AND WRING OUT THE DESIGN ON THE EM UNIT!**
 - EQM (if required).
 - PFM + FM + Spare Units tested according to a progressive **2 phase test strategy.**

“T-E-M-P” Design Approach...

- *Successful execution of the careful and detailed “Thermal-Electrical-Mechanical-Process” approach for the integrated elements of your design will determine the success of its implementation.*
 - *Control the design from the top-down and end-to-end.*
 - *Synthesize your design as a system of familiar elements that deliver a deterministic result.*
 - *Manage all T-E-M-P interfaces **by design**.*
 - *Use rational design criteria for key resources.*
 - *Control performance and margins by design.*
 - *Use analysis to verify the design rather than a way to make problems disappear.*

Achieving Deterministic Performance... 1

- *Deterministic performance in our context means that the high voltage unit and associated system not only meets its requirements but is also fully understood and tested functionally down to the element level.*
- *Operational states in response to control inputs together with off-nominal states such as turn-on, turn-off and stand-by states should be predictable and have **known measured system responses that assure safe and reliable operation.***
- *The unit should be testable at the element level to verify that it **performs as designed** as part of a larger test program intended to verify that the system requirements are satisfied.*

Achieving Deterministic Performance... 2

- *Achieving deterministic performance starts with the establishing the key T-E-M-P design factors, executing the design, controlling manufacture and then executing a detailed adjustment and test program.*
 - *Design realism and robustness.*
 - *Design precision yielding repeatable measurements and trend metrics.*
 - *Proper selection and utilization of parts.*
 - *Functional partitioning.*
 - *E-Field management.*
 - *Control of systematic errors.*
 - *Tolerance to arcing and random factors.*
 - *Adjusting to the center of the distribution.*
 - *Functional stabilization.*

Designing for Manufacture... 1

- *Successful manufacture of a high voltage system starts with the use of controlled, inspectable processes for a design that has had its requirements aligned to the application of proven functional elements.*
 - *Use of proven processes consistent with required element and system performance and reliability.*
 - *Managed assembly flow using detailed procedures to minimize damage or contamination of key components during handling and cleaning.*
 - *Perform engineering supervision of all key process steps.*
 - *Define Engineering and Quality inspections at key process points.*
 - *Ensure processes are matched to assembly capability of organization.*
 - *Use a build sequence that allows for a 2-phase test strategy.*

**Examples of Detailed
Process Control. Explain the
WHY as well as the WHAT!**

Designing for Manufacture... 2

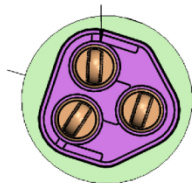
| Continued | | Initials/Date | Inspect/Date | Extension |
|-----------|---|---------------|--------------|-----------|
| 12 | <p>Install leaded TOP and BOT side passive components, test points and transistors EXCEPT FOR SAT components (shown in green on BOT side) R3, R125, R217, RN101, RN102, RN201, RN202, T101, T102, T201, T202, Q101, Q108, Q201, Q208, C131, C225, D105-D120, D124-D126, D205-D220 and D224-D227.</p> <p>Note: some of the parts lay down on the board while other parts stand up. Take care to assure that parts that lay down have strain relief on leads.</p> <p>Note: Wire ends on C113, C116, C134, C170, C207, C210, C228, C270, D104, D105, D204, D205, R12, R134, R178, R21, R226 and R270 should be trimmed to less than .010 inches and reflowed to eliminate sharp points per procedure BE/999/96/032A.</p> <p>Note that C171, C172, C271, C272, R182-R184 and R282-R284 are not part of circuit board assembly and will be installed in the "ear" sections of the module later in this procedure.</p> <p>If there are any other missing parts identify them below:</p> <p>_____</p> <p>_____</p> <p>_____</p> | | XXXXX | |
| *N | Take care to protect and not contaminate parts installed in previous steps. | | | |
| 13 | Install Microcircuits on TOP side. | | XXXXX | |
| 14 | Install heat shrink tubing on FB101, FB102, FB201 and FB202. | | XXXXX | |
| 15 | Form leads of Q101, Q108, Q201 and Q208 by splaying out the base and collector leads to fit into the PC board. Maintain the emitter leads straight out of the parts. | | XXXXX | |
| 16 | Slide ferrite beads on to the emitter leads of Q101, Q108, Q201 and Q208 and then insert the parts into the PC board such that the bead is still free to move with ~.010 inch clearance. Solder parts in place. | | XXXXX | |
| 17 | Clean thoroughly with IPA or ethyl alcohol. | | XXXXX | |
| IP | INSPECTION POINT- Complete parts placement, soldering inspection and lead length inspection. Also verify polarity of all tantalum capacitors. | XXXXX | | |
| *N | Note: Several of the steps below involve the installation of specialty items or high voltage parts with associated placement and lead trimming issues. They are to be performed under the supervision of S. Battel or with his cognizance | XXXXX | XXXXX | XXXXX |

| Continued | | Initials/Date | Inspect/Date | Extension |
|-----------|--|---------------|--------------|-----------|
| 34 | Using same (or another) batch of EN-11 from STEP 29, install top multiplier shields T100 (CIPS-M-24015) and T200 (CIPS-M-24016) . Cure for 16 hours at 60C (in parallel with STEP 29) prior to further handling. | | XXXXXX | |
| 35 | Under the direction of S. Battel, apply EN-11 per procedure BE/999/94/248A to bottom-side high voltage resistor shield CIPS-M24013 in RN101 and RN201 locations. Take care to achieve a void-free interface. Cure for 16 hours at 60C prior to further handling. | | XXXX | |
| | MIX# _____ | | | |
| 36 | Using same (or another) batch of EN-11 from STEP 31, install bottom multiplier shields B100 (CIPS-M-24018) and B200 (CIPS-M-24017) . Cure for 16 hours at 60C (in parallel with STEP 31) prior to further handling. | | XXXXXX | |
| 37 | Pre-form leads of high voltage resistors RN101, RN102, RN201 and RN202 and install leaving .020 inch gap above insulators. Trim HV leads (1 place on each part) to eliminate sharp points and re-flow solder to minimize potential for HV breakdown per procedure BE/999/96/032A. Clean locally using IPA. | | XXXXXX | |
| 38 | Install thermistor R3. Clean locally using IPA. | | XXXXXX | |
| 39 | Mix Cab-O-Sil EN-11 per procedure BE/999/94/059B. Under the direction of S. Battel, stake RN101, RN102, RN201, RN202, C131, C225 and R3. Cure for 6 hours at room temperature followed by 16 hours at 60C prior to further handling. | | XXXXXX | |
| 40 | Prepare a 10 gram batch of Epo-Tek H22 silver epoxy per BE/999/98/115. Be sure to retain some of the material for a cure coupon. | | XXXXXX | |
| | MIX# _____ | | | |
| 41 | Form chassis stubs from STEP 22 with modest strain relief to be in contact with the center of the box wall. Apply epoxy to the wire and wall to effect a solid electrical connection. | | XXXXXX | |
| | Take great care to ensure that no silver epoxy touches the PC board or any high voltage insulators. | | | |
| 42 | Insert 2 HV shields (PN BE21903740B1) into turrets and solder in place. Ensure that shields are installed flush with bottom of turrets and have good solder fillet. | | XXXXXX | |
| 43 | Clean thoroughly. | | XXXXXX | |
| 44 | Install T101, T102, T201 and T202 under the direction of S. Battel. Trim Pin 2 on each device per procedure BE/999/96/032A. | | XXXXXX | |
| | Note that once magnetics devices are installed, board cannot be immersed in solvents and must be very carefully cleaned to avoid attack and crazing of magnet wire. Take great care with all cleaning processes. | | | |

Designing for Manufacture... 3

Continued

| | Initials/Date | Inspect/Date | Extension |
|------|---------------|--------------|-----------|
| 48 | | XXXXX | |
| 49 | | XXXXX | |
| IP | XXXXX | | |
| 50 | | XXXXX | |
| 51 | | XXXXX | |
| MIX# | | | |
| 52 | | XXXXX | |
| 53 | | XXXX | |
| MIX# | | | |
| 54 | | XXXXX | |
| 55 | | XXXXX | |



Continued

| | Initials/Date | Inspect/Date | Extension |
|----|---------------|--------------|-----------|
| 66 | | XXXXX | |
| 67 | | XXXXX | |
| 68 | | XXXXX | |
| 69 | | XXXXX | |
| 70 | | XXXXX | |
| 71 | | XXXXX | |
| 72 | | XXXXX | |
| 73 | | XXXXX | |
| 74 | | XXXXX | |
| *N | | | |
| 75 | | XXXXX | |
| 76 | | XXXX | |

Designing for Analysis...

- *Designs should be functionally partitioned and incorporate test points such that each element can be functionally tested and then correlated with **key** analysis results.*
 - *Analysis should be performed at the system level as part of an integrated T-E-M-P strategy.*
 - *Precision designs should use components with inherent precision and stability or incorporate trim adjustments that center unit performance at the preferred mid-point of the functional and/or aging distribution.*
 - *Most elements once incorporated into a high voltage system are best tested for overall robustness through a VTF approach where every internal element is parametrically monitored and trended.*
- *If possible, high voltage elements should be designed with symmetry and controlled geometries that are understandable through hand analysis as well as computer-aided techniques.*

Designing for Test... 1

- *High voltage designs are best understood through detailed functional testing at both the element and system level.*
 - *Ability to test each element through its full design range.*
 - *Simple and controlled interfaces.*
 - *Partitioning and insertion of accessible test points.*
 - *Compatible with standard and reproducible test setups.*
 - *Precision necessary for repeatable tests and repeatable metrics.*
- *Build in the capability to test in 2 phases.*
 - ***Phase 1 testing to design** at the element level (typically prior to irreversible steps such as potting) **using internal test points**, wide temperature/stress margins and incremental temperature steps.*
 - ***Phase 2 testing to unit requirements** after unit closeout over a narrower range using **correlated internal monitors**.*

Designing for Test... 2

Comparison of In-Process Test and Final Bench Test Data Sets

IUVS HVPS TEMP TEST DATA SHEET UNIT Fh-02 SN -02 DATE: JAN 09 2012

TEST CONDITION: 201K17 MEASURED TEMP: 118.7 TIME: 1038

| MHVDACSET→ PARAMETER | +15 VOLTS | NOM LOAD | | | | |
|-------------------------|-----------|----------|--------|--------|--------|--------|
| TEMPMON (CH105) | 0.000 | 1.000 | 2.000 | 3.000 | 4.000 | 5.000 |
| HV OFF | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15V-15L_A | 4.81 | 1.185 | XXXXX | XXXXX | XXXXX | XXXXX |
| +15V-15L_B | 4.92 | 1.184 | XXXXX | XXXXX | XXXXX | XXXXX |
| FHV_A/B_ON | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15V-15L_A | 2.327 | 1.183 | XXXXX | XXXXX | XXXXX | XXXXX |
| +15V-15L_B | 2.305 | 1.182 | XXXXX | XXXXX | XXXXX | XXXXX |
| MHV+FHV_A/B_ON | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15L_A | 28.91 | 30.90 | 33.68 | 36.28 | 38.2 | 42.0 |
| -15L_A | -1.94 | XXXXX | XXXXX | XXXXX | XXXXX | -1.88 |
| MFREQ_A | 66.407 | 62.025 | 68.256 | 68.715 | 68.528 | 69.073 |
| FFREQ_A | 58.127 | XXXXX | XXXXX | XXXXX | XXXXX | 59.111 |
| +GATE_A (CH221) | 36.6 | XXXXX | XXXXX | XXXXX | XXXXX | 37.4 |
| -GATE_A (CH221) | -18.2 | XXXXX | XXXXX | XXXXX | XXXXX | -19.05 |
| MHV_A (CH222) | 70.4 | 198.1 | 392.4 | 596.5 | 795.9 | 985.3 |
| FHV_A (CH223) | 603.4 | 62.02 | 6402 | 6602 | 6802 | 7002 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15L_B | 28.42 | 30.40 | 32.12 | 35.53 | 38.5 | 41.1 |
| -15L_B | -1.93 | XXXXX | XXXXX | XXXXX | XXXXX | -1.88 |
| MFREQ_B | 66.952 | 68.264 | 68.854 | 69.322 | 69.537 | 69.692 |
| FFREQ_B | 58.362 | XXXXX | XXXXX | XXXXX | XXXXX | 58.693 |
| +GATE_B (CH224) | 38.0 | XXXXX | XXXXX | XXXXX | XXXXX | 38.0 |
| -GATE_B (CH224) | -18.42 | XXXXX | XXXXX | XXXXX | XXXXX | -19.28 |
| MHV_B (CH225) | 700.4 | 198.1 | 392.4 | 596.5 | 795.8 | 985.3 |
| FHV_B (CH226) | 603.3 | 62.02 | 6402 | 6602 | 6802 | 7002 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| DACINPOT_A (CH111) | 0.000 | 1.000 | XXXXX | 2.588 | XXXXX | 4.888 |
| MHVMON_A (CH112) | 0.200 | 0.560 | XXXXX | 1.681 | XXXXX | 2.804 |
| FHVMON_A (CH113) | 2.427 | 2.482 | XXXXX | 2.643 | XXXXX | 2.803 |
| DACINPOT_B (CH114) | 0.000 | 1.000 | XXXXX | 2.588 | XXXXX | 4.888 |
| MHVMON_B (CH115) | 0.199 | 0.560 | XXXXX | 1.681 | XXXXX | 2.804 |
| FHVMON_B (CH116) | 2.426 | 2.482 | XXXXX | 2.643 | XXXXX | 2.803 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| GATE50_A (CH201) | 55.558 | 55.540 | XXXXX | XXXXX | XXXXX | 55.548 |
| GATE50_B (CH202) | 55.674 | 55.675 | XXXXX | XXXXX | XXXXX | 55.538 |
| VDAC_A (CH203) | 0.000 | 0.988 | XXXXX | XXXXX | XXXXX | 4.888 |
| MSENSE_A (CH204) | 0.337 | 0.718 | XXXXX | XXXXX | XXXXX | 5.002 |
| FSENSE_A (CH205) | 6.207 | 6.200 | XXXXX | XXXXX | XXXXX | 9.007 |
| DSENSE_A (CH206) | 3.338 | 3.328 | XXXXX | XXXXX | XXXXX | 3.328 |
| MERROR_A (CH207) | 1.262 | 1.415 | XXXXX | XXXXX | XXXXX | 2.242 |
| FERROR_A (CH208) | 2.525 | 3.000 | XXXXX | XXXXX | XXXXX | 7.092 |
| DIODEREF_A (CH209) | -6.328 | -6.318 | XXXXX | XXXXX | XXXXX | -6.327 |
| VDAC_B (CH210) | 0.000 | 0.988 | XXXXX | XXXXX | XXXXX | 4.888 |
| MSENSE_B (CH211) | 0.354 | 0.888 | XXXXX | XXXXX | XXXXX | 5.005 |
| FSENSE_B (CH212) | 6.038 | 6.202 | XXXXX | XXXXX | XXXXX | 7.008 |
| DSENSE_B (CH213) | 3.323 | 3.323 | XXXXX | XXXXX | XXXXX | 3.327 |
| MERROR_B (CH214) | 1.355 | 1.354 | XXXXX | XXXXX | XXXXX | 2.162 |
| FERROR_B (CH215) | 2.541 | 2.955 | XXXXX | XXXXX | XXXXX | 7.040 |
| DIODEREF_B (CH216) | -6.322 | -6.322 | XXXXX | XXXXX | XXXXX | -6.322 |

JAN 22 2012

IUVS HVPS BENCH TEST DATA SHEET UNIT Fh-02 SN -02 DATE:

TEST CONDITION: AMBIENT MEASURED TEMP: 68F TIME: 1108

| MHVDACSET→ PARAMETER | +15 VOLTS | NOM LOAD | | | | |
|-------------------------|-----------|----------|-------|-------|-------|--------|
| TEMPMON (CH105) | 0.08K | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| HV OFF | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15V-15L_A | 4.82 | 1.185 | XXXXX | XXXXX | XXXXX | XXXXX |
| +15V-15L_B | 4.92 | 1.183 | XXXXX | XXXXX | XXXXX | XXXXX |
| FHV_A/B_ON | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15V-15L_A | 2.327 | 1.184 | XXXXX | XXXXX | XXXXX | XXXXX |
| +15V-15L_B | 2.354 | 1.183 | XXXXX | XXXXX | XXXXX | XXXXX |
| MHV+FHV_A/B_ON | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15L_A | 29.46 | 31.52 | 34.40 | 37.17 | 39.9 | 42.7 |
| -15L_A | -1.95 | -1.93 | -1.91 | -1.91 | -1.91 | -1.90 |
| +GATE_A (CH221) | 38.6 | XXXXX | XXXXX | XXXXX | XXXXX | 38.6 |
| -GATE_A (CH221) | -19.6 | XXXXX | XXXXX | XXXXX | XXXXX | -20.0 |
| MHV_A (CH222) | 69.4 | 189.9 | 398.3 | 592.4 | 796.8 | 986.4 |
| FHV_A (CH223) | 602.2 | 6202 | 6402 | 6602 | 6802 | 7002 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15L_B | 29.85 | 31.00 | 33.84 | 36.58 | 39.3 | 42.0 |
| -15L_B | -1.94 | -1.91 | -1.90 | -1.89 | -1.89 | -1.88 |
| +GATE_B (CH224) | 38.0 | XXXXX | XXXXX | XXXXX | XXXXX | 38.1 |
| -GATE_B (CH224) | -19.8 | XXXXX | XXXXX | XXXXX | XXXXX | -19.43 |
| MHV_B (CH225) | 68.8 | 199.0 | 398.2 | 592.3 | 796.8 | 986.4 |
| FHV_B (CH226) | 602.3 | 6203 | 6403 | 6603 | 6803 | 7004 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| DACINPOT_A (CH111) | 0.000 | 1.000 | 2.000 | 2.888 | 3.888 | 4.888 |
| MHVMON_A (CH112) | 0.195 | 0.560 | 1.120 | 1.681 | 2.242 | 2.804 |
| FHVMON_A (CH113) | 2.430 | 2.482 | 2.562 | 2.642 | 2.722 | 2.802 |
| DACINPOT_B (CH114) | 0.000 | 1.000 | 2.000 | 2.888 | 3.888 | 4.888 |
| MHVMON_B (CH115) | 0.193 | 0.560 | 1.121 | 1.681 | 2.243 | 2.805 |
| FHVMON_B (CH116) | 2.434 | 2.482 | 2.562 | 2.642 | 2.722 | 2.808 |

Designing for Test... 3

Unit Comparisons
from Different Builds
7 years Apart

IUVS HVPS TEMP TEST DATA SHEET UNIT Fh-02 SN -02 DATE: JAN 09 2012
TEST CONDITION: 201M17 MEASURED TEMP: 118.7 TIME: 1038

| MVHDACSET→ PARAMETER | +/-15 VOLTS NOM LOAD | | | | | |
|-------------------------|----------------------|--------|--------|--------|--------|---------|
| | 0.000 | 1.000 | 2.000 | 3.000 | 4.000 | 5.000 |
| TEMPMON (CH105) | 12.345 | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| HV OFF | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15U/-15L A | 4.81 -1.95 | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15U/-15L B | 4.92 -1.94 | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| FHV A/B ON | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15U/-15L A | 23.27 -1.93 | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15U/-15L B | 23.05 -1.92 | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| MHV+FHV A/B ON | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15L A | 28.91 | 30.90 | 33.68 | 36.28 | 38.2 | 42.0 |
| -15L A | -1.94 | XXXXX | XXXXX | XXXXX | XXXXX | -1.89 |
| MFREQ A | 66.407 | 62.035 | 68.256 | 68.315 | 68.528 | 69.073 |
| FFREQ A | 58.127 | XXXXX | XXXXX | XXXXX | XXXXX | 59.111 |
| +GATE A (CH221) | 36.6 | XXXXX | XXXXX | XXXXX | XXXXX | 37.4 |
| -GATE A (CH221) | -18.2 | XXXXX | XXXXX | XXXXX | XXXXX | -19.05 |
| MHV A (CH222) | 70.4 | 198.1 | 392.4 | 596.5 | 795.9 | 985.3 |
| FHV A (CH223) | 6034 | 602 | 6402 | 6602 | 6802 | 7002 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15L B | 28.42 | 30.40 | 32.17 | 35.53 | 38.5 | 41.1 |
| -15L B | -1.93 | XXXXX | XXXXX | XXXXX | XXXXX | -1.88 |
| MFREQ B | 66.952 | 68.264 | 68.554 | 69.322 | 69.537 | 69.692 |
| FFREQ B | 58.362 | XXXXX | XXXXX | XXXXX | XXXXX | 58.693 |
| +GATE B (CH224) | 38.0 | XXXXX | XXXXX | XXXXX | XXXXX | 38.0 |
| -GATE B (CH224) | -18.42 | XXXXX | XXXXX | XXXXX | XXXXX | -19.2.8 |
| MHV B (CH225) | 70.4 | 198.1 | 392.4 | 596.5 | 795.9 | 985.3 |
| FHV B (CH226) | 6034 | 602 | 6402 | 6602 | 6802 | 7002 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| DACINPUT A (CH111) | 0.000 | 1.000 | XXXXX | 2.589 | XXXXX | 4.899 |
| MHVMON A (CH112) | 0.200 | 0.560 | XXXXX | 1.681 | XXXXX | 2.804 |
| FHVMON A (CH113) | 2.427 | 2.582 | XXXXX | 2.643 | XXXXX | 2.803 |
| DACINPUT B (CH114) | 0.000 | 1.000 | XXXXX | 2.589 | XXXXX | 4.899 |
| MHVMON B (CH115) | 0.199 | 0.560 | XXXXX | 1.681 | XXXXX | 2.804 |
| FHVMON B (CH116) | 2.426 | 2.582 | XXXXX | 2.643 | XXXXX | 2.803 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| GATE50 A (CH201) | 55.558 | 55.540 | XXXXX | 55.548 | XXXXX | 55.548 |
| GATE50 B (CH202) | 55.679 | 55.615 | XXXXX | 55.538 | XXXXX | 55.538 |
| VDAC A (CH203) | 0.000 | 0.999 | XXXXX | 4.998 | XXXXX | 4.998 |
| MSENSE A (CH204) | 0.237 | 0.718 | XXXXX | 5.002 | XXXXX | 5.002 |
| DSENSE A (CH205) | 6.207 | 6.200 | XXXXX | 6.095 | XXXXX | 6.095 |
| DSENSE A (CH206) | 2.338 | 2.328 | XXXXX | 2.323 | XXXXX | 2.323 |
| MERROR A (CH207) | 1.662 | 1.415 | XXXXX | 2.242 | XXXXX | 2.242 |
| FERROR A (CH208) | 2.525 | 2.000 | XXXXX | 2.092 | XXXXX | 2.092 |
| DIODEREF A (CH209) | -6.328 | -6.318 | XXXXX | -6.323 | XXXXX | -6.323 |
| VDAC B (CH210) | 0.000 | 0.999 | XXXXX | 4.998 | XXXXX | 4.998 |
| MSENSE B (CH211) | 0.234 | 0.718 | XXXXX | 5.002 | XXXXX | 5.002 |
| DSENSE B (CH212) | 6.038 | 6.202 | XXXXX | 6.008 | XXXXX | 6.008 |
| DSENSE B (CH213) | 2.323 | 2.323 | XXXXX | 2.323 | XXXXX | 2.323 |
| MERROR B (CH214) | 1.355 | 1.355 | XXXXX | 1.355 | XXXXX | 1.355 |
| FERROR B (CH215) | 2.541 | 2.555 | XXXXX | 2.562 | XXXXX | 2.562 |
| DIODEREF B (CH216) | -6.322 | -6.322 | XXXXX | -6.322 | XXXXX | -6.322 |

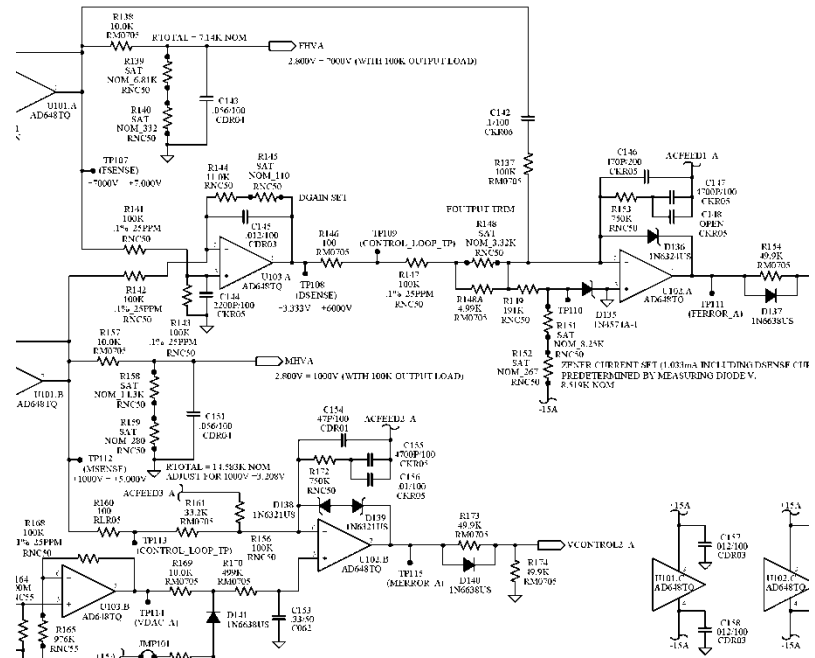
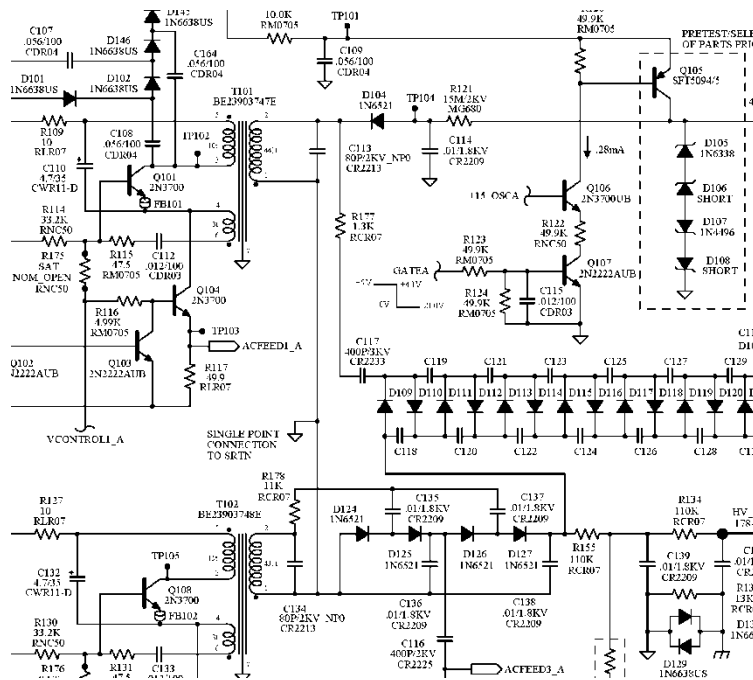
AIM HVPS TEMP TEST DATA SHEET UNIT 1F SN 004AD DATE: 12/16/04
TEST CONDITION: +20f MEASURED TEMP: 119.3 TIME: 0936

| MVHDACSET→ PARAMETER | +/-15 VOLTS NOM LOAD | | | | | |
|-------------------------|----------------------|----------|--------|--------|--------|--------|
| | 0.000 | 1.000 | 2.000 | 3.000 | 4.000 | 5.000 |
| TEMPMON (CH105) | 11.327 | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| HV OFF | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15U/-15L A | 5.00 -1.203 | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15U/-15L B | 5.03 -1.98 | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| FHV A/B ON | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15U/-15L A | 25.321 -2.00 | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15U/-15L B | 25.16 -1.96 | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| MHV+FHV A/B ON | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15L A | 25.64 | 31.89 | 34.56 | 37.10 | 38.5 | 42.0 |
| -15L A | -2.01 | XXXXX | XXXXX | XXXXX | XXXXX | -1.91 |
| MFREQ A | 67.384 | 68.559 | 69.610 | 69.937 | 70.127 | 70.230 |
| FFREQ A | 60.927 | XXXXX | XXXXX | XXXXX | XXXXX | 60.355 |
| +GATE A (CH221) | 38.1 | XXXXX | XXXXX | XXXXX | XXXXX | 38.1 |
| -GATE A (CH221) | -200.1 | XXXXX | XXXXX | XXXXX | XXXXX | -200.2 |
| MHV A (CH222) | 70.1 | 199.1 | 399.4 | 592.4 | 796.6 | 995.8 |
| FHV A (CH223) | 6021.3 | 6201.2 | 6401.1 | 6600.6 | 6800.4 | 7000.2 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| +15L B | 25.38 | 31.46 | 34.11 | 36.62 | 38.1 | 41.6 |
| -15L B | -1.92 | XXXXX | XXXXX | XXXXX | XXXXX | -1.87 |
| MFREQ B | 67.003 | 68.191 | 68.814 | 69.129 | 69.305 | 69.412 |
| FFREQ B | 60.367 | XXXXX | XXXXX | XXXXX | XXXXX | 60.210 |
| +GATE B (CH224) | 38.0 | XXXXX | XXXXX | XXXXX | XXXXX | 38.3 |
| -GATE B (CH224) | -202.2 | XXXXX | XXXXX | XXXXX | XXXXX | -202.3 |
| MHV B (CH225) | 65.9 | 199.2 | 399.4 | 592.3 | 792.1 | 996.5 |
| FHV B (CH226) | 6022.9 | 6202.3 | 6401.9 | 6601.3 | 6801.0 | 7000.2 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| DACINPUT A (CH111) | 0.0000 | 1.9998 | XXXXX | 2.9995 | XXXXX | 4.9995 |
| MHVMON A (CH112) | 0.197 | 0.599 | XXXXX | 1.600 | XXXXX | 2.600 |
| FHVMON A (CH113) | 2.427 | 2.427 | XXXXX | 2.632 | XXXXX | 2.632 |
| DACINPUT B (CH114) | 0.0000 | 1.9998 | XXXXX | 2.9995 | XXXXX | 4.9995 |
| MHVMON B (CH115) | 0.180 | 0.599 | XXXXX | 1.601 | XXXXX | 2.601 |
| FHVMON B (CH116) | 2.428 | 2.428 | XXXXX | 2.632 | XXXXX | 2.632 |
| XXXXXXXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX | XXXXX |
| GATE50 A (CH201) | 55.500 | 55.500 | XXXXX | 55.500 | XXXXX | 55.500 |
| GATE50 B (CH202) | 55.485 | 55.485 | XXXXX | 55.485 | XXXXX | 55.485 |
| VDAC A (CH203) | -100.00 | 999.92 | XXXXX | 999.92 | XXXXX | 999.92 |
| MSENSE A (CH204) | 1.226 | 1.9996 | XXXXX | XXXXX | XXXXX | XXXXX |
| FSENSE A (CH205) | 6.095 | 6.095 | XXXXX | XXXXX | XXXXX | XXXXX |
| DSENSE A (CH206) | 2.323 | 2.323 | XXXXX | XXXXX | XXXXX | XXXXX |
| MERROR A (CH207) | 1.226 | 1.226 | XXXXX | XXXXX | XXXXX | XXXXX |
| FERROR A (CH208) | 2.112 | 2.112 | XXXXX | XXXXX | XXXXX | XXXXX |
| DIODEREF A (CH209) | -6.28837 | -6.28838 | XXXXX | XXXXX | XXXXX | XXXXX |
| VDAC B (CH210) | -100.00 | 999.92 | XXXXX | 999.92 | XXXXX | 999.92 |
| MSENSE B (CH211) | 1.2511 | 1.9992 | XXXXX | XXXXX | XXXXX | XXXXX |
| FSENSE B (CH212) | 6.0819 | 6.2116 | XXXXX | XXXXX | XXXXX | XXXXX |
| DSENSE B (CH213) | 2.337 | 2.337 | XXXXX | XXXXX | XXXXX | XXXXX |
| MERROR B (CH214) | 1.320 | 1.320 | XXXXX | XXXXX | XXXXX | XXXXX |
| FERROR B (CH215) | 2.071 | 2.071 | XXXXX | XXXXX | XXXXX | XXXXX |
| DIODEREF B (CH216) | -6.24021 | -6.24025 | XXXXX | XXXXX | XXXXX | XXXXX |

Designing for Test... 4

Test points should be placed to allow for easy measurement and to give full insight into design performance.

Example Test Point Placement



Designing for Repair...

- *Once specialty coatings are applied or encapsulation occurs, most high voltage elements cannot be repaired with guaranteed reliability.*
 - *Insulation is materially degraded by the repair process.*
 - *Transitional boundaries or gaps introduced.*
- *Some elements such as magnetics can be replaced if the design is made compatible.*
- *Best approach is 2 phase testing with burn-in **prior** to final irreversible coating and encapsulation steps.*
 - *Also allows for higher temperature operation during process.*
- *Sparing philosophy must account for unit replacement including long processing time.*

We are “poachers”... fortunately poaching is legal in our business!

What Drives Technology in Our Business?

Electric Power Industry – Largely overseas; Interests are ultra-high voltage techniques buried cable insulation performance and aging, insulator design, ceramic materials, modeling methods, measurement equipment, specialty fuel cell materials, nano-materials and diagnostic test methods.

Automobile Industry – Domestic and overseas; Interests are engineering plastics, power electronics, high temperature durability and material aging.

Commercial Displays – Largely overseas; Interests are transformer technology including piezo transformers and semiconducting coatings.

Particle Accelerators – Domestic but transitioning to overseas; Special interests are radiation effects on materials, analysis software, insulator design, high power DC and RF methods and pulse forming technology.

RF and Microwave – Domestic; Special interests in unique materials, high thermal conductivity materials, low dielectric constant materials, cables and connectors, specialty plating and coatings.

Key High Voltage Components and Technologies...

- *Magnetic Devices*
- *Capacitors*
- *Diodes*
- *Resistors*
- *Specialty Opto-Couplers (Modulators)*
- *Shielded and Unshielded Cables*
- *Connectors/Terminations*
- *Materials and Coatings*
- *Analysis Software*

Game Changers...

Change comes slow but does come in our business!

- *Understanding of aging effects in dielectrics (1960's).*
- *Floating plate ceramic capacitors (1970's).*
- *High performance high voltage cables (1970's).*
- *HV601-801 (and similar devices) opto-modulators (1980's).*
- *Parylene coating technology (1990's).*
- *Fine-line precision high voltage resistors (1990's).*
- *3D Field Analysis tools (1990's).*
- *Nano-particles (almost there).*
- *Piezo transformers (almost there).*
- *Silicon Carbide parts (almost there)*
- *Diamond based materials (almost there)*

Eroding National Capabilities...

- *PC Board Manufacturing*
- *Plating and Coatings*
- *Specialty Magnetic Components*
- *Low Frequency Semiconductor Devices*
- *High Voltage Bipolar Transistors*
- *Non-RoHS Electronic Components*
- *Skilled Hand Assembly*

Develop Trust and Confidence in Your Key Vendors...

- *The key vendors I usually work with are the following although there are many others that are qualified as well.*
- **CalRaminc** (30+ years including KD)
- **VMI** (30+ years)
- **Reynolds** (30+ years)
- **Caddock** (30+ years)
- **SSDI** (20+ years)
- **Ohmcraft** (15+ years)
- **RJR** (15+ years)
- **Micropac** (10+ years)

Don't be afraid to work with your vendors on special technology or component challenges!

Part Selection and Specification...

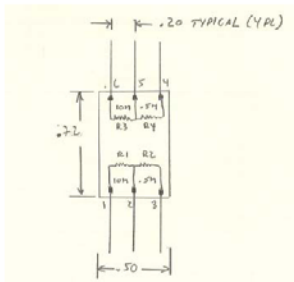
- *Don't be afraid to design a special part if it is inside your experience and if it results in a substantial simplification of the design or if it results in a substantial process or reliability improvement.*
- *Use SCD's or detailed spec sheets for parts and materials where element performance or reliability is critically dependent on fit or function. One great benefit of an SCD is that it reflects design intent and does not go out of date!*
- *Make sure your vendor is familiar with the key parameters that your design is dependent upon. Also work with your vendor on accepting parts if they are simply marginal on an uncritical but controlled parameter.*
- *Evaluate engineering devices out of same lot in parallel with screening and qualification to validate compatibility with design.*
- *Buy enough special parts to allow "cherry picking" for key parameters.*

SCD's Provide Clear Direction for Process Critical Parts... 1

Manufacturer's Part Number: CN-827

Quantity: 60 Delivered (plus TBD parts for testing/qualification at vendor). Note that extra parts are required to allow for selection in specific applications.

Body Size: 0.50" L X .72" H X .05 (max)" T



Resistance Ratio: 2 times 20:1

Value: 2 times 10.50 Megohms Overall; 10.0 Megohms/0.50 Megohm

Voltage Rating: 2,000 Vdc

Material Type: Flat 0.025" thick alumina substrate with non-inductive metal oxide resistance film on one side only. Dual resistor networks are mirror images of each other on opposing edges of substrate.

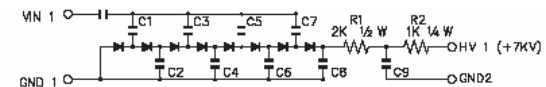
Coating: Blue Film over resistor pattern.

Ratio Tolerance: +/- 1.0%

Absolute Tolerance: +/- 1.0%

GND1, GND2 VIN, HV1

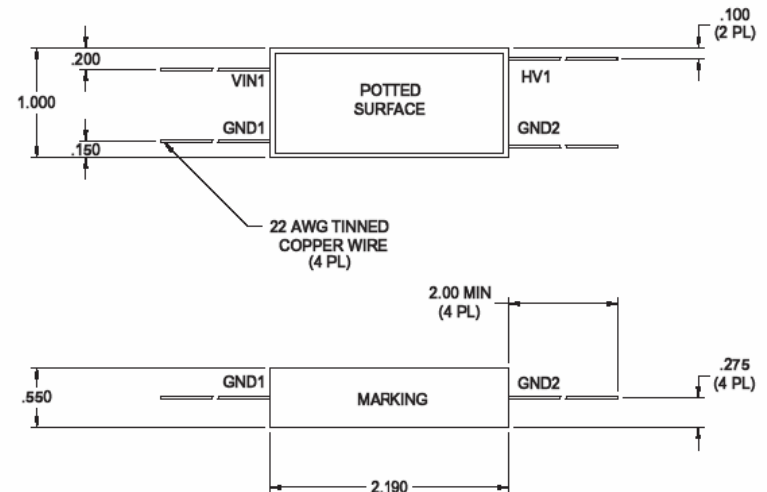
TOLERANCE
 .XX ±015
 .XXX ±010



NOTE:

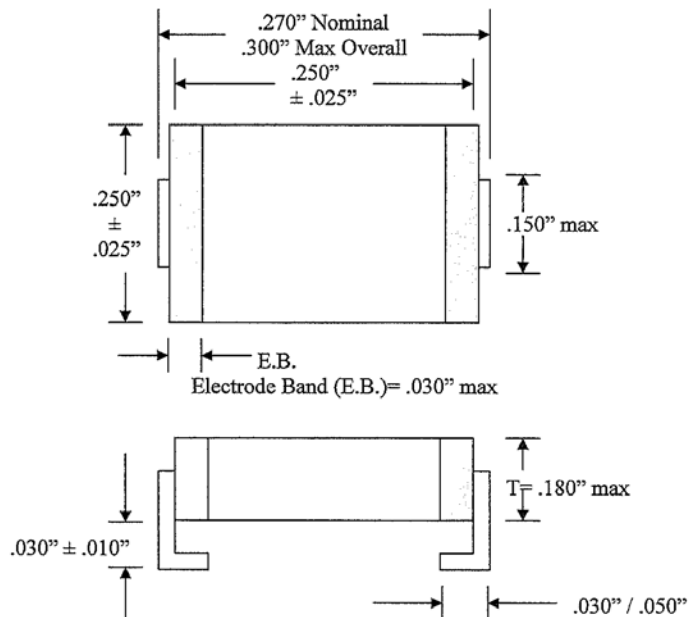
1) SANDBLAST ALL SURFACES OF SHELL PRIOR TO ASSEMBLY.

2) UNITS SHALL BE OVERPOTTED AND THEN THE TOP SURFACE GROUND TO THE FINISHED DIMENSION.



SCD's Provide Clear Direction for Process Critical Parts... 2

| | Date | Initials | Comments |
|------|---------|----------|----------|
| Rev. | 3/24/03 | | |
| Rev. | 3/28/03 | | P/N |
| Rev. | | | |



Specifications

- Capacitance= $10,000 \text{ pF} \pm 10\%$
- Dissipation Factor= $.025$ max
- Insulation Resistance
 - $100,000 \text{ meg}\Omega$ or $1000 \text{ meg}\Omega\text{-}\mu\text{F}$ whichever is less @ 25°C
 - $10,000 \text{ meg}\Omega$ or $100 \text{ meg}\Omega\text{-}\mu\text{F}$ whichever is less @ 25°C
- Rated Voltage= 1800 VDC
- Dielectric Type= X7R (BR), -40% max @ -55°C to 125°C w/ rated voltage applied, 125 V/mil max
- C-SAM Testing 100% per CalRamic Drawing #10107 Rev A
- Group A testing IAW Mil-Prf-49467B, except voltage conditioning to be 240 hours min @ rated voltage.
- Voltage conditioning to be performed in flourinert or equivalent.
- Partial discharge testing 100 % per Mil-Prf-49467, 42% of DC rating, 100 picocoulombs max continuous.

1. Tab configuration= 'B' as shown
2. Tab material $0.009''$ phosphorous bronze with $300 \mu \text{ in. min. } 90\% \text{ tin, } 10\% \text{ Lead (min)}$
3. High temp solder 10/88/2

Engineering Evaluation Methods...

- *Rapid evaluation of engineering parts or sample devices is an essential step prior to a final design commitment.*
- *A realistic “test as you operate” approach in combination with accelerated life testing and progressive “spiral” thermal testing can yield early confidence using relatively few parts and with a modest investment of time.*
- *Spiral tests typically involve 50 to 100 thermal cycles with a device operating in a realistic mode. Temperature range is progressively increased after each 10 to 20 cycles up to the device limits or to both understand device parametric performance and to determine the device limits.*

Example: -10 to +40; -25 to +55; -40 to +70; -55 to +85...

***Introducing Jeff Day to Discuss the
Design and Proper Application of
High Voltage Capacitors***



CALRAMIC
TECHNOLOGIES LLC

Jeff M. Day

President

jday@calramic.com

High Voltage Ceramic Capacitors

500 VDC – 20,000 VDC

2012 NASA/NESC

High Voltage Power Supply Design Workshop

April 2-3, 2012

Topics

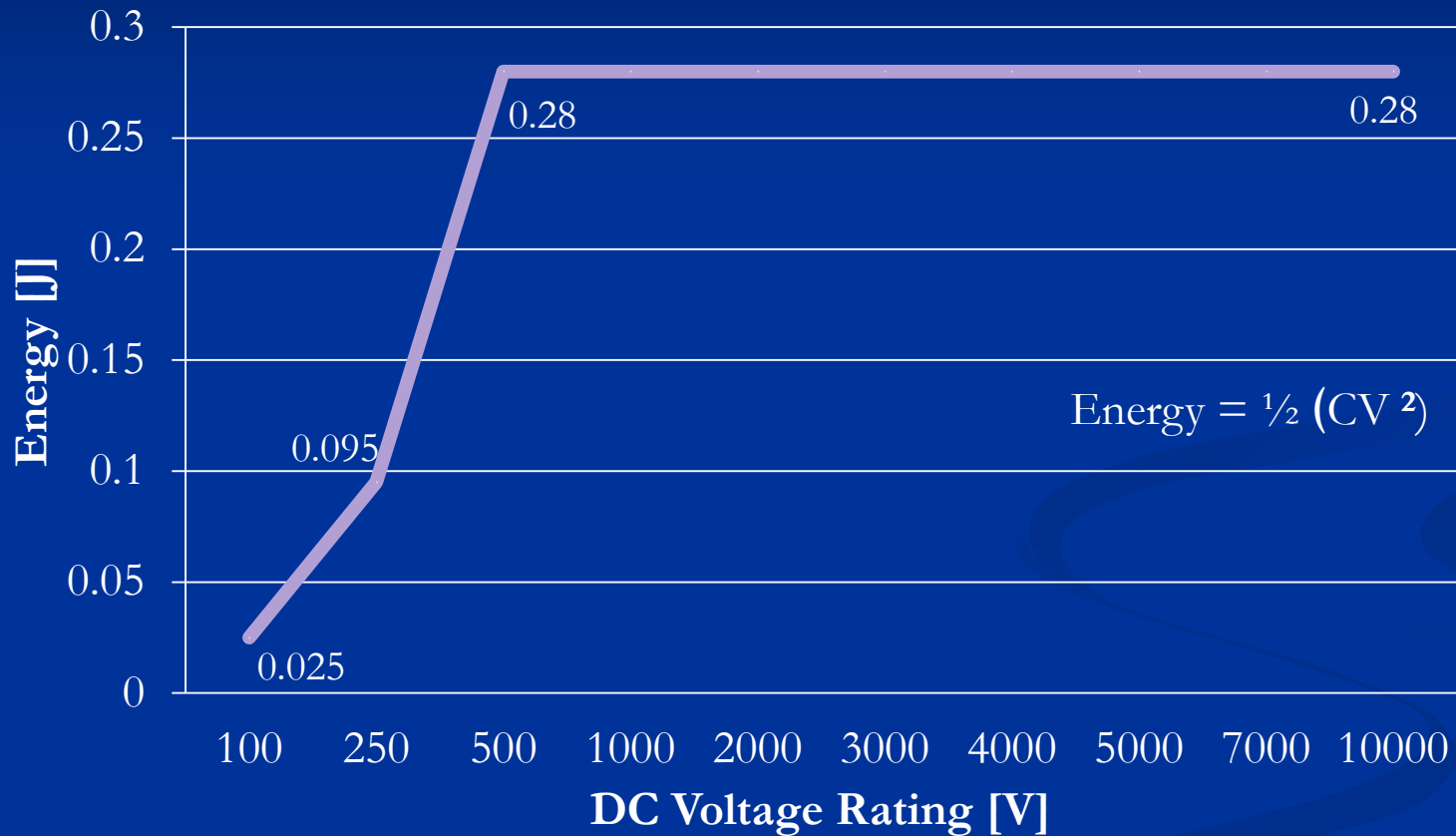
- High Voltage Dielectric Characteristics
- High Voltage Design Philosophies
- High Voltage Testing & Screening options

Our Philosophy of Reliability

- Materials Choice – High Quality, Consistent & Reliable Sources
- Space Quality HV Design Guidelines & Discipline
- Test & Screen to assure the first two are done well
- Establish a client/supplier partnership based on open communication to build trust & confidence

High Voltage Definition (X7R) Based Ceramics

Energy vs. Voltage Rating



High Voltage Ceramic Dielectric Types vs. Dielectric Constant

| Dielectric Type | Dielectric Constant (K) |
|--------------------------------|------------------------------------|
| Ceramic | 20 – 20,000 |
| High Voltage Ceramic | K75 – 110 (NPO) K2000-2600(X7R) |
| Mica | 4 – 8 |
| Electrolytic Dry & Wet | 4 – 10 |
| Film | 10 |
| Paper | 4 – 6 |
| Porcelain | 3 – 10 |
| Tantalum Oxide | 30 – 50 |
| Glass | 3 – 19 |
| Air | 1 |
| Al ₂ O ₃ | 9 |

- Two Conductive Layers
- Separated by a Dielectric Medium
- Ceramic exhibits much greater dielectric constants than the others, thereby offering a reduction geometries and mass
- As with any dielectric, understanding the limits of the material under load conditions in the application is critical

High Voltage Ceramic Dielectric Parameter Considerations

- Increases in K (Dielectric Constant) represent larger changes in intrinsic properties of the dielectric, such as:
 - Temperature Coefficient, Increases with higher K
 - **Voltage Coefficient, Increases with higher K**
 - Dissipation Factor, Increases with higher K
 - Dielectric Strength, Decreases with higher K's
 - Insulation Resistance, Decreases with higher K's
 - **Piezoelectric Properties increase with higher K's**
 - C-V Values, directly proportional to K

Voltage Temperature Coefficient (VTC) Summary

- Voltage Coefficient is based on material type and dielectric stress, as dielectric stress increases, voltage coefficient increases to a higher percentage of capacitance loss
- Power supply design considerations should be made based on the determination of the resulting capacitance at operating voltage & temperature

Voltage Temperature Coefficient

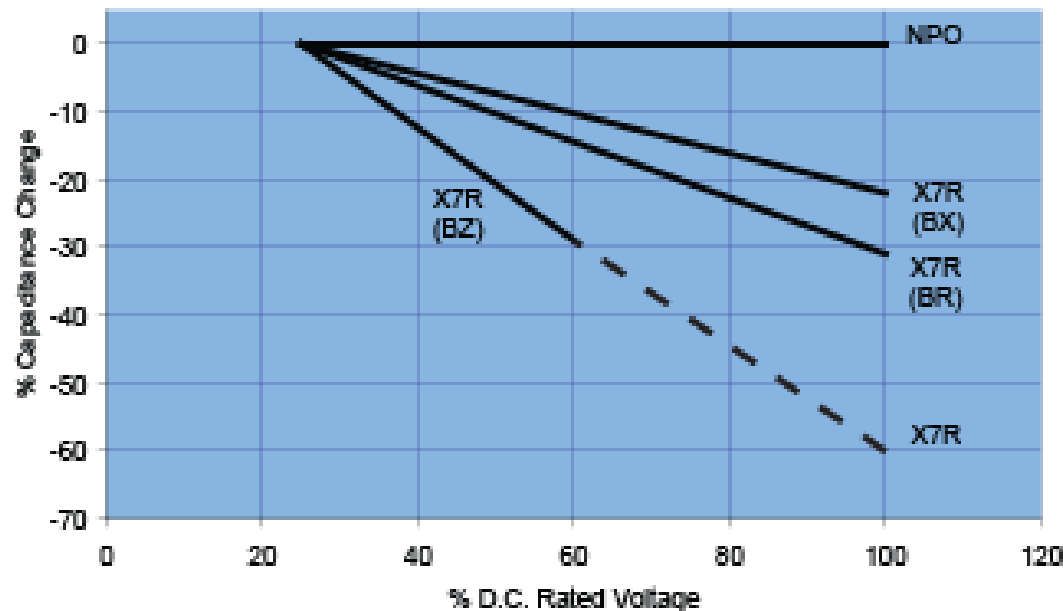
Change in Capacitance with Applied Voltage & Temperature

Ref: MIL-PRF-49467C

Dielectric Type (EIA Designation)

| Specifications | NPO (H.V.) | X7R (MIL-COMM) | X7R-BX (L.V.) | X7R-BR (H.V.) | X7R-BZ (H.V.) |
|---------------------|------------|----------------|---------------|---------------|---------------------------------|
| Voltage Coefficient | 0 | -70% Max | -25% Max | -40% Max | -40% Max @ 60% of Rated Voltage |

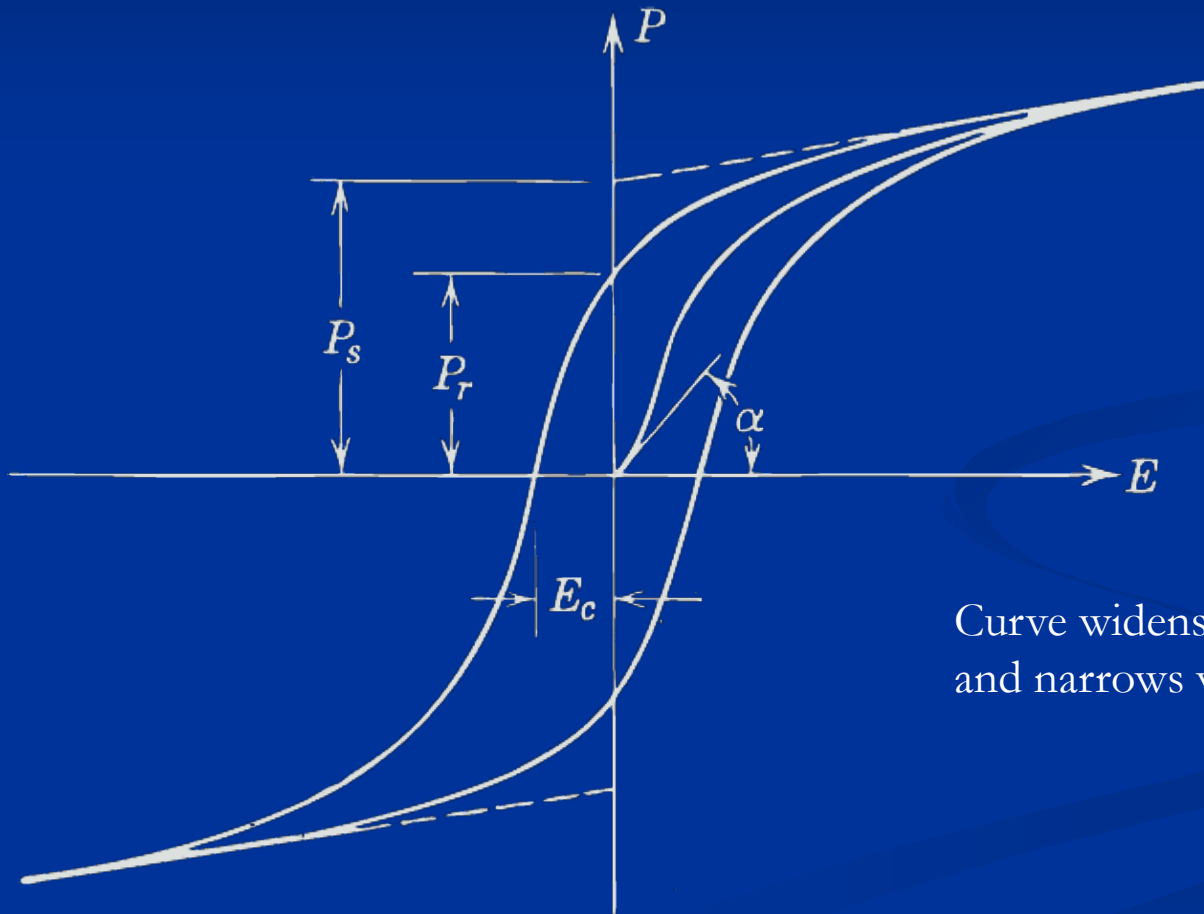
Typical Voltage Temperature Coefficient



Ferroelectric and Piezoelectric Properties

- Ferroelectric Dielectric – The spontaneous alignment of electric dipoles in the ceramic with an applied field
 - * X7R, BaTiO₃ Based Materials are Ferroelectric
 - * NPO Material is not
- Piezoelectric Dielectrics – Due to the Ferroelectric nature of the dielectric, an applied field creates a mechanical distortion
- Care should be taken when using X7R based dielectrics in AC, or pulse DC conditions. NPO dielectrics can be used in a variety of applications due to their non-ferroelectric/piezoelectric nature

Ferroelectric Dielectrics



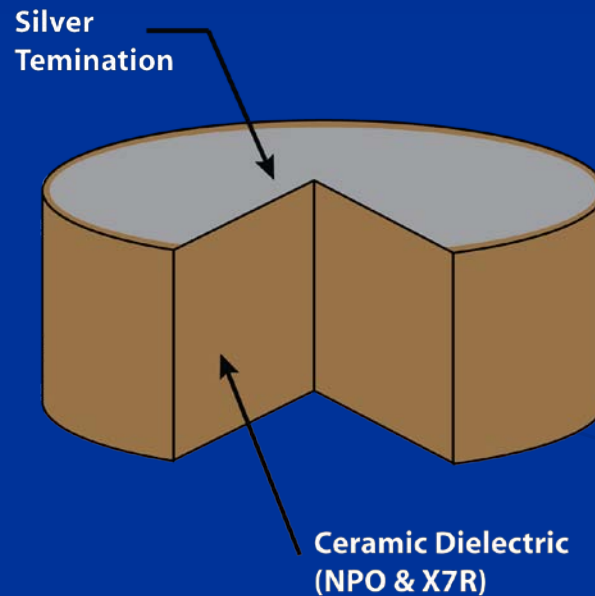
Curve widens with lower temperature,
and narrows with higher temperature

Fig. 18.32. A typical ferroelectric hysteresis loop

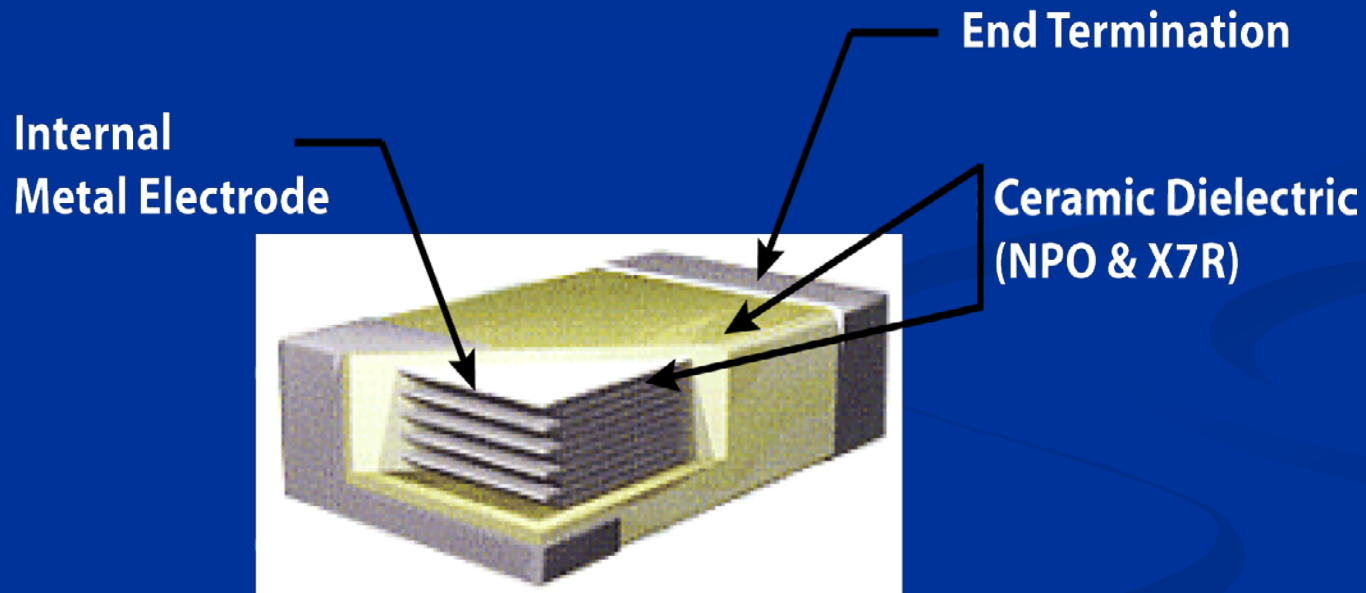
*J. Am. Chem. Soc., 58, 1486 (1936)

Design Philosophies

Typical Single Layer Ceramic Capacitor *(3,000VDC – 20,000VDC)*

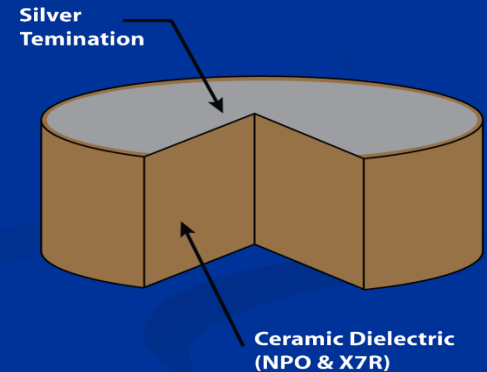
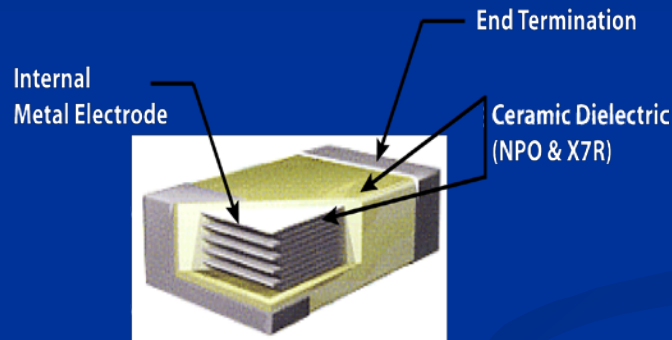


Typical Multilayer Ceramic Chip Capacitor (*500VDC – 10,000VDC*)



Formula for Calculating Capacitance of a Capacitor

$$\text{Capacitance} = \frac{.224 * K * A_f * N}{t_f}$$



Where: .224 = Constant

K = Dielectric Constant

A_f = Active Area

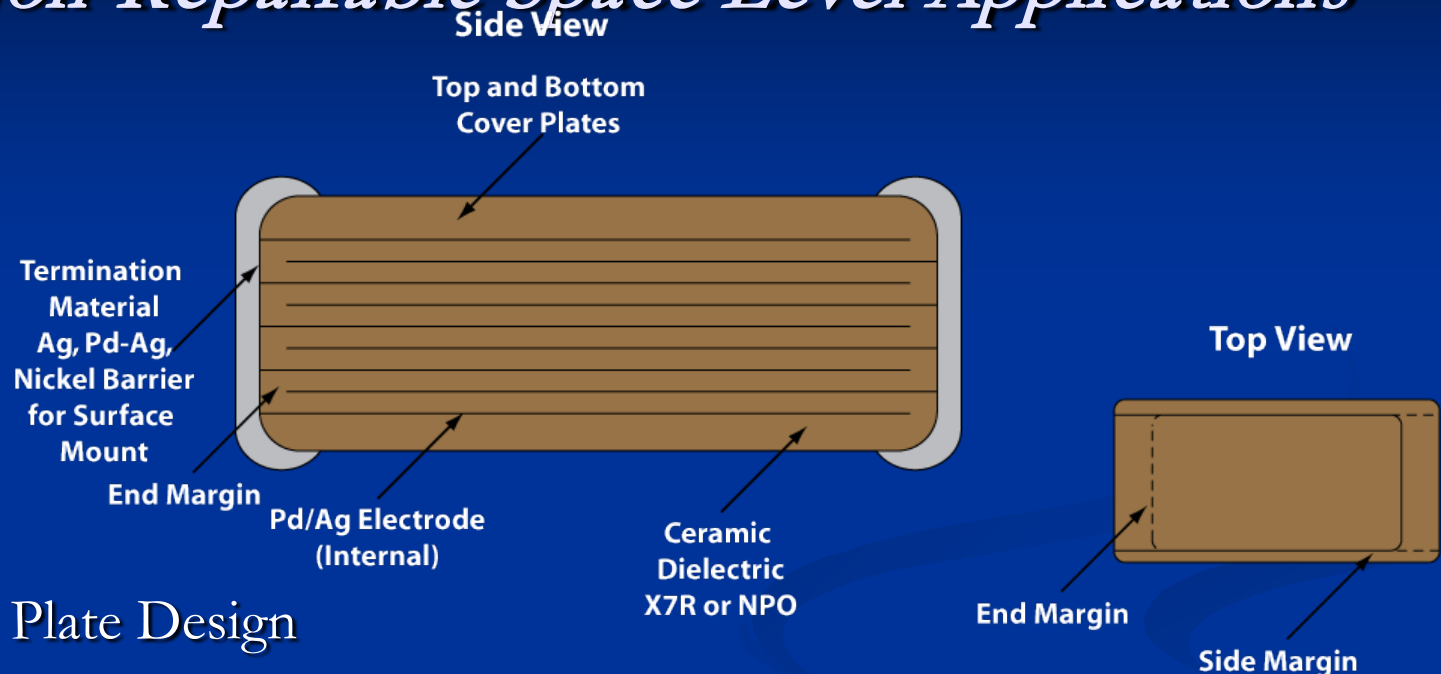
N = Number of Electrode Plates

t_f = Dielectric Thickness

Internal Construction

500 VDC – 1,000 VDC

Non-Repairable Space Level Applications

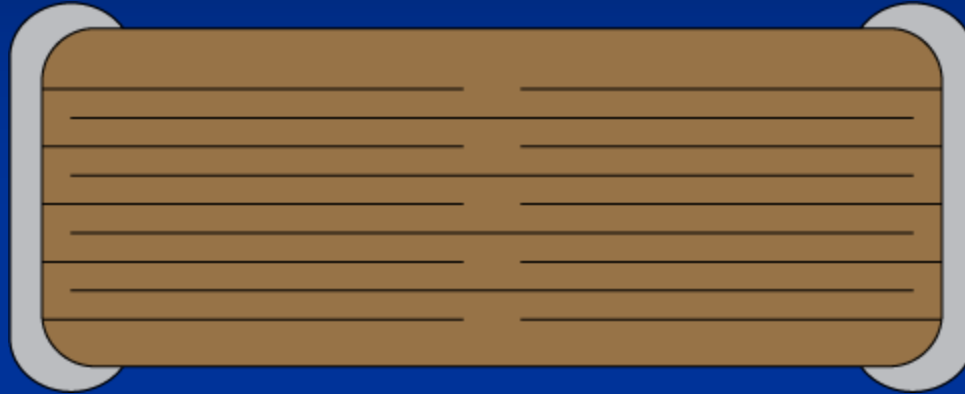


- Parallel Plate Design
- Co-fired Composite of Ceramic and Metal
- Design Considerations for Reliability
 - Dielectric Thickness < 125 volts/mil (X7R), 375 volts/mil (NPO)
 - Cover Plate Thickness at > 1.3x of Dielectric Thickness
 - End and Side Margins < 75 volts/mil
 - Radius on corners of electrode plates and external edges of structure

Internal Construction

2,000 VDC – 3,000 VDC

Non-Repairable Space Level Applications

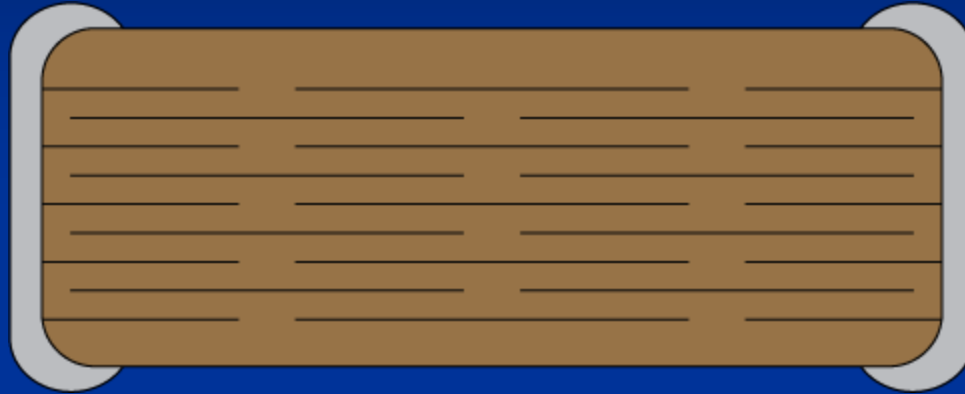


- Series Parallel Design
- Single Floating Plate
- 2 Capacitors in Series
- Reduction of Margin Stresses
- Same volts/mil Design Principles Apply

Internal Construction

4,000 VDC – 7,000 VDC

Non-Repairable Space Level Applications

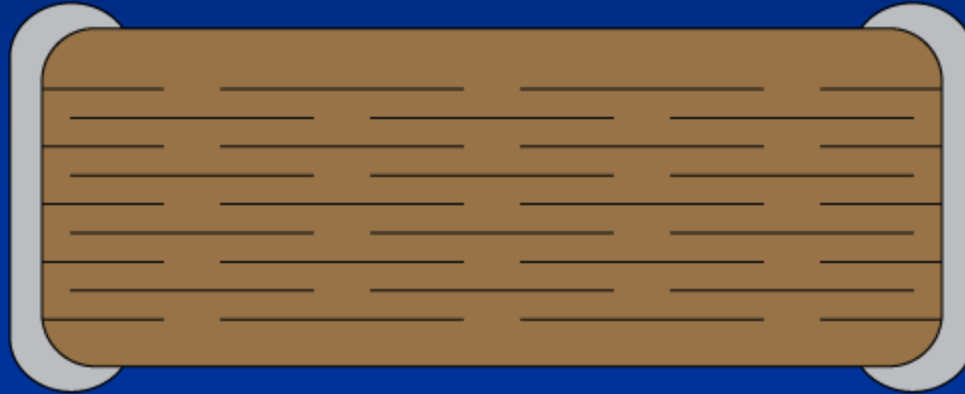


- Series Parallel Design
- 2 Floating Plates
- 4 Capacitors in Series
- Reduction of Margin Stresses
- Some loss of effective area
- Same volts/mil Design Principles Apply

Internal Construction

7,500 VDC – 10,000 VDC

Non-Repairable Space Level Applications



- Series Parallel Design
- 3 Floating Plates
- 6 Capacitors in Series
- Reduction of Margin Stresses
- Same volts/mil Design Principles Apply

Testing and Screening Options of High Voltage Ceramic Capacitors

100% Group A Screening per MIL-PRF-49467C

Non- Repairable Space Level

- 5 Cycles Thermal Shock, -55°C – 125°C
- Dielectric Withstanding Voltage @ $1.5x \leq 1250$ VDC rated, $1.2x > 1250$ VDC, $1.5x$ for Disc Capacitors
- Voltage Conditioning (Burn In) @ Rated Voltage and Temperature
- Insulation Resistance @ Rated Voltage and Temperature
- Insulation Resistance at 25°C
- Capacitance and Dissipation Factor at 25°C
- **100% Partial Discharge (Corona) Testing**
- Final Visual Inspection

100% SLAM/CSAM Ultrasound Testing

Non-Repairable Hi-Rel Applications

- Ultrasound Waves are transmitted through the Capacitor
- Detection of flaws in the Capacitor such as voids, delaminations and cracks
- Expensive Process
- Sometimes used in conjunction with Partial Discharge Testing

Group B Sampling per MIL-PRF-49467C

Table VI. Periodic Group B Inspection

| Inspection | Requirement Paragraph | Test Method Paragraph | Number of Sample Units to be Inspected | | Number of Defectives Permitted <u>2/</u> | |
|--|-----------------------|-----------------------|--|-----------|---|---|
| <u>Subgroup 1 (every 6 months)</u> | | | | | | |
| Terminal strength | 3.18 | 4.8.14 | 12 | <u>2/</u> | 1 | 1 |
| Resistance to soldering heat | 3.11 | 4.8.7 | | | | |
| Moisture resistance | 3.19 | 4.8.15 | | | | |
| | | | | | | |
| <u>Subgroup 2 (every 6 months)</u> | | | | | | |
| Voltage-temperature limits <u>3/</u> | 3.14 | 4.8.10 | 6 | | 1 | |
| Low temperature storage | 3.23 | 4.8.19 | | | | |
| Marking legibility (laser marking only) | 3.25.1 | 4.8.1.1 | | | | |
| <u>Subgroup 3 (every 6 months)</u> | | | | | | |
| Resistance to solvents | 3.21 | 4.8.17 | <u>4/</u> 4 | | 1 | |
| <u>Subgroup 4 (every 3 months)</u> | | | | | | |
| Life (at elevated ambient temperature) 2000 hours | 3.22 | 4.8.18 | 10 minimum per style | | 1 | |
| Partial Discharge | 3.10 | 4.8.6 | | | | |

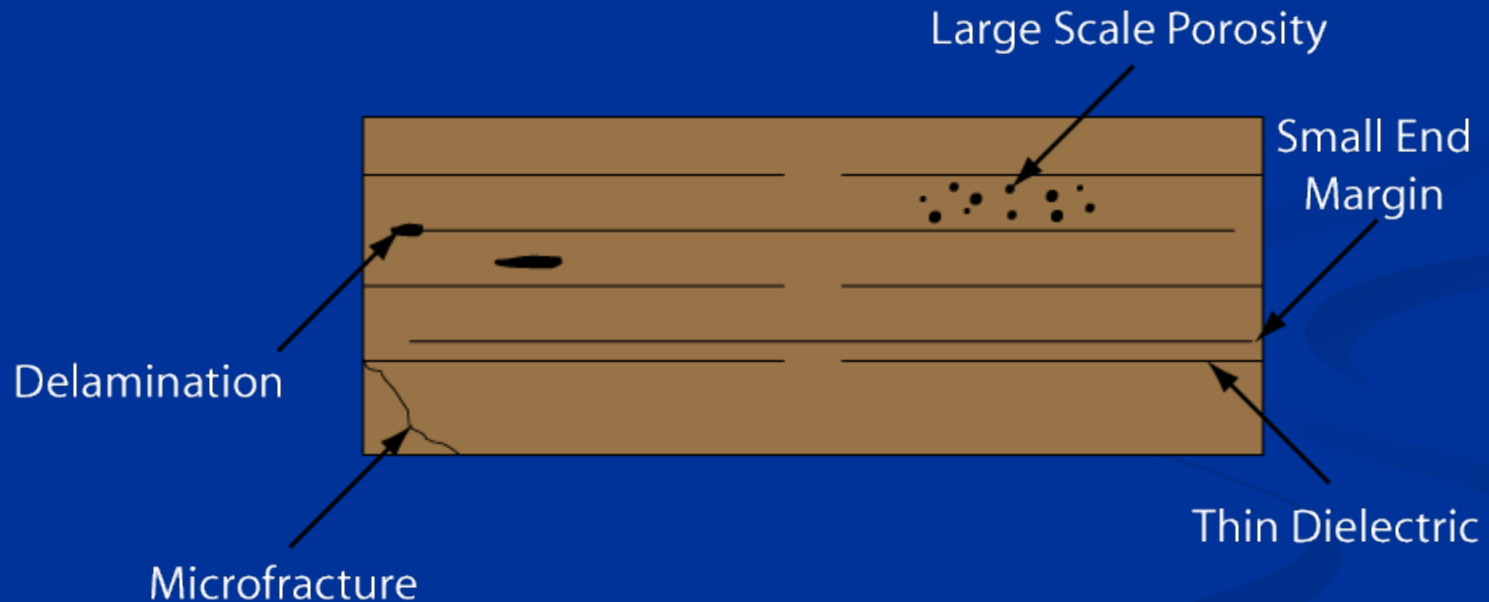
1/ A sample unit having one or more defects shall be charged as a single defective.

2/ Samples shall be representative of the highest capacitance value of each style manufactured during the sampling period.

3/ Samples shall be selected from a minimum of two lots per sampling period when more than one lot of dielectric is used.

4/ When more than one marking type is used (see 3.21), an additional four samples shall be added for each additional marking type.

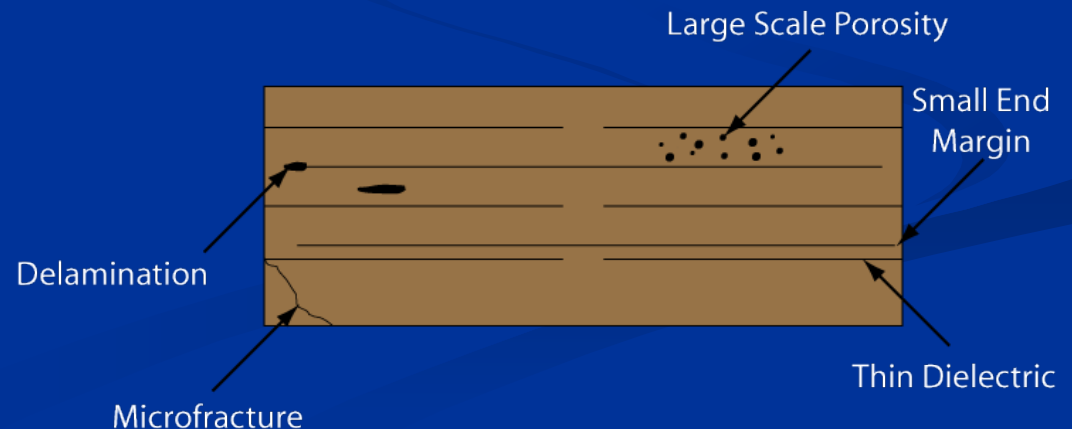
Potential Capacitor Flaws



Screening Options by Flaws

Group A, Mil prf-49467C (w/o Partial Discharge)

- Microfractures
- Large Delaminations
- Very Thin Dielectric
- Very Small End Margin



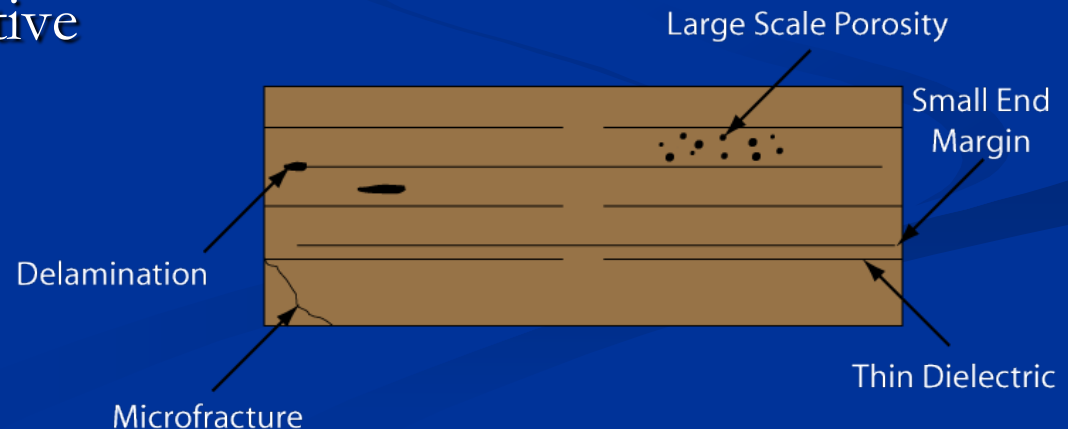
Screening Options by Flaws

Partial Discharge

- Microfractures
- Delaminations of Any Size in active area
- Thin Dielectric
- Large size Porosity in active area only
- Small End Margin

SLAM/C-SAM

- Large size Porosity or delaminations in all areas (cover plates)



Partial Discharge Overview

- Two primary breakdown mechanisms of ceramic capacitors are:
 - Electron Avalanche breakdown
 - Partial discharge Corona breakdown

Corona Breakdown

- Ionization of gas within a void or delamination caused by conduction of current across the flaw
- Governed by MIL-PRF-49467C, 0.42 x DC rating, tested @ VRMS, 60Hz, 25°C,
- 100 pico Coulombs maximum, continuous
- Applied voltages must be above Paschen's minimum of 320VRMS for Corona to occur
- Two types of Corona:
 - Townsend Type - Low intensity (10 pc), infrequent small spark, short duration
 - Streamer Type - Above CIV there is are continuous discharges, and may eventually lead to failure of the capacitor

References

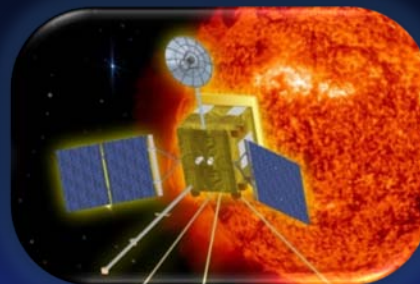
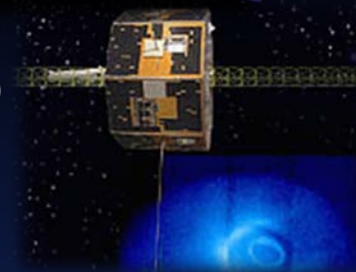
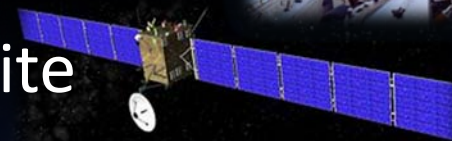
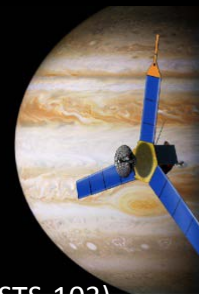
- Bartnikas, R. and Mahon, E.J., Editors, “Engineering Dielectrics Volume I Corona Measurement and Interpretation”, American Society for Testing and Materials, 1979, ATSM STP 669
- Boggs, S.A., “Partial Discharge: Overview and Signal Generation”, IEEE # 0883-7554/90/0700-0033, 1990
- Day, J., Roach, M., and Maxwell, J., “Partial Discharge (Corona) Testing for High Voltage Ceramic Capacitors”, Capacitor and Resistor Technology Symposium, March 1997, pp. 237-243
- MIL-PRF-49467C, Military Specifications, Capacitors, Fixed, Ceramic, Multilayer, High Voltage (General Purpose) Established Reliability, General Specification For
- EIA-469-C, Standard Test Method for Destructive Physical Analysis (DPA) of Ceramic Monolithic Capacitors

***Introducing Allen Drumheller to Discuss
the Design and Proper Application of
Specialty High Voltage Resistors***

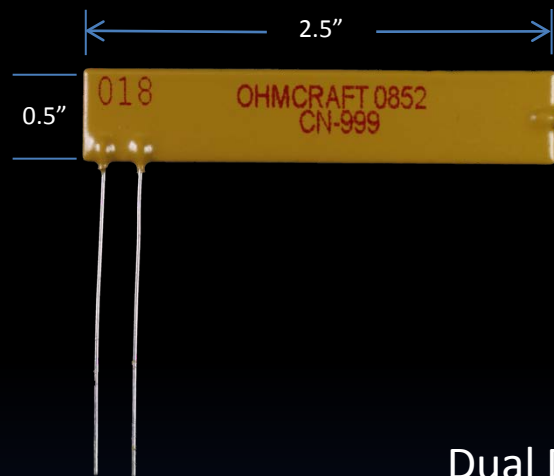
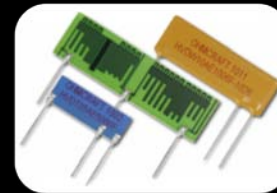
OHMCRAFT Space Applications



- MSL– CheMin, SAM
- Juno – JADE, JEDI
- Hubble Space Telescope (December 1999 repair STS-103)
- Rosetta, the Comet-Chasing Satellite
- IMAGE Satellite (Imager for Magnetopause-to-Aurora Global Exploration)
- Solar Orbiter - SWA

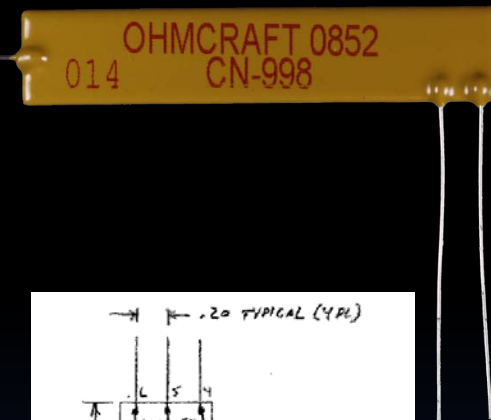


High Voltage Leaded Resistors

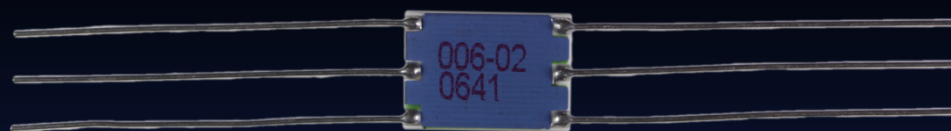


Battel Engineering

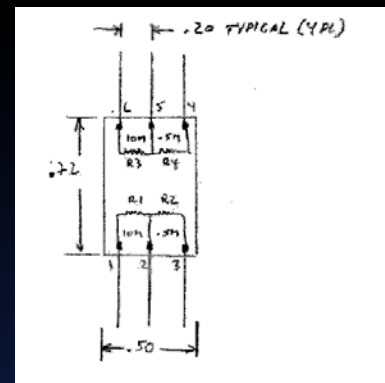
| | |
|---------------------------|-----------------|
| Continuous Voltage | 30KV |
| Value R_T | 3.001G Ω |
| Absolute Tolerance | $\pm 5\%$ |
| Ratio R_T/R_L | 3001:1 |
| Ratio Tolerance R_T/R_L | $\pm 0.25\%$ |
| Power | 0.3W |



Dual Dividers

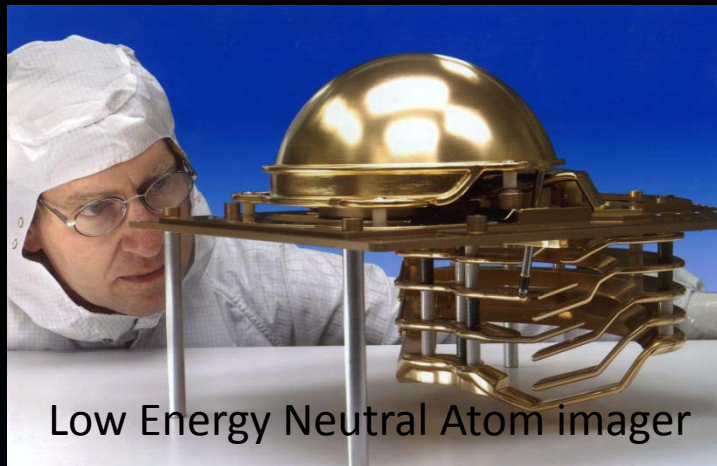
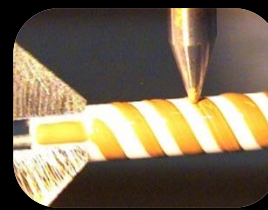


| | |
|---------------------------|----------------|
| Continuous Voltage | 2000V |
| Value R_T | 10.5M Ω |
| Absolute Tolerance | $\pm 1\%$ |
| Ratio R_T/R_L | 21:1 |
| Ratio Tolerance R_T/R_L | $\pm 1\%$ |
| Power | 0.3W |
| Size | 0.5 x 0.72" |

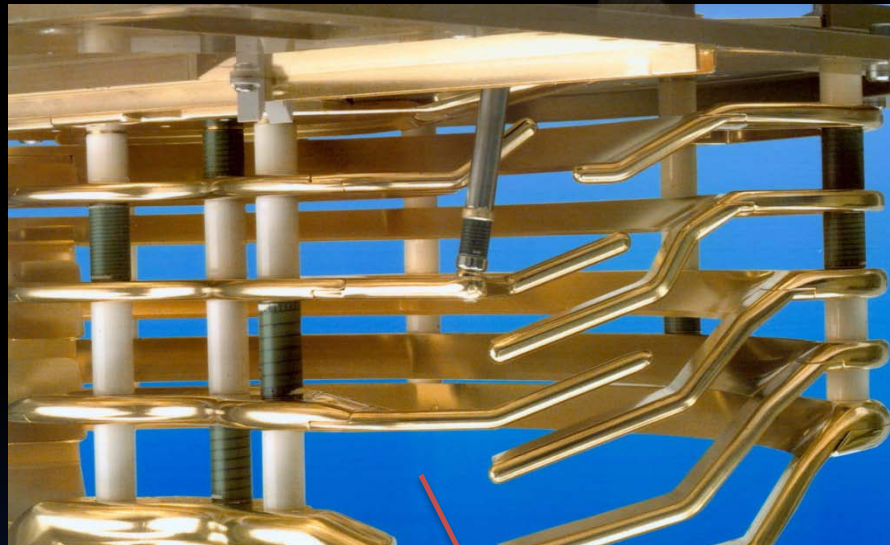


S. J. Battel
Drawing From
Procurement Specification

Non-Traditional Resistors



Low Energy Neutral Atom imager



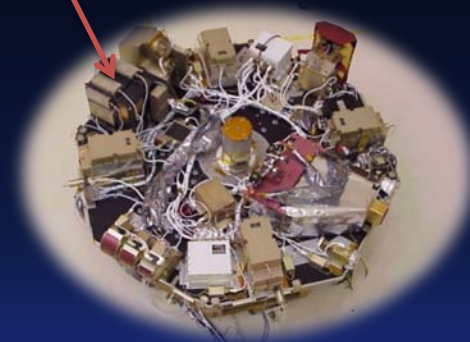
Lockheed Martin Missiles & Space Co.

8 Unique parts ranging from $539\text{M}\Omega$ to $11.138\text{G}\Omega \pm 1\%$

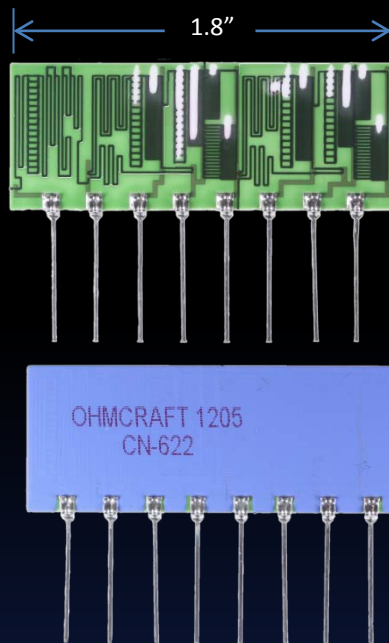
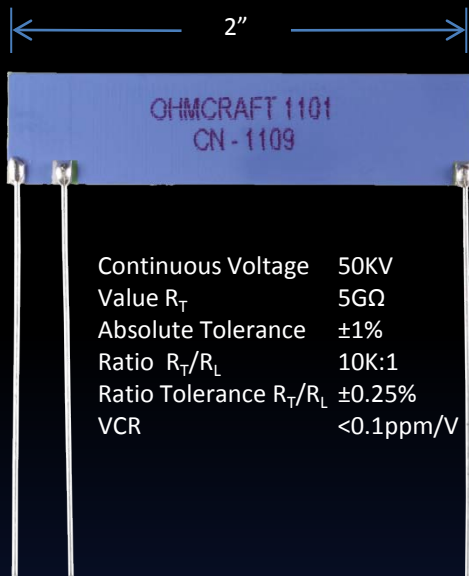
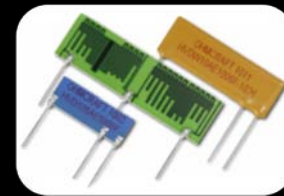
The resistor are part of the structure of the LENA instrument

LENA was 1 of 7 instruments on the IMAGE Spacecraft

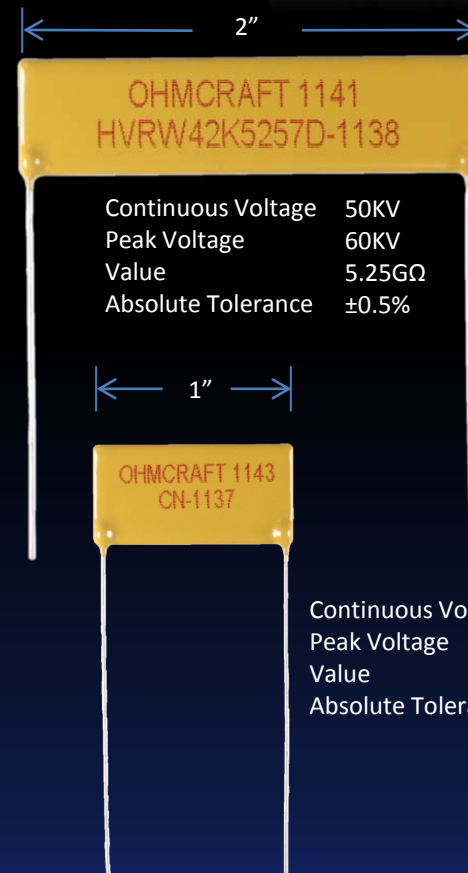
Ohmcraft had parts in at least 3 instruments



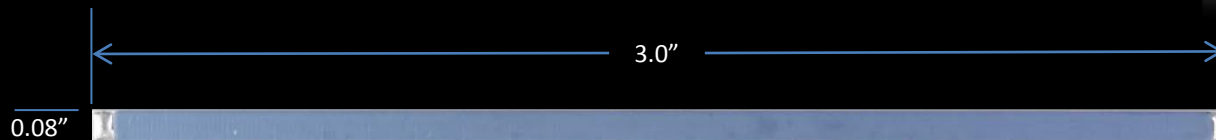
High Voltage Leaded Resistors



1G Ω to 1K Ω Decade Divider
Ratio Tolerance 0.25%
TCR Tracking 25ppm/ $^{\circ}\text{C}$
Voltage 1000V



Surface Mount Resistors



| | |
|--------------------|--------------|
| Continuous Voltage | 50KV in oil |
| Value R_T | 20G Ω |
| Absolute Tolerance | $\pm 1\%$ |
| VCR | <0.5ppm/V |



HVC2010M1203FB
120K Ω
2500V 20ms Pulse
3 Joule

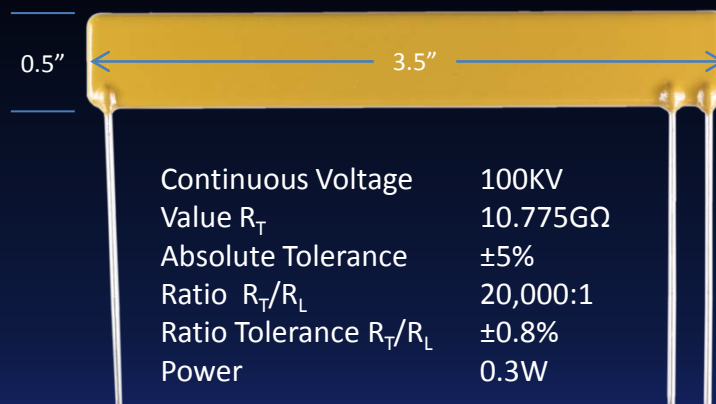
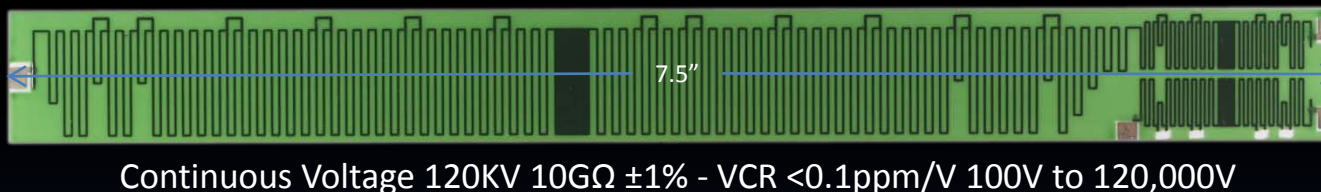
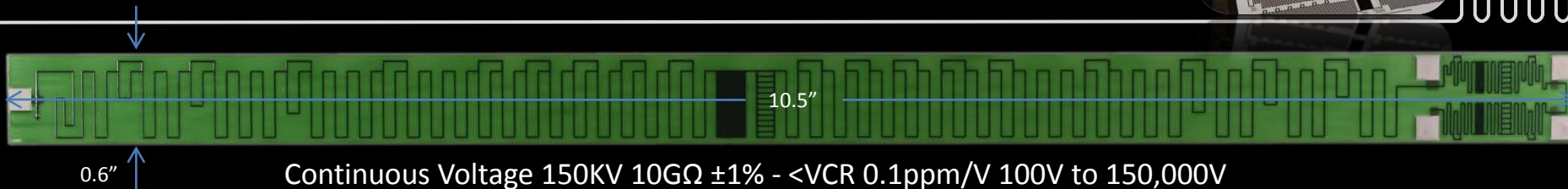
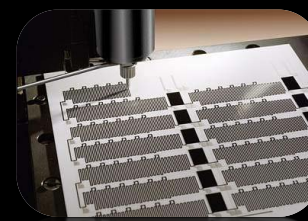


HVC3508H3306FB
330M Ω
10KV



HVC2510K8756FT
875M Ω
8.5KV
VCR <3ppm/V

150KV Resistor



Lot Acceptance Testing



7



Typical LAT Data

| | |
|------------------------------|-----------------|
| Thermal shock | 0.02% |
| Low temperature operation | 0.01% |
| Short time overload | 0.05% |
| High temperature exposure | 0.01% |
| Resistance to soldering heat | 0.05% |
| Moisture resistance | 0.01% |
| Life Qualification | 0.01% to 0.15%* |

* High wattage parts can shift more than others

Microopen at Work



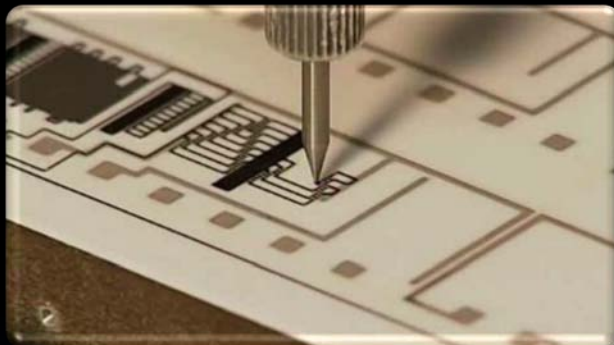
Product Gas heater

Substrate Quartz

Flowable Material Pt ink

Application Gas chromatography

Line Width 875µm



Product Endotracheal tube

Substrate DEHP-free PVC

Flowable Material Polymeric Ag ink

Application Bio-impedance

Line Width 625µm



Product Conical/Square balloon

Substrate Urethane

Flowable Material Polymeric Ag ink

Application Ablation

Line Width 250µm

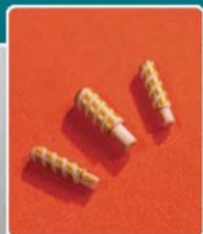


Product Electrocauterization Probe

Substrate 7 FR, 96% Alumina ceramic, bullet shaped

Flowable Material Gold-filled cermet conductive ink

Pattern Bipolar helix, 250 micron line width



Product Immersion heater

Substrate Stainless steel

Flowable Material Dielectric, Ag conductor and resistor inks

Application Cauterization

Pattern 6 layer pattern with helical heater, 375µm line width, 1125µm pattern width



***Introducing Dave McCormick to Discuss
Considerations in the Selection of
High Voltage Cables and Connectors***



Space Level Interconnect Components

Dave McCormick

Director of Engineering

Teledyne Reynolds, Inc

5005 McConnell Ave.

Los Angeles, CA 90066

- ***High Voltage Interconnections***
- ***High Voltage Wire***
- ***Hybrid Cable Assemblies***
- ***Ceramic to metal Brazed Interconnects***
- ***High Voltage Mica Capacitors***

Space Level Products

Agenda

- Applications
- Definition of space level component
- Connector features
- Voltage rating
- Environment
- Configuration
- Processes
- Testing
- Data
- Types of Interconnects
- Application Notes (Technical Bulletins)
- Capacitors

Typical Applications

- Propulsion
 - Electrostatic Ion Thrusters
 - Electromagnet Ion Thrusters
 - Electro thermal (Arcjet) Thrusters
 - Electrodynamic Tethers
 - Pulse Detonation Engines
 - Spark Igniters
- Mass Spectrometers
- Radar
- Detectors
 - Photomultiplier tubes (PMT)
 - Microchannel Plates (MCP)
 - Avalanche Photo Diodes (APD)

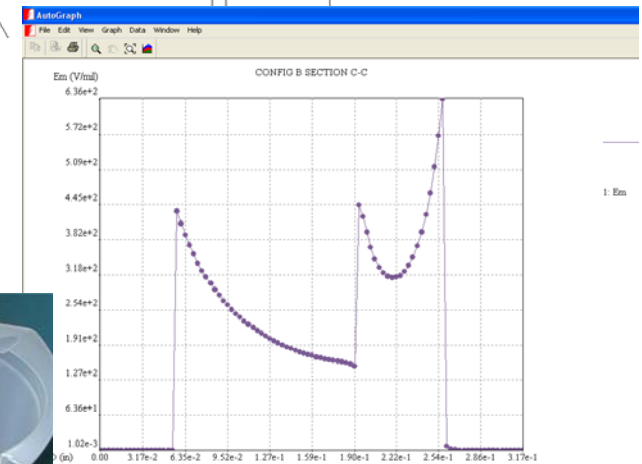
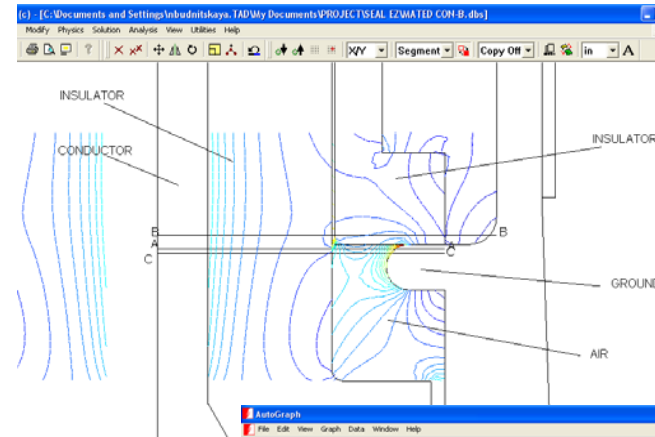


What constitutes a 'space level' HV connector?

- Reliability
 - Lot traceability
 - Screening
 - Supporting data
- Vented / non vented
- Low outgassing (TML <1%; CVCM <0.1%)
- High purity insulation
- Hermetic – some cases
- Red plague resistant (silver plate thickness) – *sometimes*
- Non magnetic metals
- No pure tin

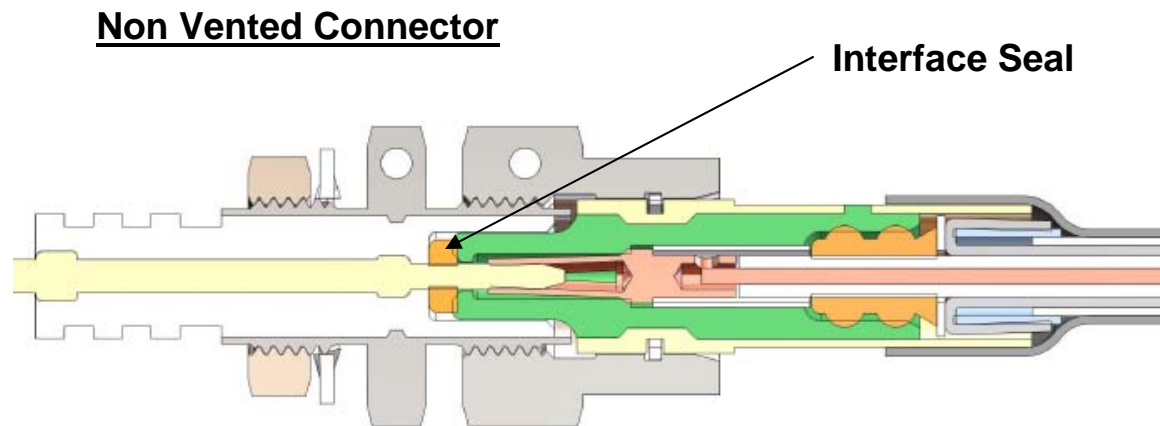
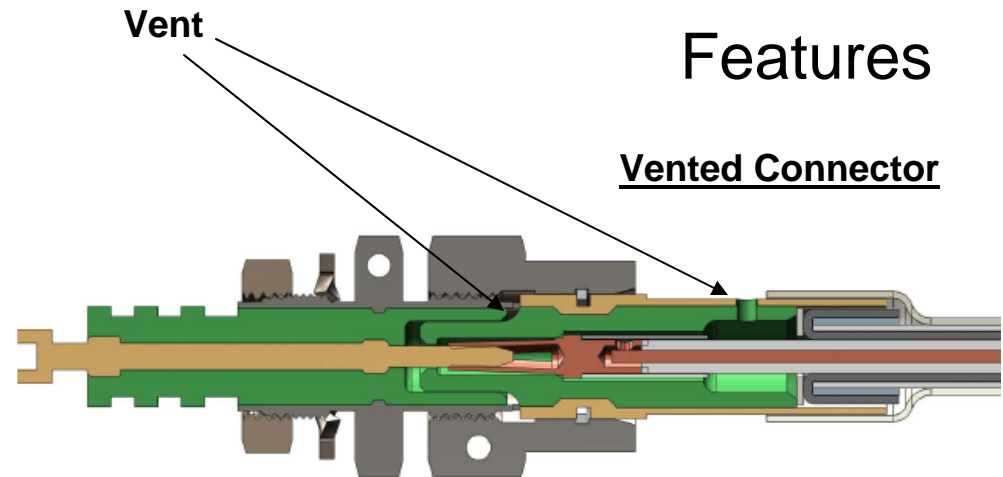
How is this achieved?

- Knowing the induced voltage stress & margin
 - Electrostatic analysis & test data
- Knowing the characteristics of the material & process used
 - Laboratory / verification methods
 - Database of materials & processes
 - Outgassing
- Solid modeling design & analysis
- High voltage testing
 - Dielectric withstanding voltage (DWV)
 - Insulation Resistance
 - Corona / Partial Discharge
- Qualification tests



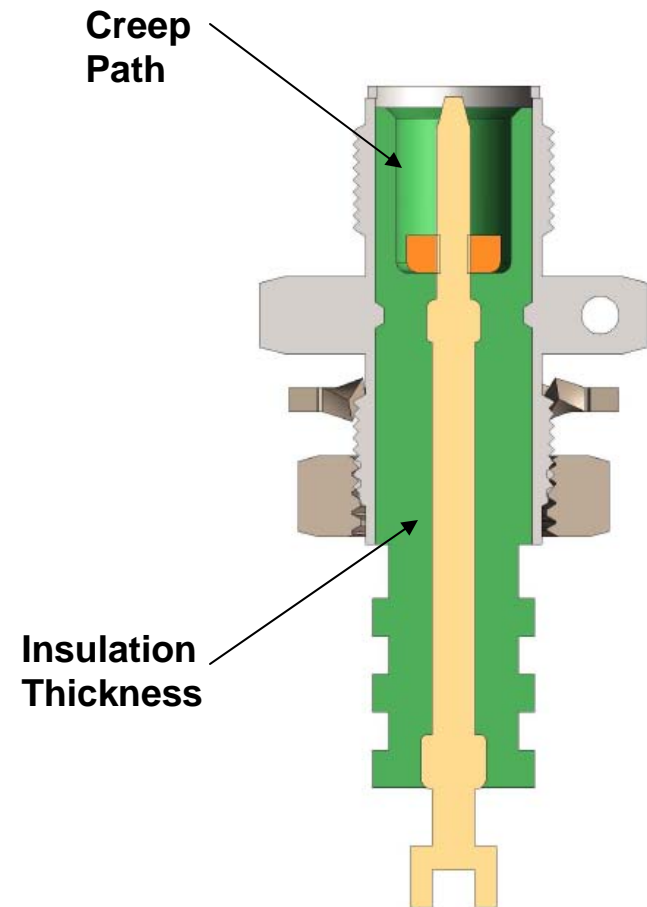
- Configuration
 - Single pin
 - Multi-pin
 - Shields
- Vented vs. non vented
 - Paschen curve
- Voltage rating
 - Margin of safety
- Environments
 - Natural
 - Induced
- Hermetic

Connector Features



Connector Voltage Rating

- Type of insulation
 - Temperature capability
 - Dielectric Strength
 - Most polymers are measured at 60Hz AC
 - AC to DC: 1:2 to 1:4
 - Volume Resistivity
 - Low volume resistivity / higher leakage current
 - TML & CVCMM
 - Some are on NASA website others are tested
- Thickness of insulation surrounding conductors
- Edge effects
 - Sharp corners induce high voltage stresses
 - $\sim d/D$
- Air voids – source of ionization
 - Common
 - Induced by processes
- Creep path
 - Interface
 - Substrates
- Interface compression ('non' vented connectors)



Environmental

- Pressure
 - Sea level / vacuum / Paschen curve
- Temperature
 - Operating
 - Storage / Non Operating
 - Dwell times
- Humidity / Moisture
- Hermeticity: Specify differential pressure condition and the acceptable leak rate.
- Thermal Cycling: Specify extremes, dwell time, rate of change and number of cycles.
- Dielectric Fluids and Gases:
 - Fluids should be specified with the degree of exposure.
 - Exposure can range from vapors, to splash, to total immersion.
 - Specify whether or not the connector is required to seal the dielectric from escaping.
- Radiation: Specify the type, level and dose rate

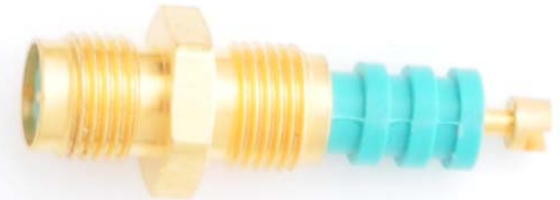


Connector Mechanical

- Threaded / Bayonet
 - Mating cycles
- Material - metallic
 - Non magnetic
- Finishes
 - Plating (if not stainless)
 - Red plague
- Durability
 - Consider plating



Gold Plated Brass 600



Stainless 600 Series



Connector Processes

- Soldering
 - J STD 001E/S & Company standards
 - Special attention to sharp corners /excessive flux
- Material analysis
 - Surface adhesion / bonding
 - Voltage withstanding proportional to adhesion strength
- Rubber & plastic molding
 - Voids
- Ceramic to metal brazing
- Altitude – vacuum testing
- Corona testing
- Encapsulation
- Wire – reel to reel cable screening
 - Detecting voids / contamination



Connector Testing & Validation

- Dielectric Withstanding Voltage (See Table)
 - Leakage current
- Insulation Resistance
 - 500VDC; varies depending on insulation thickness
 - Before and after DWV
- Circuit Resistance
 - Not just continuity; to assure all terminations are good
- Real time X ray
- Space simulation
- Screening
 - Thermal cycling
 - Partial discharge

| DC Rating | Test Voltage Percent of Rating |
|------------------|-----------------------------------|
| 0 – 12 kVDC | 150% |
| 12.1 – 20 kVDC | 140% |
| 20.1 – 30 kVDC | 130% |
| ≥ 30.1 kVDC | 120% |



Connector Data

- Test Reports
- Material & Process Data List
- X Ray
- Lot control



X Ray Screen

| TELEDYNE REYNOLDS, INC. A Teledyne Technologies Company | | PART NUMBER: 178-6027 | | SHEET 1 OF 1 | | |
|---|--|-----------------------------------|---------|---|-------------------|----------------------|
| CAGE CODE 99747 | | SERIES: 6005 | | REV: _____ | | |
| QUALITY CONFORMANCE INSPECTION | | JOB ORDER NO: _____ | | SERIAL NO / DATE CODE: _____ | | |
| TEST DATA | | WORK ORDER NO: _____ | | CUSTOMER: _____ | | |
| TEST PROCEDURE TITLE: _____ | | TEST PROCEDURE NO: _____ | | REV: _____ | | |
| TEST TECH / INSPECTOR: _____ | | ENGINEER (WHEN APPLICABLE): _____ | | DATE: _____ | | |
| REMARKS: _____ | | QTY SUBMITTED: _____ | | ACCEPTED: <input type="checkbox"/> IN <input type="checkbox"/> CUST | | |
| | | QTY ACCEPTED: _____ | | REJECTED: <input type="checkbox"/> _____ | | |
| TEST RESULTS MUST BE RECORDED IN UNITS OF MEASUREMENT SPECIFIED | | | | | | |
| PROCEDURE PARAGRAPH NUMBER | PARAMETER DESCRIPTION | REQUIREMENT MINIMUM | MAXIMUM | UNITS | ACTUAL READING | TECH / INSP STAMP |
| | VERIFY OUTGASSING DATA SHEET IS ATTACHED FOR THE FOLLOWING MATERIALS/PARTS: | | | | | |
| | KYNAR (E595-09-025) | | | | | |
| | FEP 100 (167-2896) (E595-09-014) | | | | | |
| | DIALYL PHTHALATE (E595-09-001) (E595-09-002) | | | | | |
| NOTE 4 | DIELECTRIC WITHSTANDING VOLTAGE, HIPOUT AT 7.5 KVDC FOR ONE MINUTE AT AMBIENT CONDITIONS. ELECTRICAL LEAKAGE NOT TO EXCEED _____ | | 10 | MICROAMPS | PASS/FAIL | |

TELEDYNE REYNOLDS, INC.
A Teledyne Technologies Company

Test Data Sheet

Material List PN: 178-5996

| TRI PIN | Description | Material | Finish | Comments |
|------------|--|---|---|-----------------|
| 178-5996 | SINGLE ENDED PLUG CABLE ASSEMBLY, SPACE RATED, 6005 SERIES | MARKEM 7906, BLACK | | |
| R-500-4 | INK, EPOXY, BLACK | SINCOB40 SOLDER | | |
| 178-2881-1 | SHRINK TUBING (ID SLEEVE) | CLEAR KYNAR (AW AMS-DTL-23053/8) | | MEETS ASTM E595 |
| 167-2896 | HIGH VOLTAGE COAXIAL CABLE TYPE "L" Ø.050 CORE FEP | CENTER: 15 STRANDS OF 38 AWG COPPER WIRE PER MIL-C-17 INNER INSULATION: FEP 100, NATURAL BRAID: COPPER BRAID PER MIL-C-17 JACKET: FEP 100, WHITE | CENTER: SILVER PLATED (AWW ASTM B258) BRAID: SILVER PLATED (AWW ASTM B258) | MEETS ASTM E595 |
| 178-2881 | SHRINK TUBING | CLEAR KYNAR (AW AMS-DTL-23053/8) | | MEETS ASTM E595 |
| 167-3541-1 | U-SLEEVE | COPPER (AWW ASTM B152, COLD ROLLED ANNEALED) | SULFAMATE NICKEL (AWW SAE AMS-QQ-N-280 CLASS 2, .0001-.0003 THK) | |
| 167-4112 | WASHER | 301 STAINLESS STEEL PER QQ-S-756 | PASSIVATED PER QQ-P-35, TYPE VI OR VII | |
| 178-4924 | SPACER INSULATOR | ULTEM 1000 (ASTM D 5285) | | MEETS ASTM E595 |
| 167-4502 | CONTACT, 600 SERIES | COPPER ALLOY (AWW ASTM B196, UNS C17200 OR C17300, TEMPER T004) | COPPER UNDERPLATE (AWW SAE AMS 2416, .0001-.0002 THICK FOLLOWED BY GOLD PLATE (AWW ASTM B488, TYPE 3, CODE C, .000050-.00010 THICK) | |
| 167-4534 | RETAINING RING | BERYLLIUM COPPER (AWW ASTM B197, UNS C17200 BAR-ROUND, TEMPER T004 OR (AWW ASTM B194, TEMPER T002) | | |
| 167-7054 | COUPLING NUT | 303 STAINLESS STEEL (AWW ASTM-A-582, CONDITION A, OR 303Se (AWW ASTM-A-581) | PASSIVATED PER QQ-P-35 | |
| 167-4605 | MOLDED ASSY | MOLD MAT'L: DIALYL PHTHALATE PER ASTM D 5548, TYPE 500 | | MEETS ASTM E595 |
| 167-4600 | BODY, 600 SERIES | BRASS 1/2 HARD PER QQ-B-625 COMP. 22 (ALLOY 360) | GOLD PLATE (AWW SAE AMS 2422, .000050 IN MIN THICK, OVER COPPER SUBPLATE (AWW SAE AMS 2416, .000100 IN MIN THICK, | |

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Material & Process Data List

Space Level Interconnects

| Model | Cond | Style | Shell Type | Coupling | Insulation Type | Voltage DC | Shield |
|---------|------|------------|--------------------|---------------------|-----------------|------------|--------|
| 600 | 1 | Plug | Brass/Au | Threaded | Plastic | 5kV | Yes |
| 600 | 1 | Plug | CRES | Threaded | Plastic | 5kV | Yes |
| 600 | 1 | Receptacle | Brass/Au | Threaded | Plastic | 5kV | Yes |
| 600 | 1 | Receptacle | CRES | Threaded | Plastic | 5kV | Yes |
| 600 | 1 | Receptacle | CRES | Threaded | Ceramic | 5kV | Yes |
| 600 | 1 | Adapters | Brass/Au | Threaded | Plastic | 5kV | Yes |
| 311 | 1 | Plug | Brass/Au | Bayonet | Plastic | 15kV | Yes |
| 311 | 1 | Receptacle | Brass/Au | Bayonet | Plastic | 15kV | Yes |
| Pee Wee | 1 | Plug | N/A | Push/Pull | Plastic | 12kV | No |
| Pee Wee | 1 | Receptacle | N/A | Push/Pull | Plastic | 12kV | No |
| Pee Wee | 1 | Receptacle | N/A | Push/Pull | Ceramic | 12kV | No |
| Cable | NA | NA | N/A | NA | FEP/PFA | 18kV | Y/N |
| 1807 | 7 | Plug | Electroless Nickel | Threaded or Bayonet | Silicone | 15kV | Y/N |
| 1807 | 7 | Receptacle | | | Plastic | 15kV | Y/N |

Cable – Wire

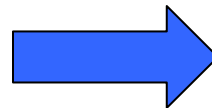
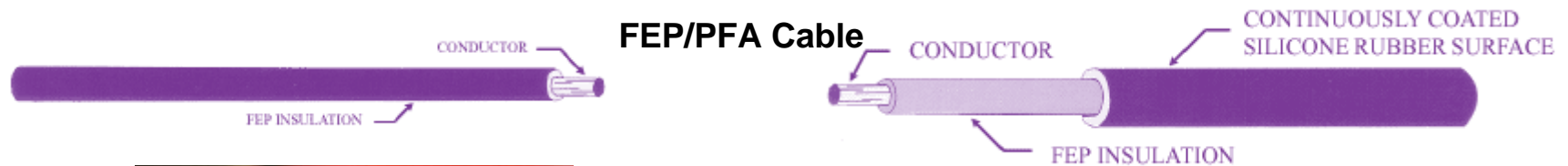
Materials

| Property | FEP | PFA | Silicone |
|-----------------------------|------------------|------------------|---------------|
| Specific Gravity Nom | 2.15 | 2.14 | 1.15-1.38 |
| Dielectric Strength (V/mil) | 500 | 500 | 575 - 700 |
| Dielectric Constant- Nom | 2.1 | 2.0 | 3.6 |
| Abrasion Resistance | Excellent | Excellent | Fair |
| Flame Retardant Properties | Excellent | Excellent | Excellent |
| Flexibility | Very good / size | Very good / size | Excellent |
| Temperature* | -70C to +200C | -70C to +200C | -65C to +200C |
| Resistance to Chemicals | Excellent | Excellent | Fair to good |

****Insulation resistance vs. high temperature***

Cable - Wire

| Insulation Type | Surface | Precoat | Environment |
|---------------------|---------|----------|--------------------------------------|
| FEP/PFA | None | None | Non potted |
| FEP/PFA | Etched | None | Epoxy/polyurethanes / some silicones |
| FEP/PFA | Etched | Silicone | Silicone |
| Silicone | None | None | Non potted or silicone |
| Dual Layer Silicone | None | None | Non potted or silicone |



Semicon Layered Cable

Application Notes

Technical Bulletins

| | |
|----------|--|
| TB10-024 | Allowable Wire Bend Radius |
| TB10-025 | When to use plain FEP, etched FEP and silicone coated FEP |
| TB10-026 | Soldering (recommended irons or wattage) 600 Series |
| TB10-027 | Soldering (recommended irons or wattage) Pee Wee Series |
| TB10-028 | Connector interface maintenance 600 Series |
| TB10-029 | Connector interface maintenance Pee Wee Series |
| TB10-030 | Mating Pee Wee Connectors |
| TB10-031 | Replacing 600 interface seals |
| TB10-032 | Mating 600 Series Connectors |
| TB10-033 | Post baking |
| TB10-034 | Mounting guidelines for Pee Wee receptacle |
| TB10-035 | Mounting / retaining of Pee Wee plug cable assemblies |
| TB10-036 | Surface quality of high voltage insulators |
| TB10-037 | Packaging and storing of space level connectors |
| TB10-038 | Space Level Non Metallic Materials - Properties / Plastic & Rubber |
| TB10-039 | Ink Properties/Ink/Shrink Sleeves |

HV Mica Capacitors

- Mica paper 0.018 – 0.05 mm (0.007 - .002 inch?)
- Wound with capacitor grade aluminum foil and epoxy impregnated
- 50pF to 5micro F
- 2kVDC – 50kVDC
- -55C to +125C
- White paper
 - Reliability & Design Considerations HV Mica Capacitors
 - Life Test / Reliability Results HV Mica Capacitors



High Voltage Mica Capacitors

| Rated DC Voltage (kV) | DC Test Voltage (kV) % of Rated |
|-----------------------|---------------------------------|
| 0 to 8.0 | 200 |
| 8.1 to 10.0 | 175 |
| 10.1 to 12.9 | 150 |
| 12.1 to 20.0 | 140 |
| 20.1 to 30.0 | 130 |
| 30.1 to 45.0 | 120 |
| 45.1 and up | 110 |

Note: some testing in the higher voltage regions will warrant immersion of the capacitor under test into a dielectric fluid or gas to prevent flashover from one termination point to another. This is dependent upon the form factor of the device under test and room ambient conditions such as relative humidity.

Contacts

- Technical Service:
 - www.teledynereynolds.com
 - Technical Information Request / Technical Support Request
 - Home page; HV Wire & Cable; Legacy Group; Advanced Group
- Connector, wire & cable
 - Cesar Aldana
 - caldana@teledynereynolds.com
 - 310-823-5491 X359
 - Dave McCormick
 - dmccormick@teledyne.com
 - 310-823-5491 X232
- Capacitors
 - Jim McCoskey
 - jmccoskey@teledyne.com
 - 805-928-5866 X 11

***Introducing Eric Hertzberg
Discussing Physics-Based
Design and Engineering Principles for
High Voltage Insulation Systems***

***Life may not be fair but at least
physics provides a level playing field!***

High Voltage Design for Space Applications

Eric Hertzberg and Tom Sanders

*Lockheed Martin Advanced Technology
Center, Palo Alto CA*

2 Apr, 2012

Table of Contents

- **Fundamental concepts**
 - Introductory Comments
 - Concepts of Gas discharge
 - Paschen Curves
 - Electric Fields
 - Stages of Breakdown
 - Geometry and electric fields
 - Dielectrics
 - Testing
- **Practical Design Considerations**
 - Vacuum
 - Conductor Surfaces
 - Triple junctions
 - Insulator surfaces
 - Bulk Insulating Material
 - HV System Life Time
 - Conservative rules of thumb
- **Related Topics**
 - Conservative Rules of Thumb
 - Cable and Connectors
 - HV in Ambient Atmosphere
 - Dangers
- **Bibliography**

Fundamental Concepts

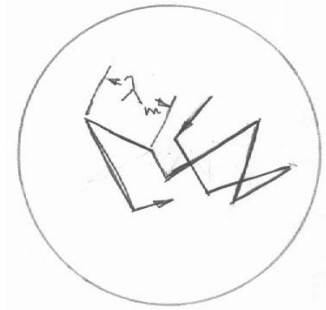
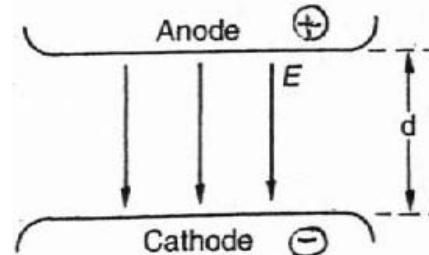
Introductory Comments

- A discussion of the behavior of Rarified Gasses in the Presence of Conductors, Insulators and Electric fields
 - DC conditions
 - AC: same physics, plus time domain effects
 - Usually aggravates DC effects
 - Field of interest is still evolving
 - Many variables
- Objective: design for zero discharge
 - Trouble-free design

Concepts of Gas Discharge, p1

- Imagine a Breakdown Test Apparatus

- Parallel plate capacitor
- Air in gap
 - “Gas dielectric”
 - No solid dielectric



- Gas behavior:

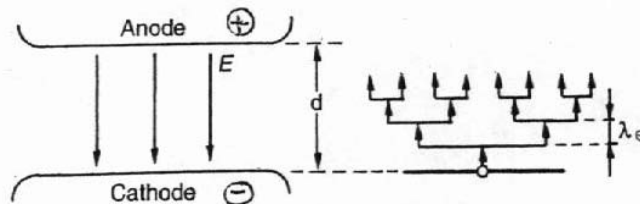
- Molecules move in random collisional motion (Brownian)
 - Average distance between collisions = Mean Free Path, λ_m
- Molecules can be ionized if
 - We impart energy, E , > molecular ionizing energy, E_{mi}
 - E_{mi} for $N_2 \approx 15$ eV
 - An electron is stripped off the molecule

- Apply high voltage (HV) across the capacitor

- Imposes an electric field between plates
 - Distribution of potential energy around conductive elements

Concepts of Gas Discharge, p2

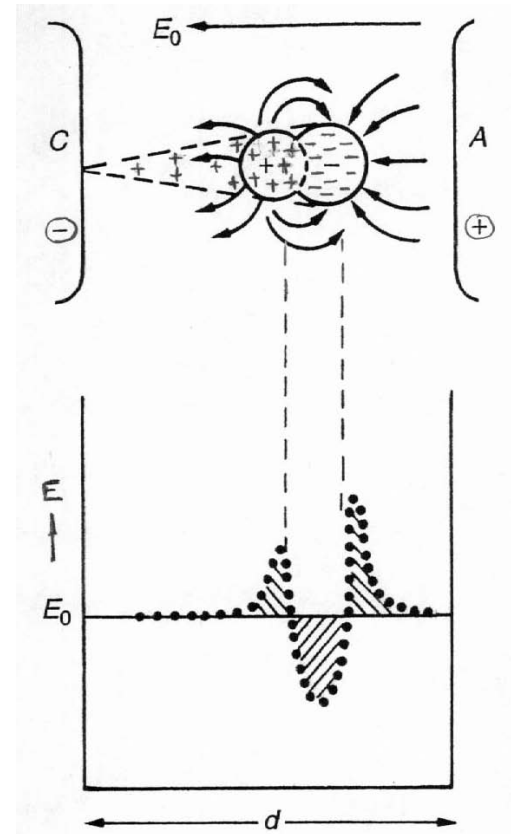
- Add a free electron into the capacitor gap
 - Electron has some λ_e in the gas environment
 - Attraction aligns λ_e with local electric field line toward + contact
 - Electron thermal energy \ll molecular ionization energy
 - Electron gains mean energy ϵ_{ef} from the electric field between collisions
 - ϵ_{ef} is proportional to λ_e
 - Convenient units: electron-volts
 - Apply to both + and – charges
 - If $\epsilon_{ef} >$ molecular ionization energy, ϵ_{mi}
 - Good probability of electron ionization of a gas molecule at the next collision
 - Once that happens we have 2 free electrons
 - Process repeats, causing an avalanche



Schematic representation from Kuffel, Zaengl and Kuffel

Concepts of Gas Discharge, p3

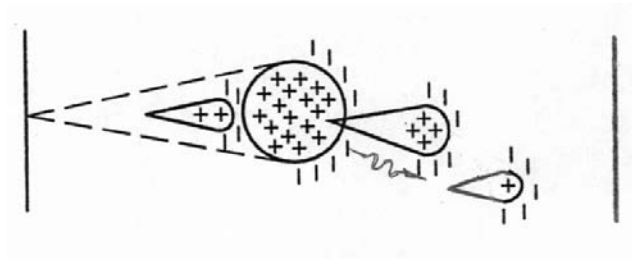
- Avalanche: onset of discharge:
 - Electrons are highly mobile (low mass)
 - Ions are ponderous (relatively high mass)
 - Electron cloud expands
 - From space charge repulsion
 - Dramatic field distortions
 - Dynamic conditions
 - Complex and random
- Dominant breakdown initiation mechanism
 - Kinetic electron ionization of ambient molecules
 - Townsend discharge



Plot from Kuffel, Zaengl and Kueffel

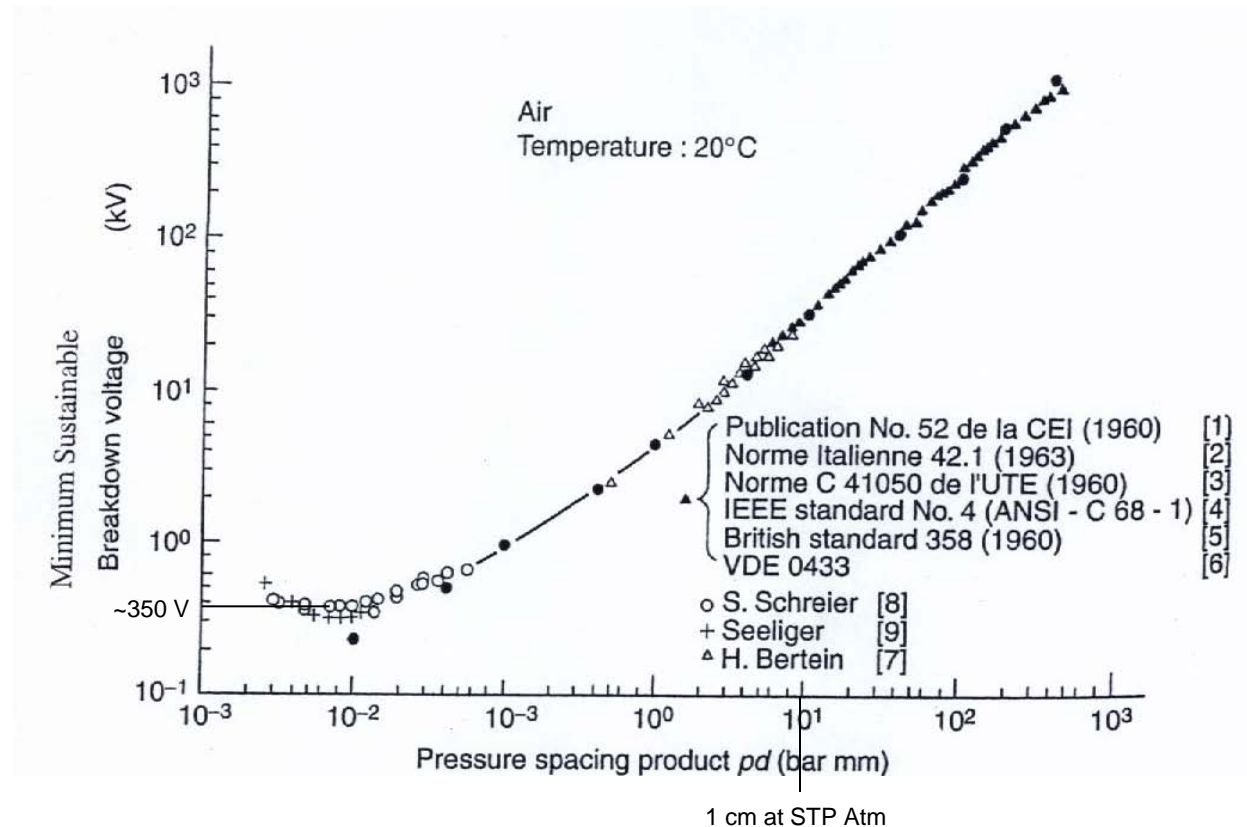
Concepts of Gas Discharge, p4

- When an electron is captured by an ion, or
- An excited molecule relaxes
 - Photon is emitted
 - Photons => photo ionization of gas => electrons
=>more avalanches



The Paschen Curve, p1

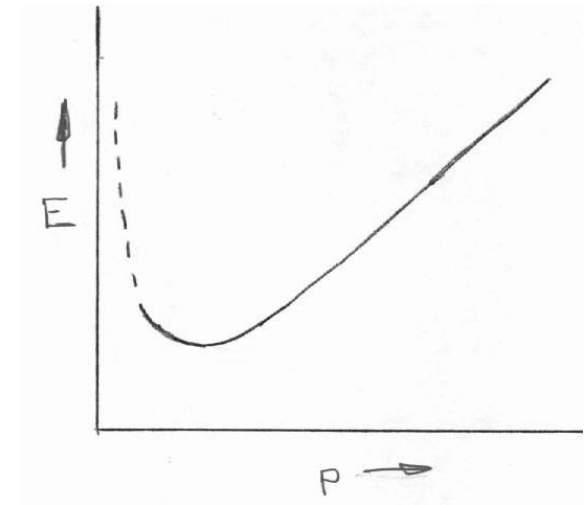
- Louis Carl Heinrich Friedrich Paschen
 - 1889, thesis work
- Why these units?
- Where is electric field?



Paschen curve for air at 20° C; solid dots are calculated using Townsend gas theory. Plot from Kuffel, Zaengl & Kuffel

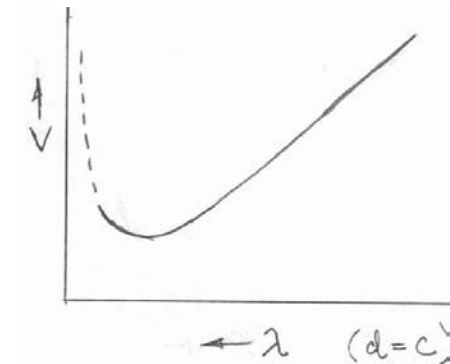
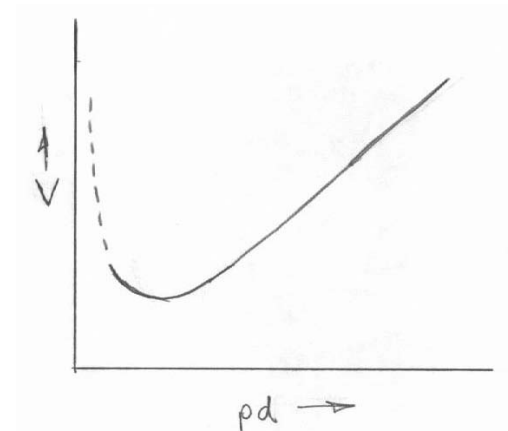
Paschen Curve, p2

- Paschen used a uniform field
 - So $E = V/d$
- Curve can be presented as E vs p
- “Minimum Sustainable Breakdown Voltage”, “ V ”
 - Challenging to define
 - Depends on measurement sensitivity



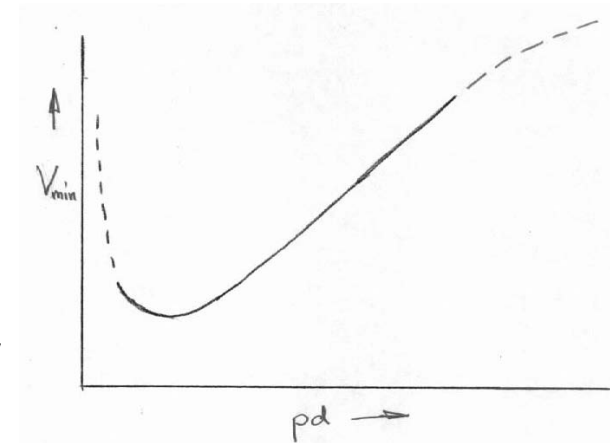
Paschen Curve, p3

- Gross oversimplification
 - 45° slope region
 - Consider d and p separately
 - With second parameter held constant
 - d : Ionizing field, $E_i = "V"/D = C$
 - Gas property
 - " V " proportional to d
 - p : Ionizing $E_{mi} = K$
 - Gas property
 - p proportional to $1/\lambda$,
 - " V " proportional to $1/\lambda$,
 - " V " proportional to p
 - Similarly for the product
 - Handy equation: $\lambda_m [\text{cm}] * p [\text{T}] = 5 \times 10^{-3}$



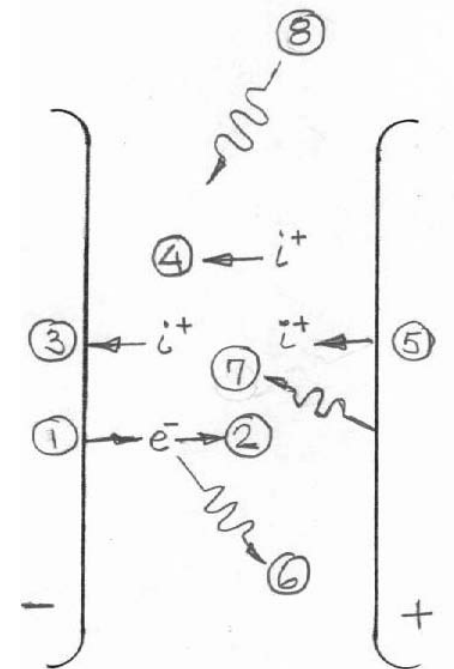
The Paschen Curve, p4

- Ends of curve
 - Minimum at low pd :
 - When $d \approx \lambda_{ei}$:
 - Most electrons strike anode
 - Few ionize gas molecules
 - Other mechanisms operate
 - » With lower ionization probability
 - “V” must rise
 - Right end
 - Other mechanisms take over
 - Curve rolls off to right



Paschen Curve, p5

- In reality, many ionizations sources:
 - By accelerated electrons
 1. Emitted from cathode (dominant initiation source)
 2. From avalanches (dominant continuation mechanism)
 - By discharge ions
 3. Striking cathode, releasing electrons
 4. Further ionizing gas molecules
 5. Emitted from anode (fields > ~20 kV/mm)
 - By photons
 6. Released by recombination processes
 7. From anode and cathode
 8. From environment (sun, other discharge, etc.)
 - Other sources of initiating electrons
 - Penetrating charged particles/cosmic rays
 - Intrinsic radio-activity of construction materials

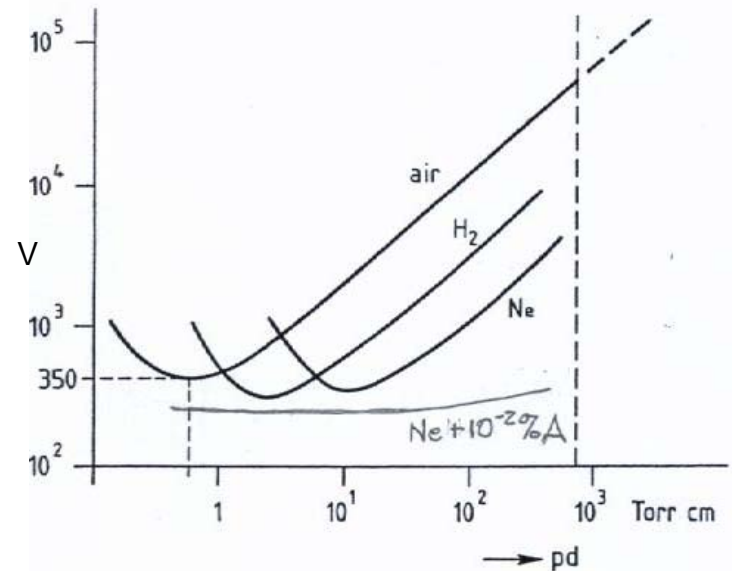


The Paschen Curve, p6

- Everything changes if any of following vary:

- Parallel field geometry
 - Typical electronics geometries => lower “V”
- Temperature
- Gas mixture
 - Particularly humidity in air
- Contact material

- Paschen is known because he controlled all the variables that would have destroyed his systematic results.



Plot from Kreuger

The Paschen Curve, p7

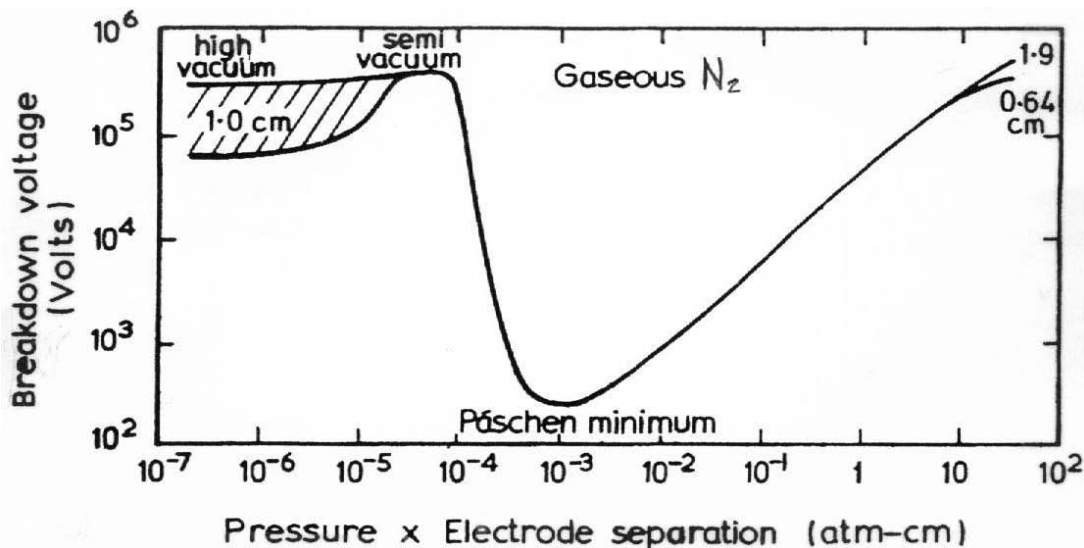
- Paschen curve doesn't go to high vacuum
- How does Paschen help us?
 - We test high HV PCBs in air before going to vacuum
 - Breakdown V in air is lower than in vacuum
 - Gas trapped in voids of bulk insulator material are governed by it
 - If unit is to operate through Paschen minimum
 - We are warned of hazard

Extending the Paschen Curve, p1

- High vacuum
 - Pressure is too low for gas ionization
 - Reduced background gas load remains
 - Clean vacuum systems: mostly H_2O , some N_2 , O_2 , CO_2 , etc
 - In our systems, also various outgassing products from HV materials
 - Un-polymerized monomers, various solvents, etc
 - Oxidation layers develop very fast in high vacuum
 - On clean metals
 - In seconds or faster for some metals
 - Even “noble metals” form a thin layer of oxides or ionic complexes
 - Partial discharge currents still develop with high voltage
 - Emitted electron pulses
 - From cathode
 - Photons are emitted from anode
 - Where emitted electrons strike
 - Pumping energy back into emission zone

Extending the Paschen Curve, p2

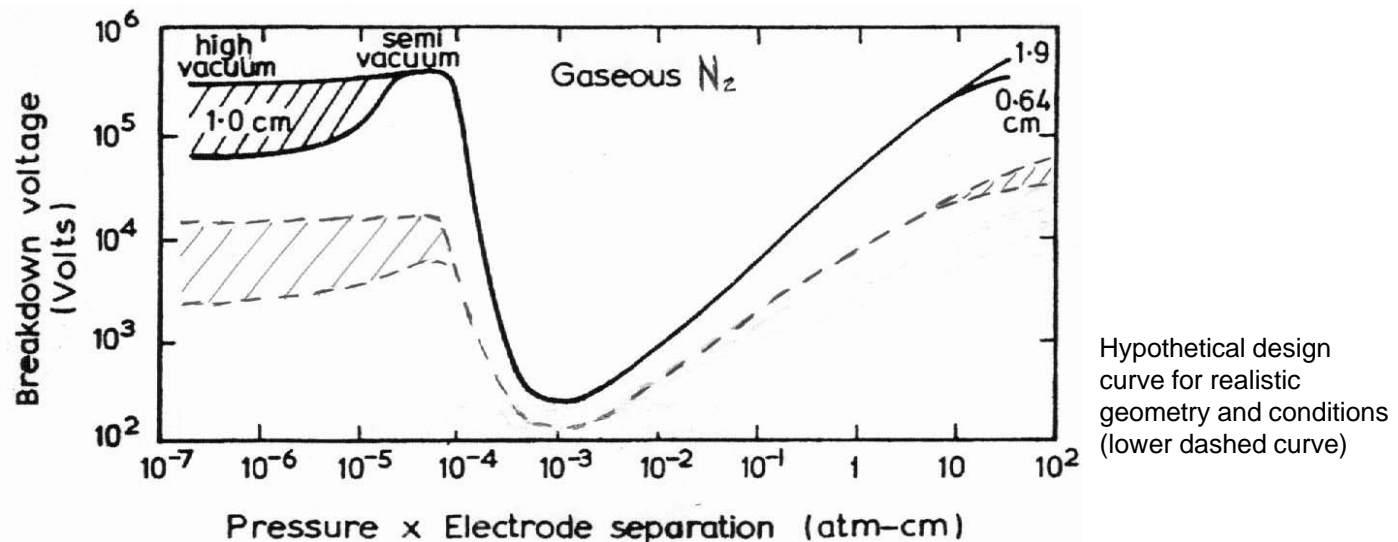
- High Vacuum (continued)
 - Multiple complex emission processes combine at Cathode, from
 - Sharp metallic μ -projections
 - Mechanism applies only at extremely high fields
 - Zones of non-metallic surface – mostly oxides, μ -projections
 - Adsorbates
 - Particulates, dust: metallic and non-metallic



From C. M. Cook
& A. H. Cookson,
IEEE Trans., E1-13,
Aug 1978

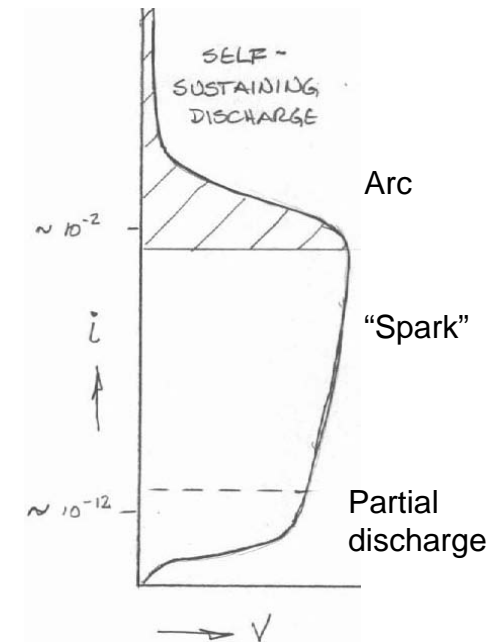
Extending the Paschen Curve, p3

- Can we use the extended Paschen curve for design?
 - NO
- Doesn't include
 - Distance dependencies
 - Geometry induced field intensifications
 - Dielectrics, etc



Stages of Breakdown, p1

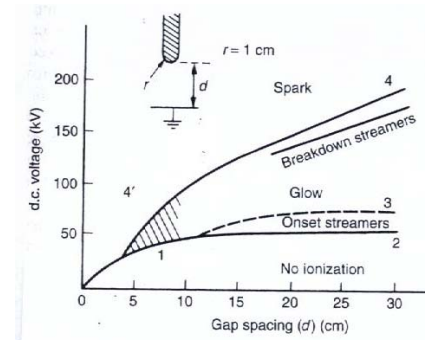
- Partial discharge - Summary
 - Pre run-away condition: charge bursts
 - Essential conditions
 - Sufficient electric fields
 - Initiating electron(s) leading to avalanches
 - Source of gas molecules
 - Feedback mechanisms
 - » UV photons
 - » Energetic ions
 - » Heat, releasing more gas and electrons
 - » High, irregular electric fields from avalanche charges
 - » Some dependence on cathode material
 - Generally persists only when $d \leq 5$ mm and $P \leq 1$ std atm



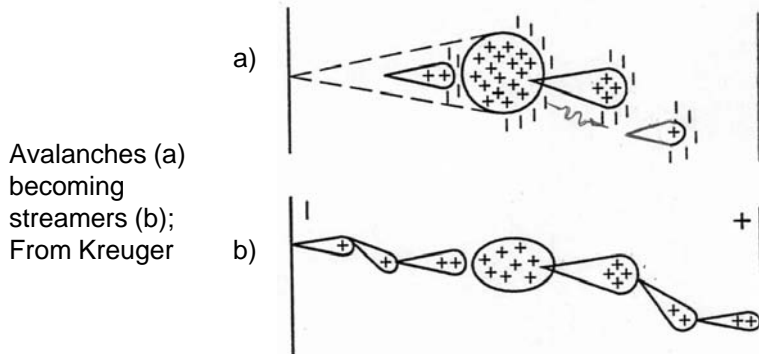
Over-simplified plot of discharge-spark-arc i-V plot.

Stages of Breakdown, p2

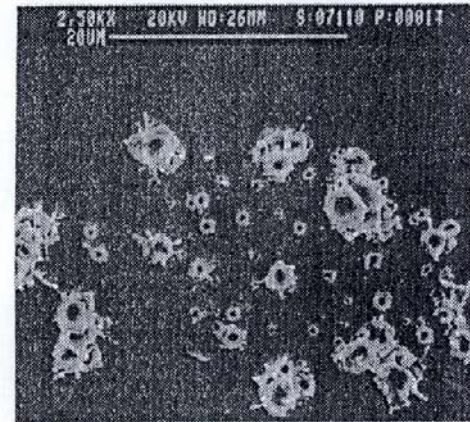
- “Sparks”
 - Multiple avalanches coalescing to produce streamers
 - Typically at higher pressures and larger gaps
 - May involve contaminant particles
 - Are electrically charged and become projectiles
 - Strike opposite electrode producing vapor and more projectiles, etc
 - Tend to pit conductors
 - Usually quench rapidly



More detailed diagram of various forms of breakdown;
From Kuffel, Zaengl and Kuffel



Avalanches (a)
becoming
streamers (b);
From Kreuger



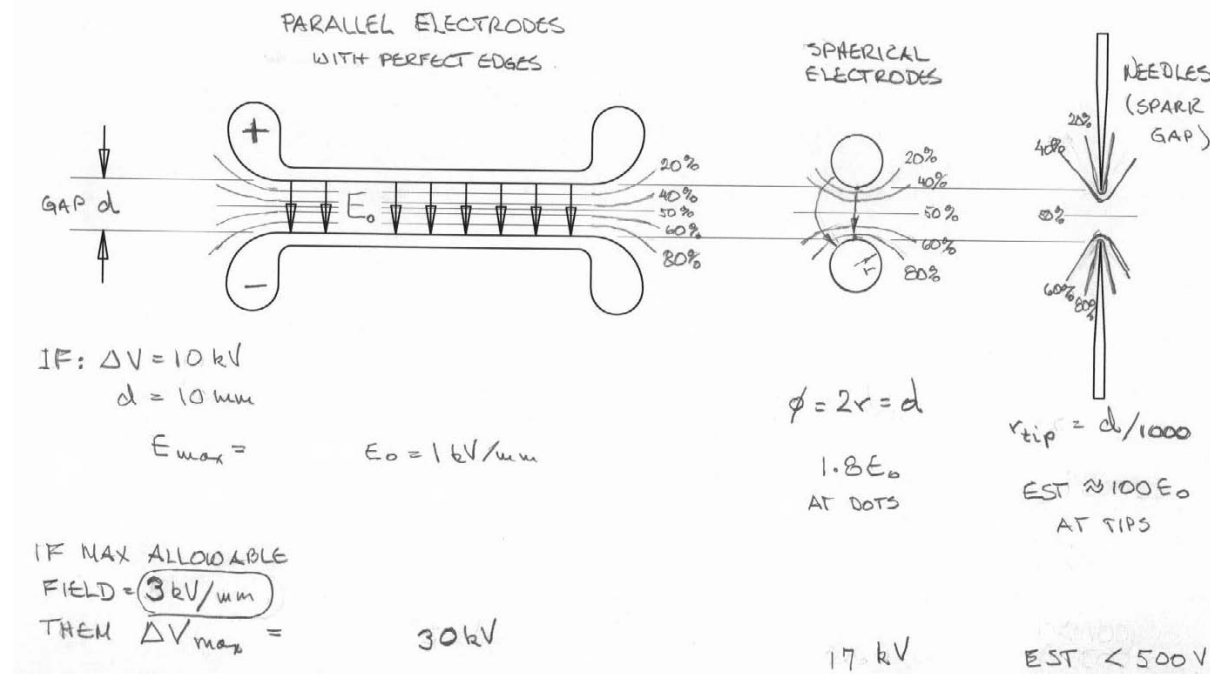
Electrode cratering from a spark;
Photo from Latham

Stages of Breakdown, p3

- Arcs
 - Plasma tube develops:
 - $i \uparrow$, Ω way \downarrow , sustaining $V \downarrow$
 - 5,000 to 20,000 °C
 - One author claims up to 10^8 A/cm²
 - Often hard to quench
 - Feed off of electrode material

Geometry and electric fields, p1

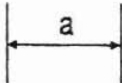
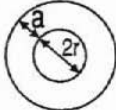
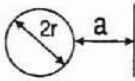
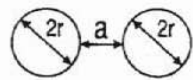
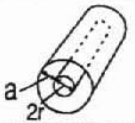

- Distribution of potential energy around conductive electrodes
 - Continuum of potentials
- Entirely geometry dependent



Geometry cannot be ignored!

Geometry and electric fields, p2

Max fields for convenient geometries

| Configuration | | Formula for E_{MAX} |
|---|---|--|
| Two Parallel Plane Plates |  | $\frac{U}{a}$ |
| Two Concentric Spheres |  | $\frac{U}{a} \left(\frac{r+a}{r} \right)$ |
| Sphere and Plane Plate |  | $0.9 \frac{U}{a} \left(\frac{r+a}{r} \right)$ |
| Two Spheres at a Distance from Each Other |  | $0.9 \frac{U}{a} \left(\frac{r+a/2}{r} \right)$ |
| Two Coaxial Cylinders |  | $\frac{U}{2.3 r \lg \left(\frac{r+a}{r} \right)}$ |
| Cylinder Parallel to Plane Plate |  | $0.9 \frac{U}{2.3 r \lg \left(\frac{r+a}{r} \right)}$ |


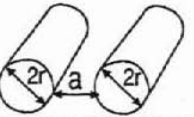
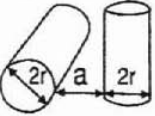
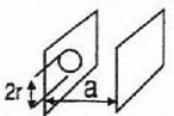
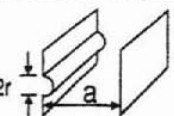
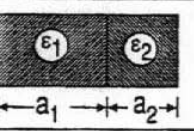
Notes:

1. Units: Volts & cm
2. $\lg = \log_{10}$
3. Factor 2.3 = $\ln(C)/\log_{10}(C)$

See website: [<http://www.nessengr.com/techdata/fields/field.html>] for field solver of these geometries.

Geometry and electric fields, p3

Max fields for convenient geometries, continued

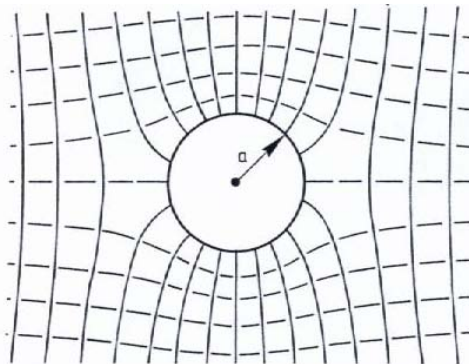
| | | |
|--|--|--|
| Cylinder Parallel to Plane Plate |  | $0.9 \frac{U}{2.3 r \lg \left(\frac{r+a}{r} \right)}$ |
| Two Parallel Cylinders |  | $0.9 \frac{U/2}{2.3 r \lg \left(\frac{r+a/2}{r} \right)}$ |
| Two Perpendicular Cylinders |  | $0.9 \frac{U/2}{2.3 r \lg \left(\frac{r+a/2}{r} \right)}$ |
| Hemisphere On One of Two Parallel Plane Plates |  | $\frac{3U}{a}; (a \gg r)$ |
| Semicylinder On One of Two Parallel Plane Plates |  | $\frac{2U}{a}; (a \gg r)$ |
| Two Dielectrics Between Plane Plates |  | $\frac{U \epsilon_{MAX}}{a_1 \epsilon_2 + a_2 \epsilon_1}$ <small>E_{MAX} OCCURS IN ZONE OF E_{MIN}</small> |

See notes on previous page

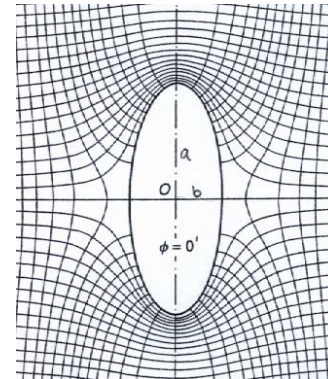
These results mostly exceed those for realistic geometries - handy for upper limits

Geometry and electric fields, p4

- Conductors in parallel field gas or vacuum gap
 - Conductor size \ll gap
 - $\epsilon_{\text{gap}} = 1$
 - Field intensifications:
 - Sphere $E_{\text{max}} = 3 \times E_0$
 - Rod $E_{\text{max}} = 2 \times E_0$
 - Ellipsoid (aligned with E_0), $E_{\text{max}} \gg E_0$

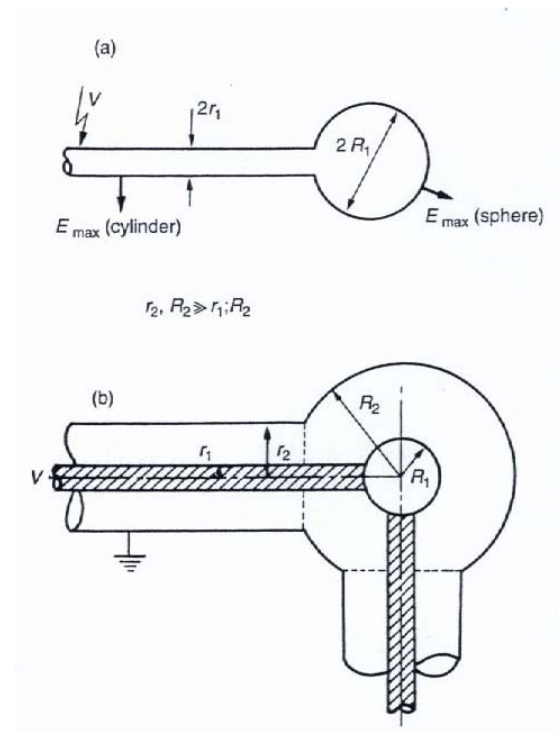


E_0



Geometry and electric fields, p5

- Wire bends intensify fields
- Use balls and rods having uniform surrounding electric fields

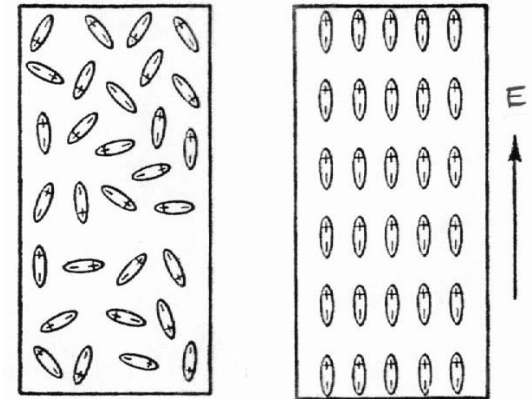


Constant field HV rod and ball hardware

Dielectrics, p1

- Dielectrics

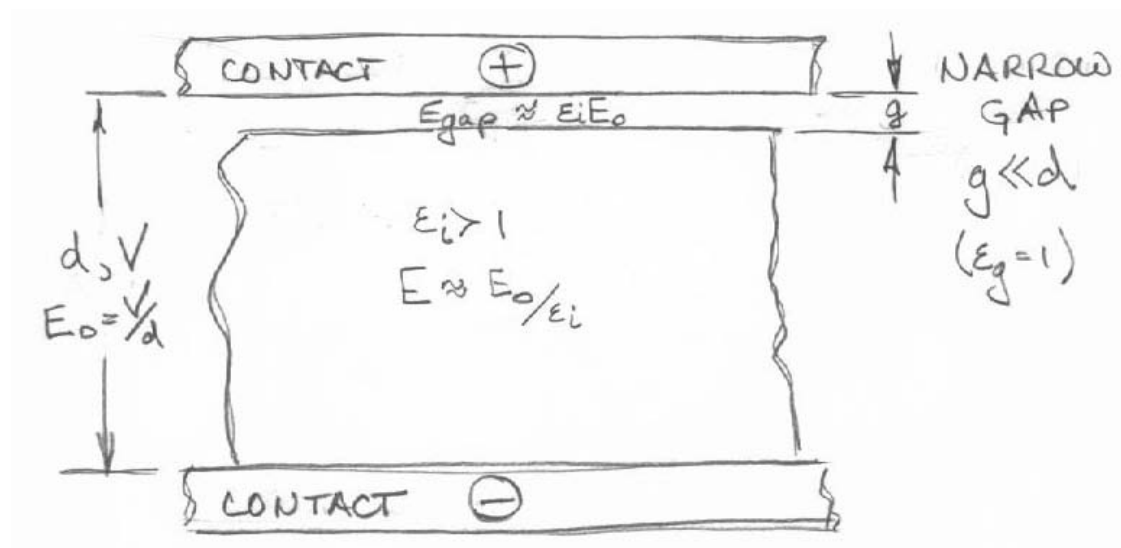
- Materials whose atomic dipoles can be aligned by the forces of an electric field
 - Called displacement charges
- Degree of susceptibility is called permittivity or relative dielectric constant, ϵ
 - $\epsilon_{\text{air}} = \epsilon_{\text{vac}} = 1$
 - $\epsilon_{\text{insulator}} = \text{typically 2 to 12 (some glasses to } \sim 30)$



Schematic of displacement dipoles in an insulator un-polarized (left) and unpolarized (right). From Introduction to Electric Fields by Walter E Rogers, 1954.

Dielectrics, p2

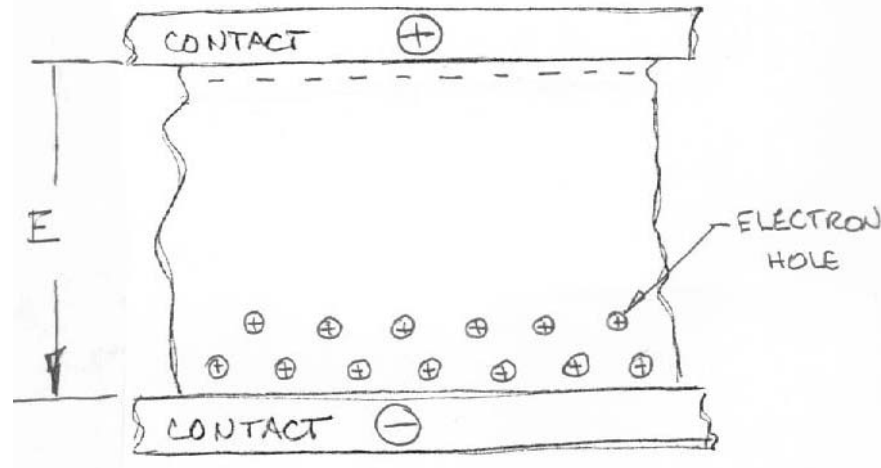
- Multiple dielectrics
- One solid and one gas dielectric
 - Displacement dipoles in dielectric
 - Reduce $E_{\text{dielectric}} \propto \epsilon_i$
 - Increase $E_{\text{gap}} \propto \epsilon_i$



Picture

Dielectrics, p3

- Dielectric Space Charge - DC
 - Electrons and holes are mobile
 - Not ions
 - Settling times depend on insulator bulk resistivity, σ_i , capacitance and geometry
 - V Polarity reversal can damage dielectric

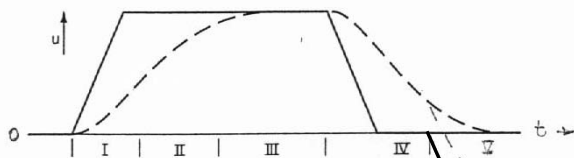
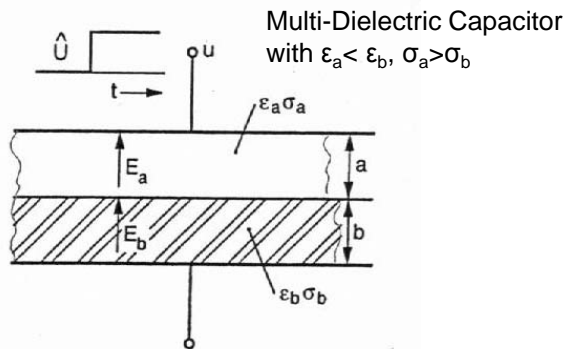


Dielectrics, p4

- Multi-layer dielectrics

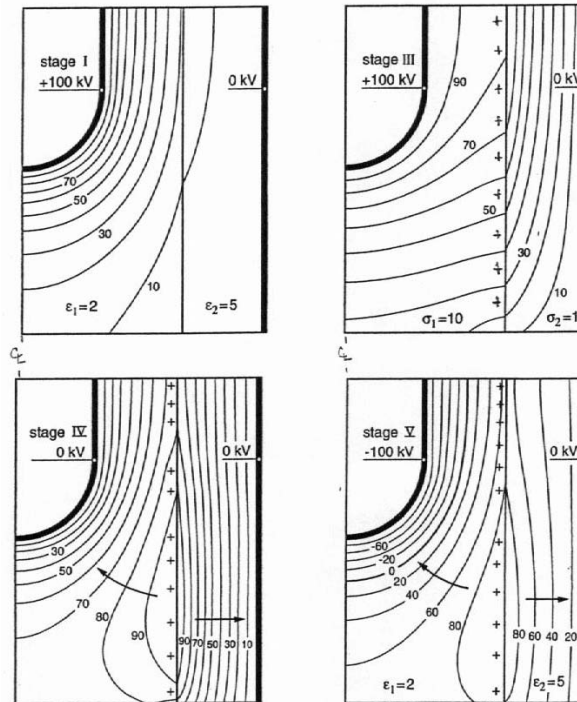
- Great benefits and potential hazards

- The end of a radiused center conductor in a grounded coaxial shell
 - Two dielectrics



Timeline of events:
Solid line = voltage;
Dashed = charge
at dielectric interface

- Can overstress dielectric



Field plots for four stages on timeline; field contours are 10 kV except for stage V; represent figures of revolution about centerlines (CL).

Contours
20 kV/line

Plots from Kreuger

Dielectrics, p5

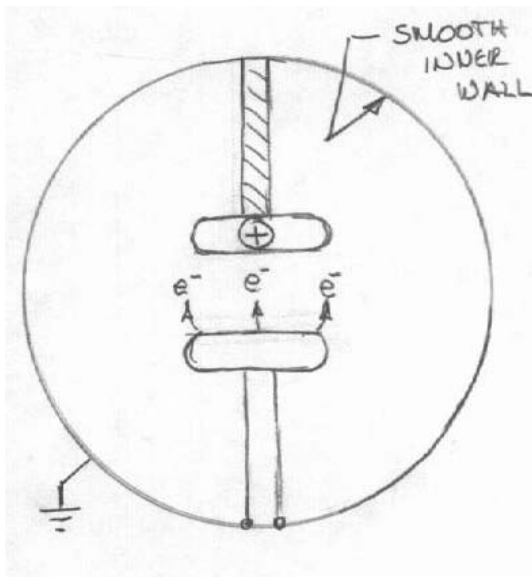
- DC Electric Fields with
 - No solid dielectric
 - Depend on conductor geometry only
 - Single solid dielectric filling field
 - Depend on bulk insulator dielectric constants, ϵ_i and conductor geometry
 - Multiple solid dielectrics filling field
 - Depends on ϵ_i 's, bulk insulator resistivities(σ_i) and geometry
 - Settling time constants at dielectric interfaces may be long
 - In the order of hours to a day
 - Solid dielectric plus gas dielectric
 - Depends on ϵ_i 's and σ_i , insulator surface resistivity (ρ_i) and geometry
 - ρ_i is often $\ll \sigma_i$
 - Due to adsorbates, contaminants, etc
 - Resistance = resistivity x area factor
 - » Area factor = (conductance path length) / (conductive area) = L/A

Reality

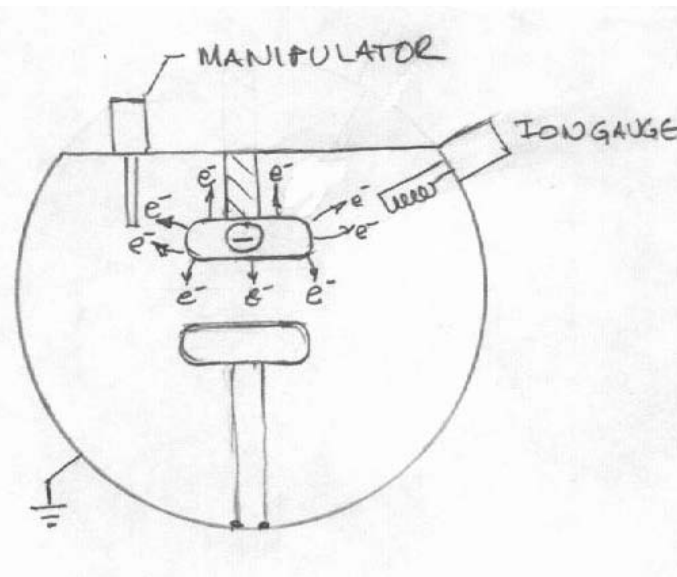
- In a perfect world:
 - Perfect: parallel electrodes, surface smoothness, cleanliness, etc
 - Electron emission field = 10^6 to 10^7 V/mm
 - 1000 to 10^4 kV/mm
 - kV/mm is unit of electric field used hereafter
 - Lifts a conduction band electron from its molecule into vacuum
 - Overcomes inter-atomic electric fields
- Real life in a conservatively designed unit:
 - 1 to 3 kV/mm will generally avoid breakdown
 - 10 kV/mm is very risky

Testing, p1

- If you test
 - Don't let the chamber participate
 - Use +HV if possible ($V < 20$ kV)



Valid Results



Invalid Results

Testing, p2

- Sensing Discharge

- Detection

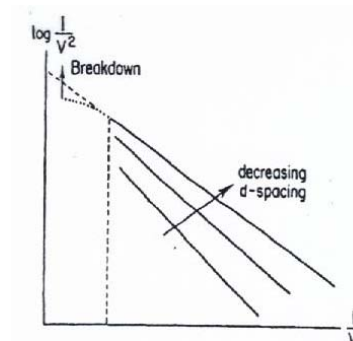
- CCD camera in a darkened room
 - Discharge noise pickup
 - Sometimes sound

- Measurement

- Sensitive charge pulse sensing equipment
 - Measure rate & pulse height distribution of charge pulses
 - » Order of peco-Coulombs thresholds
 - Fowler-Nordheim plots
 - Not applicable in presence of oxides
 - » Applicable on clean contacts only
 - » At extremely high voltages
 - Probably not useful

- During diagnostic tests

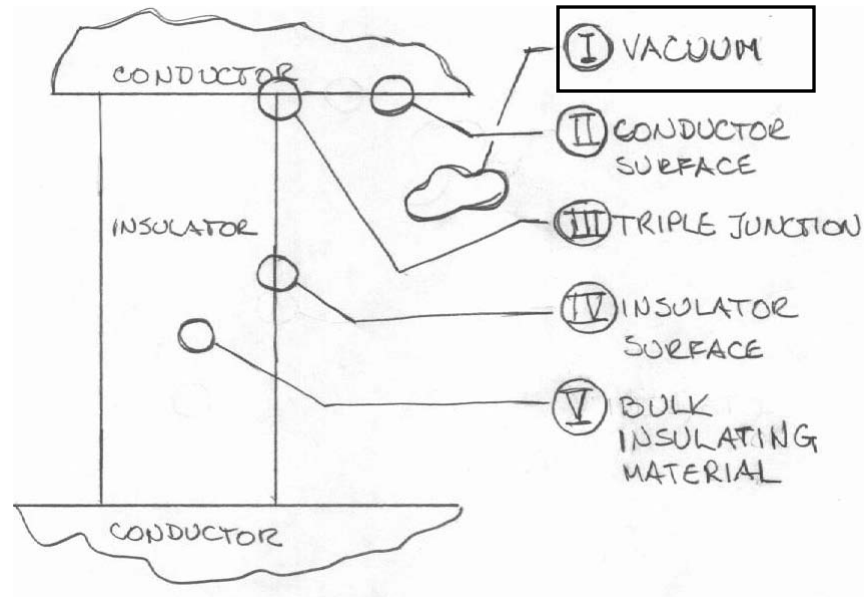
- Time constants reveal important clues



Fowler-Nordheim Plot
From Latham

Practical Design Considerations

I. "Vacuum", p1



“Vacuum”, p2

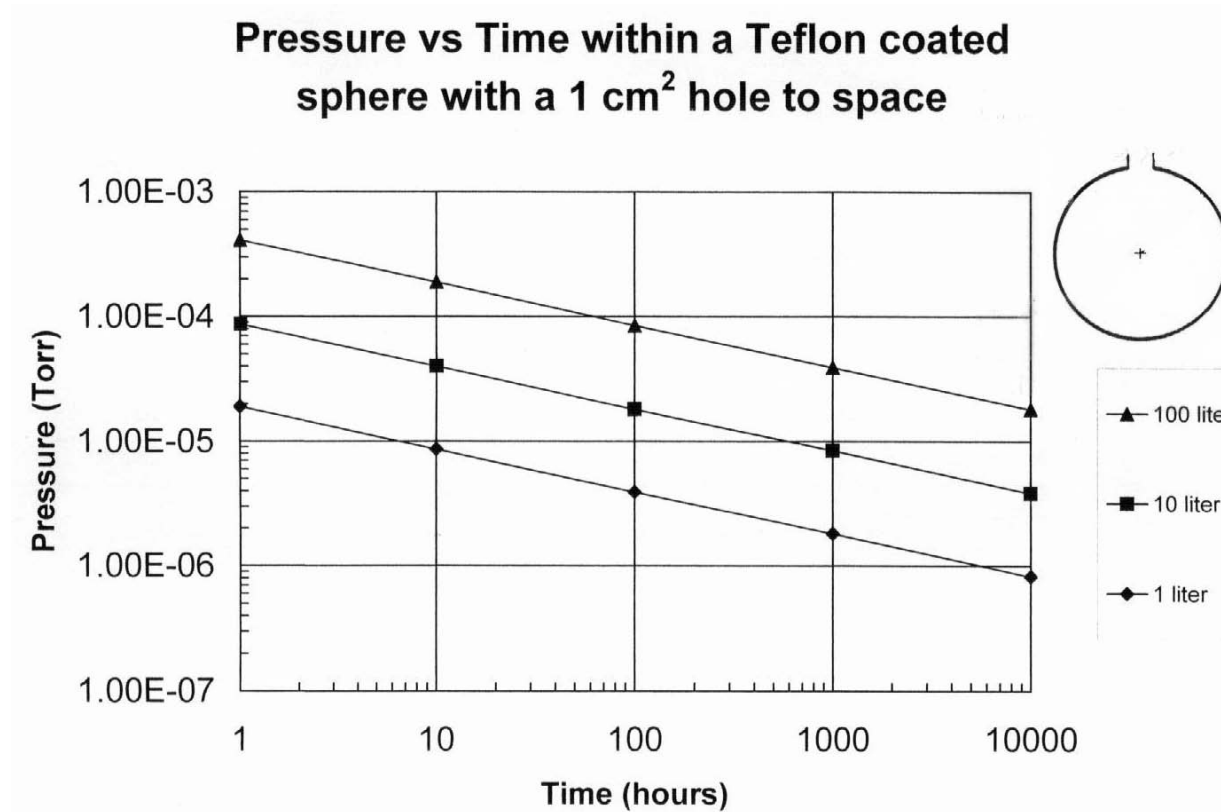
- Measure of vacuum:
 - Traditional: 1 Torr = 1 mm Hg = 1/760 std atm = 1.3×10^{-3} std atm
 - More recently: 1 bar = .99 std atm

Chart
from
Roth

| Condition | Pressure | | Mean Free Path (λ) | Gas Density (mol/cc) |
|------------------|------------|-----------------------|---------------------------------|-------------------------|
| | Torr | = Atm | | |
| Atm at STP | 760 | 1 | 67 nm | 2.5×10^{19} |
| Part. Vac | 1 | 1.3×10^{-3} | 51 μ m | 3.3×10^{16} |
| Poor Vac | 10^{-3} | 1.3×10^{-6} | 51 mm | 3.3×10^{13} |
| Fair Vac | 10^{-6} | 1.3×10^{-9} | 51 m | 3.3×10^{10} |
| Good Vac | 10^{-9} | 1.3×10^{-12} | 51 km | 3.3×10^7 |
| Space Near Earth | 10^{-15} | 1.3×10^{-18} | 5×10^6 km | 30 |

- Electronics box pressure after several months on orbit?
 - Not known, to my knowledge
 - Many material outgassing contributions
 - My estimated electronics package pressure is 10^{-5} to 10^{-8} T
 - Usually inside spacecraft and thermal blankets (MLI)
 - Warmer temperatures augment gas release

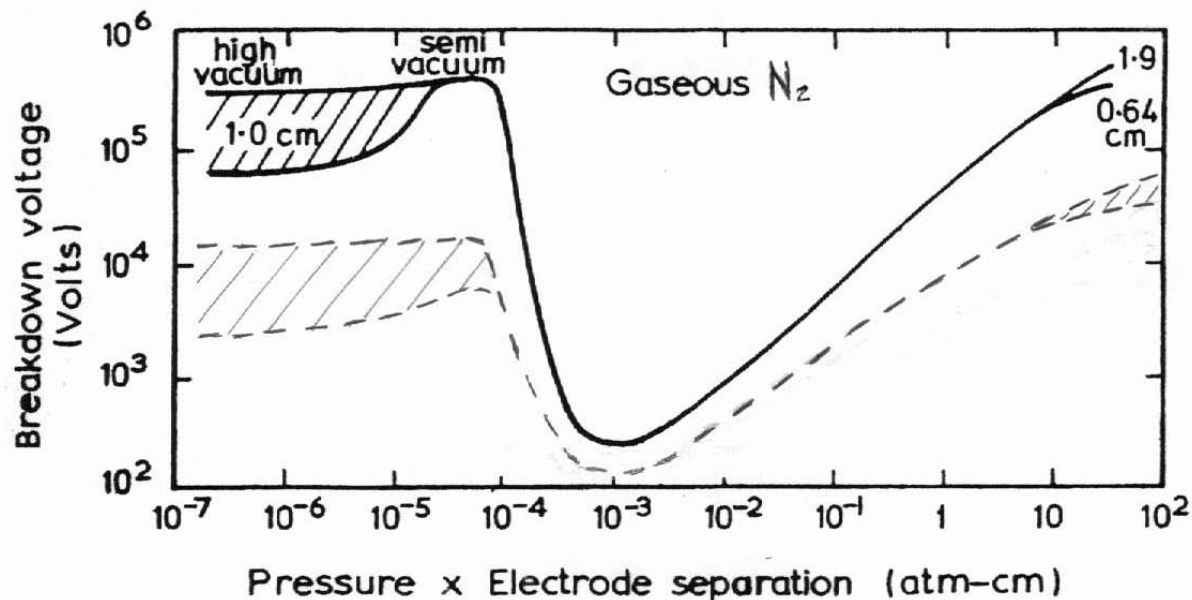
“Vacuum”, p3



Calculated pressure inside an outgassing Teflon sphere
based on best available outgassing rate data for Teflon
(Tom Sanders)

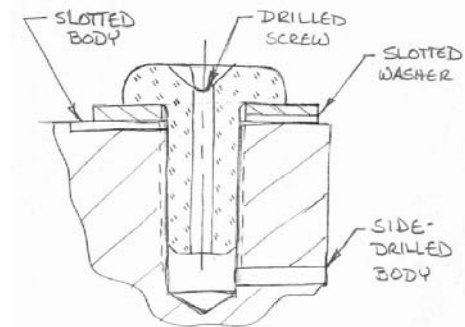
“Vacuum”, p4

- Good news:
 - Always good enough vacuum for electronics
- Bad news:
 - Never really high enough vacuum for many detectors

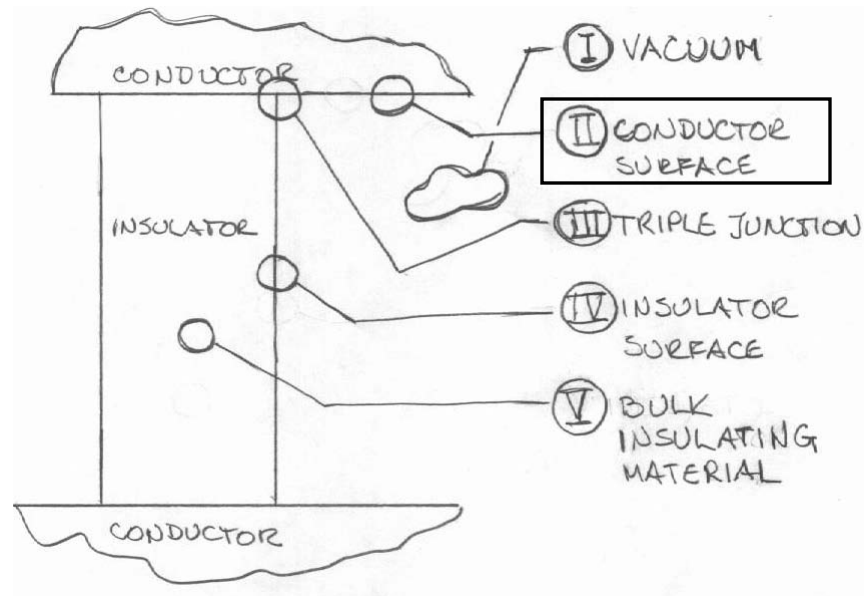


“Vacuum”, p5

- Good practice
 - Design for good enclosure venting
 - Long time rule:
 - 1 square inch vent area per cubic foot of volume
 - » $\text{Volume} / \text{Area} \leq 1730 \text{ inches}$
 - Sometimes given as: $\text{Vol} / \text{Area} \leq 2000 \text{ inches}$
 - Vent away from sensitive instrumentation, if possible
 - And vice versa
 - Block external EUV
 - Vent all trapped volumes
 - Especially below blind screws
 - Most threads do not plug gas passage
 - Virtual leaks delay ground testing
 - Vacuum pre-bake all assembled units
 - Strive for extreme cleanliness
 - Particulate
 - Chemical
 - Often called “non-volatile residue” (NVR) (\Rightarrow leads to complacency)
 - Hazardous because it IS volatile in flight environment



II. Conductor Surfaces, p1

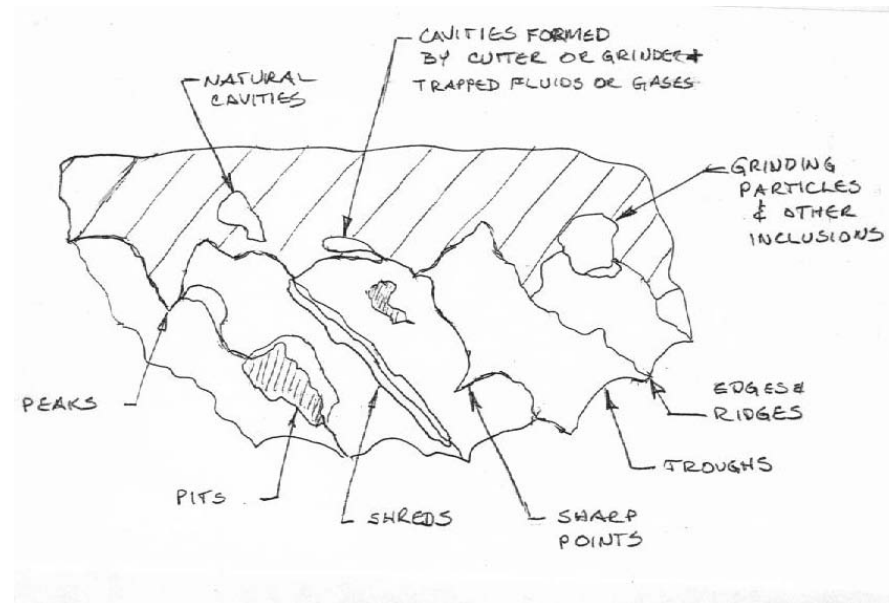


Conductor Surfaces, p2

- Material choice is limited by practicality in electronics
- Optimal conductor materials
 - Low outgassing
 - With benign outgassed volatiles
 - Less prone to oxidation
 - Carefully cleaned
 - Solder rosins, trace plating solution residues and masking materials
 - Sometimes conformal coatings
- Control conductor surface smoothness
 - Smoother is better
 - Smooth solder applications
 - Especially solder spikes

Conductor Surfaces, p3

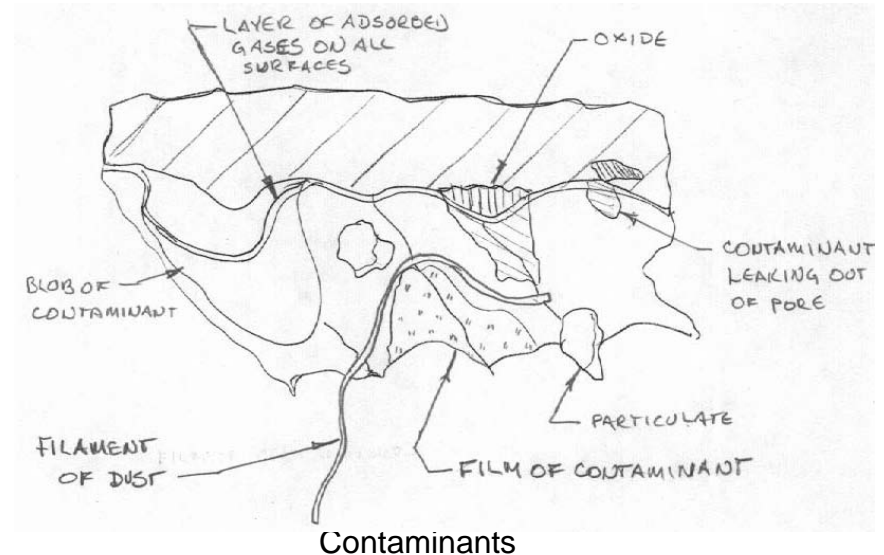
- Surface smoothness near HV
 - Nearly all manufacturing methods produce microscopic roughness
 - Ridges, troughs, spikes, pockets smeared closed, fragments, shreds



Microscopic machined features

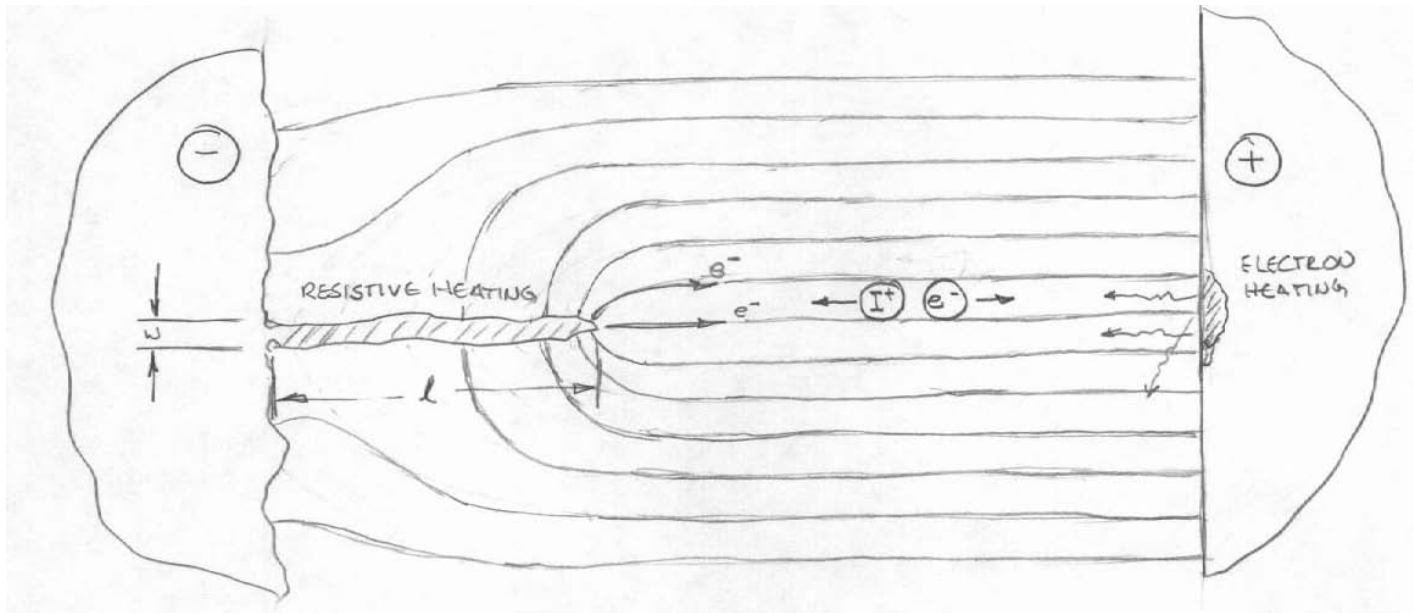
Conductor Surfaces, p4

- Surface Cleanliness
 - Oxidation
 - Particulates
 - Chemical contaminants
 - Adsorbed gases
 - Mono-layer adsorption time at 10^{-6} T: secs!
 - Cavities trap cutting oils, fluxes, cleaning fluids, other contaminants



Conductor Surfaces, p5

- Fibers and shreds
 - electric attraction lifts them into fields
 - Field amplification factors: 10s to 100s



Electric force lifts shred or fiber into field gap producing highly intensified fields at the tip , elevated e^- emission, resistive heating in shred, photon emission, etc.

Conductor Surfaces, p6

– Mitigations

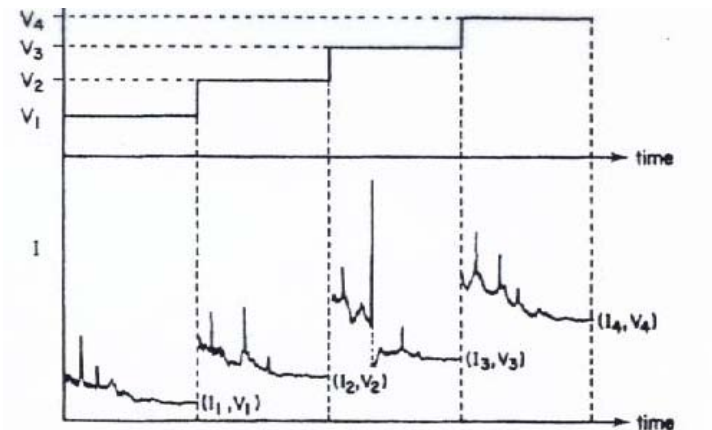
- Polish surfaces, mechanically and/or chemically
 - Both methods together are best
- Smooth solder balls at terminals
- Electro-plate contacts
 - Ni + Gold
 - Strive for particle-free plating baths
 - » Particles can add roughness to plated surfaces
- Radius corners and edges generously
- Follow best cleanliness practice

Conductor Surfaces, p7

- Thermal Sensitivity
 - Warmed surfaces release
 - Adsorbed gas
 - Gasses from micro cracks and cavities

Conductor Surfaces, p8

- “Conditioning” of un-coated HV conductors
 - Apply HV to burn off limiting protrusions, dust, etc
 - Requires high current lab power supplies
 - See
 - Latham, pp 33-39
 - Arora & Mosch, p 267
 - Practice in advance is advised
 - Effective but carries risk
 - After removal from vacuum
 - Some benefit is lost
 - Fresh dust, corrosion, etc
- Not appropriate for coated terminals

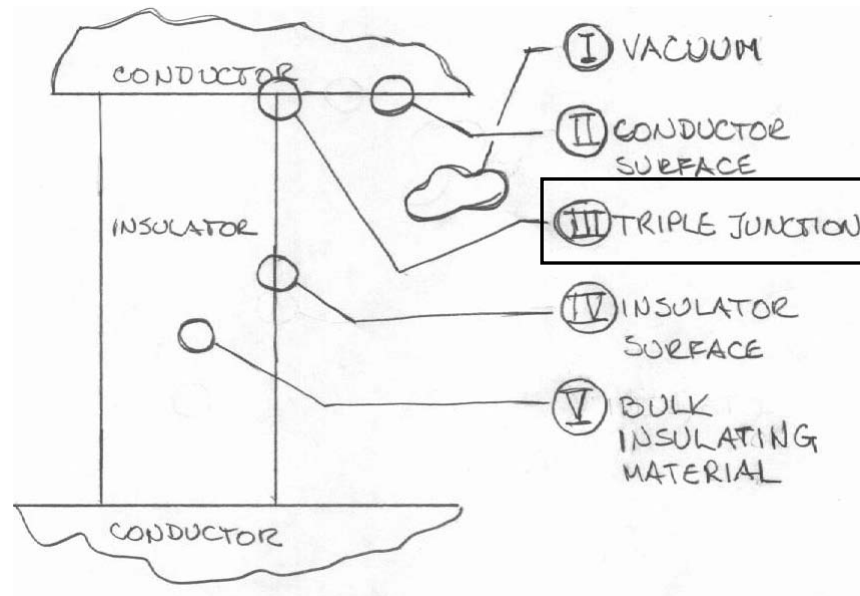


A schematic illustration of the “current” conditioning method, from Latham

Conductor Surfaces, p9

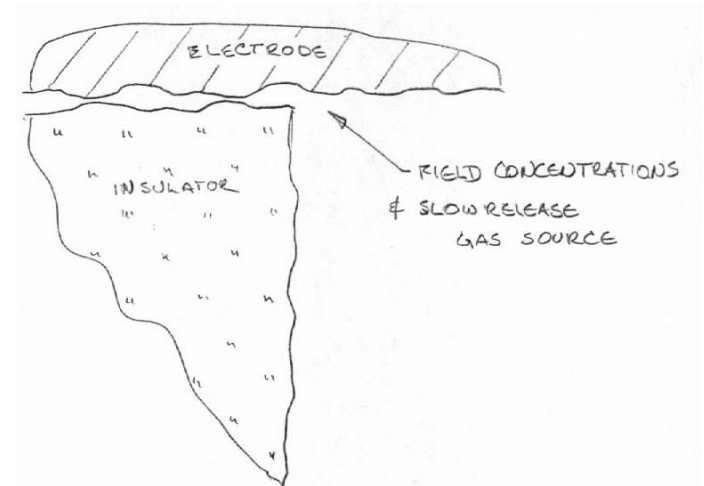
- Thin dielectric coating on conductors
 - Can be good discharge suppression barrier
 - Excludes moisture
 - Polyurethane PCB coatings
 - Often used; various issues
 - Paralene C
 - Higher dielectric strength
 - Good outgassing
 - Excellent penetration into cavities (e.g. under components)
 - Good coverage uniformity
 - Difficult to clean off connector contacts
 - Nuisance to make repairs through
 - Higher outgassing with raised temperature

III. Triple junctions, p1



Triple junctions, p2

- Definition: Zone where a conductor, an insulator and a gas dielectric or vacuum come together
 - Microscopic irregularities at mating surfaces
 - Trap gas for abundant, slow release
 - Enhance local electric fields
 - Local warming boosts
 - Field emission
 - Further gas release
- Ignition points for discharges



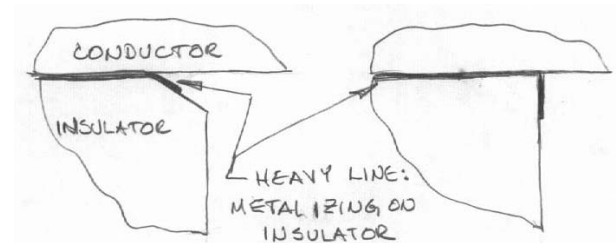
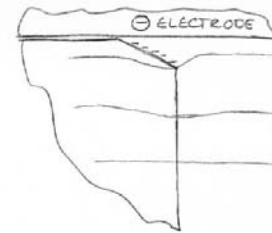
Microscopic view of
triple junction

- Essential to control!

Triple junctions, p3

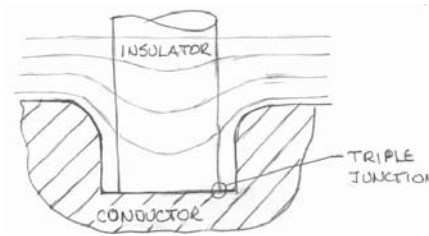
– Mitigations:

- Chamfer ends lightly per Wetzer and Wouters
 - Chamfered edge of insulator becomes charged by high fields
 - Acts to deflect and smooth equipotentials
- Metalize insulator surfaces where they will contact electrodes
 - Ceramics: fired on coatings
 - Polymers: electroplated treatments
- Best: place triple junctions away from high fields

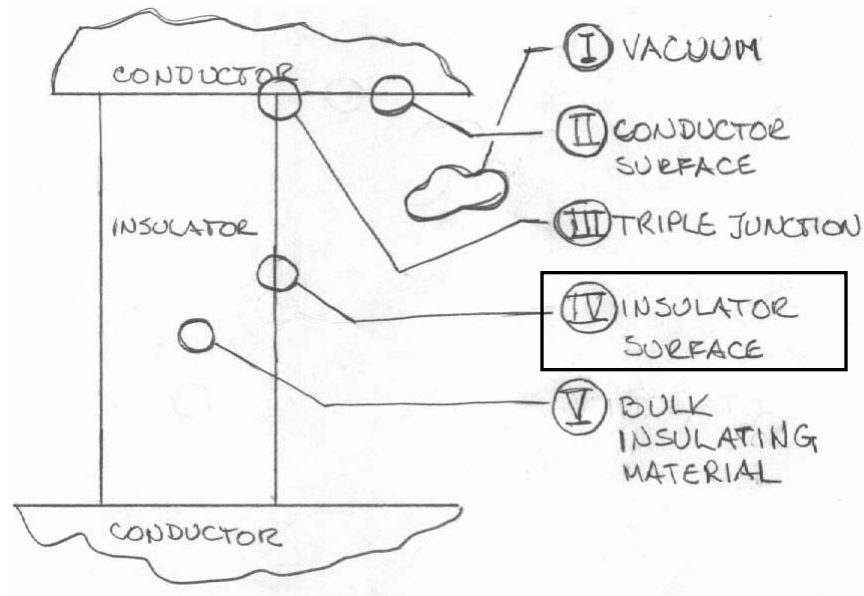


Yes: Chamfered,
partially metalized

No: Do not metalized
down edge



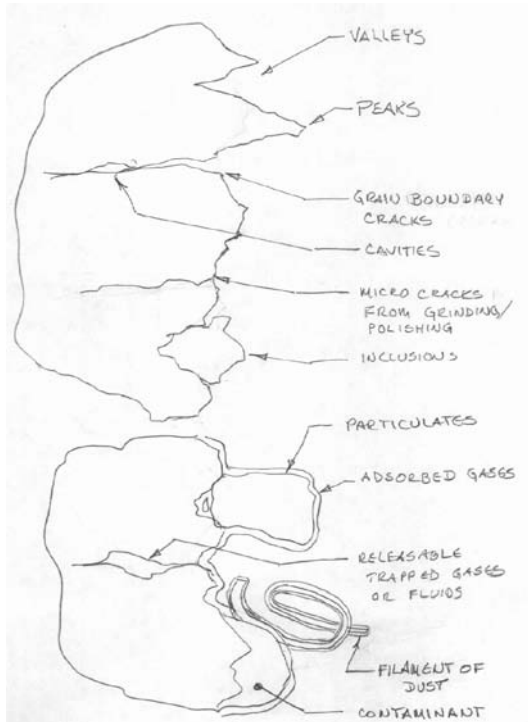
IV. Insulator Surfaces, p1



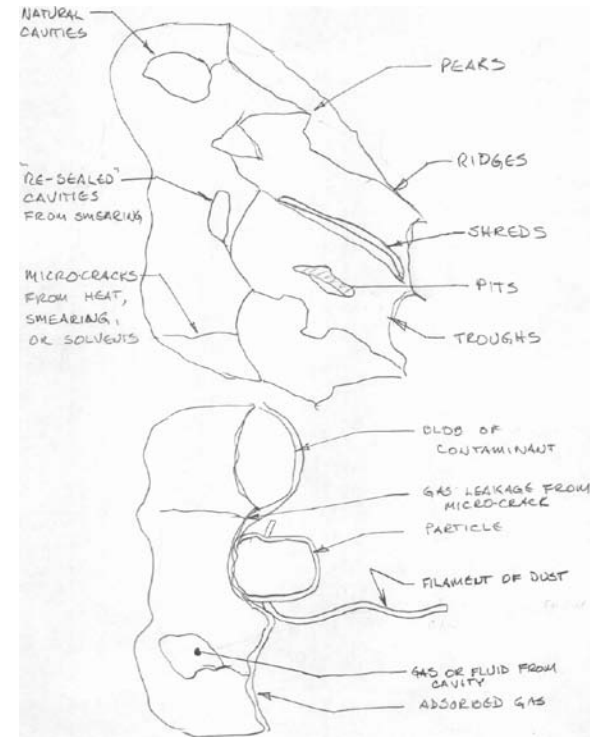
Insulator surfaces, p2

- Surface blemishes : same as in metal manufacturing:
 - Ceramics - ground
 - Peaks, valleys, surface micro cracks, cavities
 - Ceramic, metallic and grinding wheel particles, etc.
 - Acid bath removes all metallics
 - Requires re-firing to remove acid from porosity
 - Engineering plastics - turned
 - Smearing, tearing, shreds & cavities
 - Molded or bonded parts
 - Entrained bubbles, surface smearing and mold shreds
 - Puncture bubbles where visible
 - Bonded Insulator joints
 - Tiny bubbles – breakdown initiation sources
 - Annealing can foster micro-fracture healing
 - In ceramics and plastics
- Contaminants : similar to metal parts

Insulator surfaces, p3



Ceramic surface viewed microscopically,
physical features above, contaminants below.



Plastic surface viewed microscopically,
physical features above, contaminants below.

Insulator surfaces, p4

- Discharge can occur along insulator surfaces
 - Gas sources, field intensifications are present
 - Surface discharge can be self-sustaining
- Damage from HV discharge
 - To ceramic and polymeric surfaces
 - Discharge can sputter metal onto insulator surfaces
 - Reduces surface resistance unevenly
 - Hence HV standoff V
 - To bare metallic surfaces
 - Discharge can sputter polymers onto conductors
 - On polymeric surfaces:
 - Discharge may char the plastic surface, leaving a carbon track that partially shorts the insulator end to end
 - If possible, select the polymer for high tracking resistance

Insulator surfaces, p5

- Surface charging is dynamic:
 - Charge sprays around, coating some insulator surfaces
 - Alters electric fields
 - New fields redirect sprayed charge, charging different areas
 - Charge leaks off at varying rates
 - Time constants often in order of seconds

Insulator surfaces, p6

- Thermal effects
 - 2 heating modes
 - Conductive heating of conductors and insulators
 - Small temperature Δ 's
 - Slow
 - Discharge heating of surfaces
 - Large transient temperature Δ 's
 - Fast
 - Warming causes gas release from surfaces
 - Higher local pressure
 - Points can contribute thermal emission
 - Surface resistivity drops with temperature rise

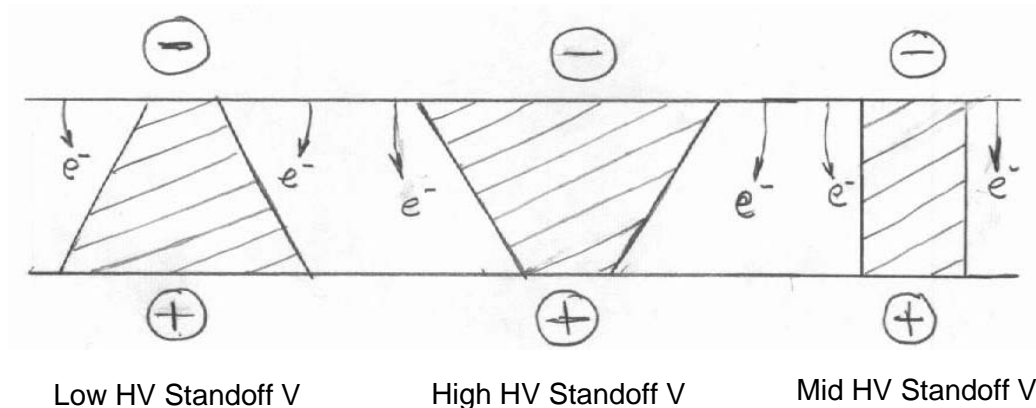
Insulator surfaces, p7

- Another sub-surface damage mechanism
 - Trapping/De-trapping
 - Theory based in quantum mechanics
 - Purports to explain some breakdown behavior within insulating materials when energetic ($>keV$) charged particles are implanted
 - Produces sub-surface charge distributions.
 - Dominant cause of damage occurs when charges escape:
 - Releasing intense local heat
 - Causing local mechanical damage
 - See Latham, chapter 9 for more

Insulator surfaces, p8

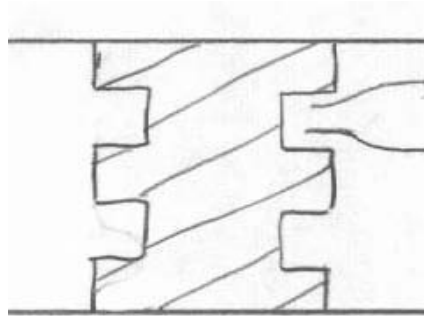
- Insulator shaping

- Some shapes furnish higher standoff voltages than others
- Fundamental explanation:
 - Insulator surfaces exposed to direct flows of emitted or breakdown electrons
 - => Lower HV standoff voltages
 - Insulator surfaces shadowed from direct flows of emitted or breakdown electrons
 - => Higher HV standoff voltages



Insulator surfaces, p9

- Insulator shaping (continued)
 - Extra mass and volume - often impractical
 - See publication by Wetzter and Wouters
 - Convolution: Little harm, little benefit
 - National power distribution system insulators function under entirely different conditions from those in space instrumentation



Insulator surfaces, p10

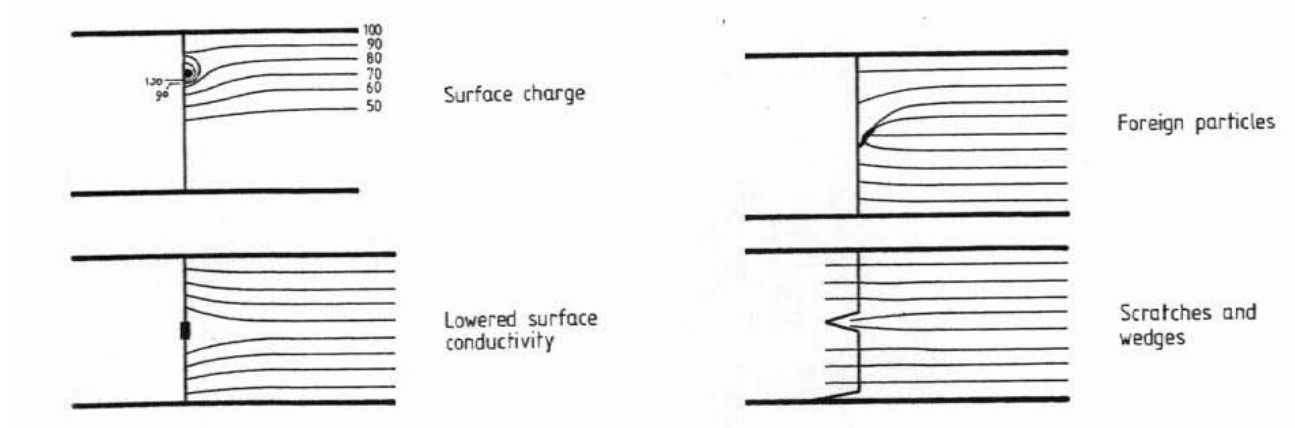
- Handling
 - Ceramic surfaces are harder than metal tools and components
 - Contact with metal will mark ceramics
 - Leaves conductive paths
 - Avoid contact of metal on ceramic insulators
 - At EVERY stage of handling and assembly
 - Use plastic tweezers, containers, etc
 - Glaze surfaces to aid handling and minimize metal marks
 - Caution: improper processing can cause micro-bubbling in glaze
 - Shorts out insulator
 - Demonstrate successful process in advance

Insulator surfaces, p11

- Optimal surface design:
 - Slightly conductive coating on insulators
 - Ω : Order of magnitude ~ 100 's of $G\Omega/\text{square}$
 - » High enough not to overload power supplies
 - » Low enough to drain sprayed charge quickly
 - Would produce more uniform fields
 - » Demands good coating uniformity
 - » Some prospective coatings are not thermally stable
 - Still searching for a source
 - Even better : shaped insulators with high, graded ρ
- Possible alternative: slight bulk conductivity
 - Not satisfactory for irregular shapes

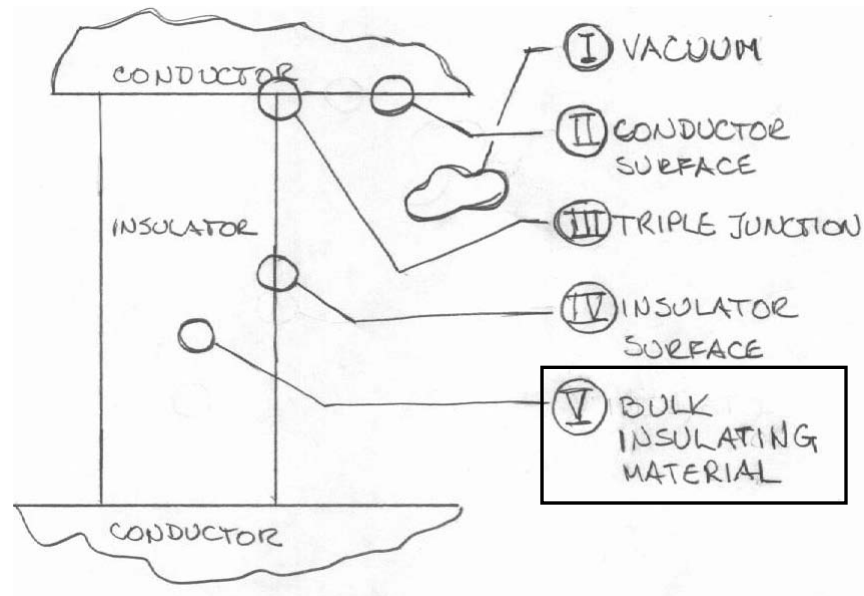
Insulator surfaces, p12

- Field disturbances on insulator surfaces



Plot from Kreuger

V. Bulk Insulating Material, p1



Bulk Insulating Material, p2

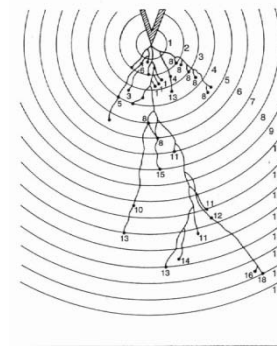
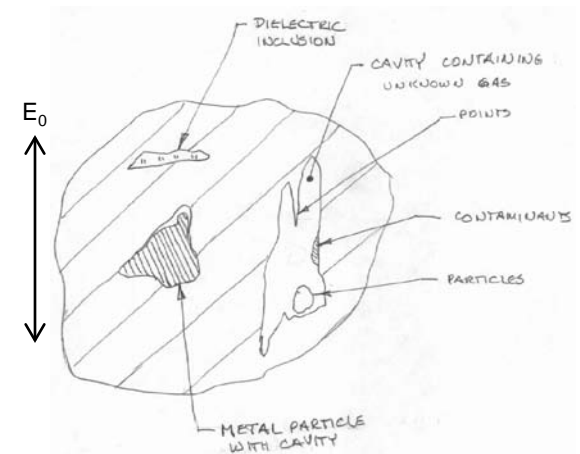
- Three classes
 - Ceramic
 - Usually alumina (Al_2O_3), but many others are available
 - Consolidated from powders under heat and pressure
 - Polycrystalline
 - With glassy components at grain boundaries
 - Always possibility of cavities
 - Mono-crystals: sapphire, other single crystals
 - Engineering plastics
 - Polyimide (Vespel, Kapton), PEEK, Ultem (Polyetherimide), others
 - Relatively low water absorption
 - Teflon & related chloro-fluoro-hydrocarbons
 - Very low water absorption
 - Consolidated from powders under heat and pressure
 - Always possibility of voids
 - Low dielectric noise
 - Molded, laminated, encapsulated and bonded insulators
 - Many materials including epoxies and silicones
 - Laminated PCBs, molded terminals, etc

Bulk Insulating Material, p3

- Molded, laminated, encapsulated and bonded materials
 - Usually entrain bubbles
 - Vacuum degassing of liquid compound before curing is ESSENTIAL
 - Laminated systems entrain contaminants along matrix fibers
 - tiny gas bubbles
 - Minute quantities of un- or partially cured polymeric material
 - Risky in higher voltage applications
 - Acceptable bubble size?
 - Depends on field, geometry, ϵ , etc.
 - Generally very small
 - Impossible to define or eliminate
- Minimize these materials near HV

Bulk Insulating Material, p4

- All insulators have internal flaws
 - Inclusions, cavities, bubbles
 - Frequently cavities form around inclusions
 - Particularly conductive inclusions
 - Aggravated by thermal expansion/contraction
 - Cause high internal fields
 - Especially in cavities perpendicular to field
- Discharge within cavities
 - Enhanced fields
 - Especially if cavity is spiky internally
 - Internal pressure close to atmospheric
 - Increases with temperature
 - May leak slowly
 - Ionic erosion at both polar ends of cavity
 - Directed toward electrodes by fields
 - Causes local heating
 - Chemically active
 - Once started, treeing & burn-through occur rapidly



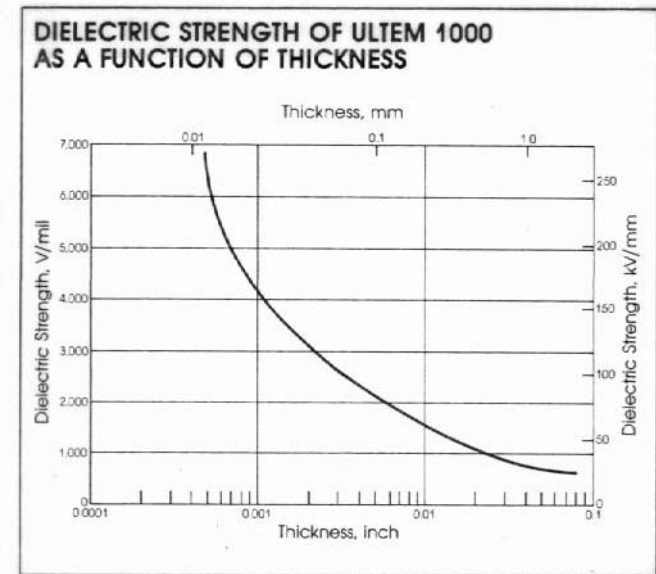
Treeing and near burn-through in plexiglass;
from Kuffel, Zaengl & Kuffel

Bulk Insulating Material, p5

- HV standoff V degrades with temperature rise
 - Critical temperature dependent functions
 - Electric material properties
 - ϵ , σ , DS etc
 - DS, σ and ρ drop sharply
 - Structural material properties
 - Strength, rigidity, plasticity, etc
 - » Weaker, more flexible warm
 - » More brittle cold
 - Gas pressure in voids increases
 - Thermal expansion stresses
 - Internal flaws can creep, separations enlarge
 - May weaken or break insulators
 - Mechanical stress worsens some electronic properties
 - Insulators are all poor thermal conductors
 - Usually sustain gradients
 - High fields warm the insulator

Bulk Insulating Material, p6

- Published Dielectric Strength (DS)
 - BEWARE!
 - Nearly all measurements are per ASTM D149
 - Spec'ed HV stand-off times between 10 and 300 seconds
 - Only 5 minutes max! Way too aggressive for us
 - DS varies inversely with insulator material thickness
 - Spec requires NO correlation to a standard thickness
 - Often inconsistencies among published figures
 - Most insulator suppliers furnish only one DS value
 - Two at most
 - Approximate correction (from Carl J. Tauscher):
 - Derate DS heavily



From General Electric product booklet

$$DS_d = DS_m (t_m / t_d)^{1/2}$$

d = desired
m = measured
t = thickness

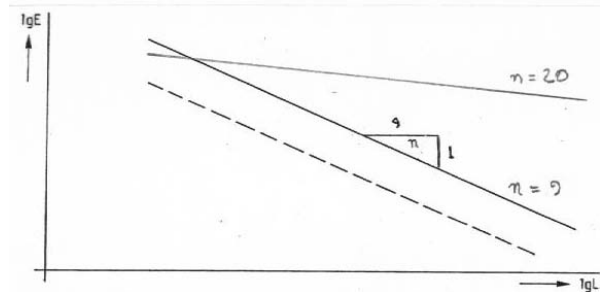
HV System Lifetimes

HV System Life Time, p1

- All HV systems have a limited life
- From the HV cable industry comes the EMPIRICAL relationship:

$$LV^n = C_i$$

- L = life time
- V = expected operational voltage
- C_i = constant, individual to each system
 - NOT a universal constant
- Exponent n is called Slope on log-log paper
 - Not presented in the conventional fashion
 - Slope is defined here as 9 , not $-1/9$
 - n can vary from well below 9 to as high as 20
 - $n = 9$ is the generally accepted value for HV cable



HV System Life Time, p2

- Leads to convenient HV test scaling equations:
 - $V_{\text{test}} = V_{\text{orbit}}(fL_{\text{orbit}}/L_{\text{test}})^{(1/n)}$
and
 - $L_{\text{test}} = fL_{\text{orbit}}(V_{\text{orbit}}/V_{\text{test}})^n$
 - f = the fraction of the orbital lifetime we are willing to expend during the test
- Above equations are simplified:
 - Assume f = only a small fraction of total life
- Bound tests using $n = 9$ max and $n =$ perhaps 7
 - Use care not to overtest
- LHV test system must be designed for higher voltages than test item
 - Power supplies, connectors, vacuum feed-throughs, cables, grounding
- Use caution

Conservative Rules of Thumb

- Maximum recommended DC design voltages from our experience:
 - Vacuum gaps: 3 kV/mm max; lower is better
 - Along insulator surfaces: 1 kV/mm
 - Within good bulk insulator material: 4 kV/mm
 - Confirm properties – use lower value for thick insulators
 - In atmosphere at STP: 1.5 to 2 kV/mm
 - Up to 3 kv/mm with low humidity
- Max HV turn-on pressure in vacuum:
 - 10^{-5} Torr pressure range
- AC (peak)
 - No experience
 - Would stay below 1/2 of DC values
 - Published AC values range from 0.7 to 0.33 of DC values

Related Topics

Cable, p1

- Cable manufacturers routinely & reliably achieve much higher fields in their dielectrics that we are likely to
 - > 50 years of proprietary development
 - Reynolds shielded HV wire: ~30 kV/mm or more
 - Reliable at rated HV for years
 - Cable makers do things most of us can't:
 - Inner conductor surface ultra-smooth
 - Maximize dielectric purity & density
 - Very few cavities & inclusions
 - Control microscopic gaps between conductors and insulating layers
 - Graduated and/or multiple dielectrics
 - Graduated insulator resistivity adjacent to conductors
 - Sometimes semi-conductor layers
 - Finished wire is HV tested

Cable, p2

- Shielded cable?
 - Shielded cable keeps the field entirely within cable
 - Strongly recommended
 - Fields are uncontrolled at ends where shielding is stripped back
 - Unshielded cable: Exterior fields => pd, etc.
 - Hazard where cable rests on grounded surface
 - Multiple dielectrics, field enhancements
- Cable is damaged when
 - Bent too tightly
 - Dielectric is deformed or separated from conductors
 - Fields are intensified
 - Reynolds shielded cable:
 - Min bend radius = 10 x insulation OD.
 - Less reliable at connector terminations
 - Stripping back shielding creates an air gap => enhances fields
 - Special field shaping ring can help where shield braid is lifted
 - Bubble-free encapsulation

Cable, p3

- Reynolds tests HV wire (2005):
 - At 8.6% of std atmosphere
 - $\approx 70,000$ feet altitude equivalent
 - Near atmospheric Paschen minimum
 - 150% of rated DC voltage, 1 min, shielding grounded
 - AC test (p-p): 70% of rated DC
 - The woven wire shield tested at 3kV AC for 30 sec
 - With respect to a surrounding coaxial ground

Connectors, p1

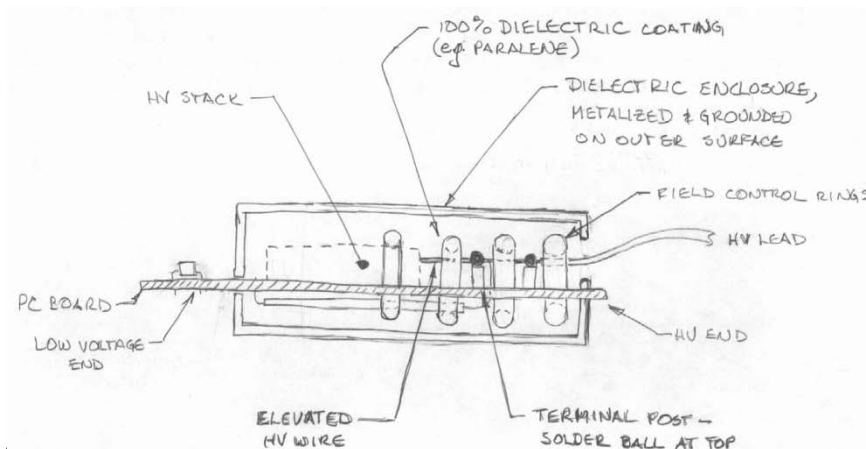
- Commercial HV connectors
 - Ease in making and breaking reliable contact
 - Design options:
 - Hermetically sealed – gas captured in connector
 - O-ring or similar
 - Usually quite reliable, even in vacuum
 - Always risk of slow leakage to Paschen minimum in flight
 - » Breakdown after time
 - Fully vented, labyrinthine breakdown path
 - Controversy about merits
 - Fully vented is better, in my opinion

Connectors, p2

- Screw/lug assembly or captive pin/socked
 - Less convenient, more tiny pieces to drop
 - More labor intensive
 - Most reliable (in my opinion) when properly designed
 - Exposes center conductor fields where shield is stripped back
 - May be an issue

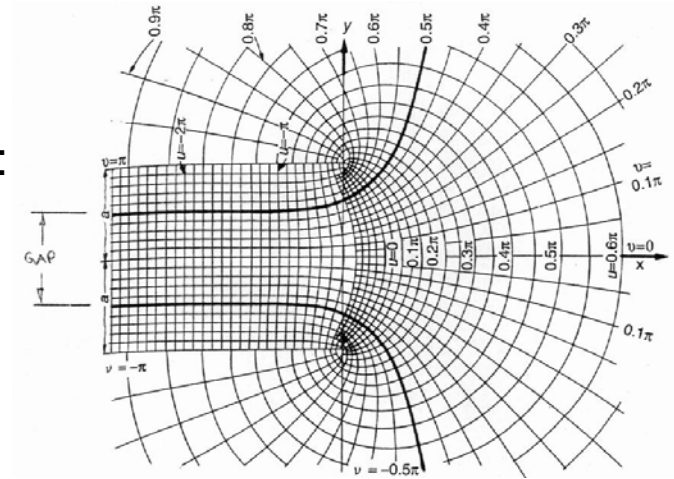
HV Electronics Boards

- Avoid HV on PCB traces
 - Air gaps in adjacent laminations
 - Small traces with sharp edges => high fields
- HV leads:
 - Elevate large diameter wires above board on suitable standoffs
 - Use large, uniform solder balls – no points
- Graduate HV from one end of board to other
- Thin-walled dielectric shell around HV circuits (optional)
 - Plated as Faraday cage on outer surface (or similar arrangement)
- Vacuum encapsulation (optional)
- Field control loops around HV zones (optional)



Misc Comments, p1

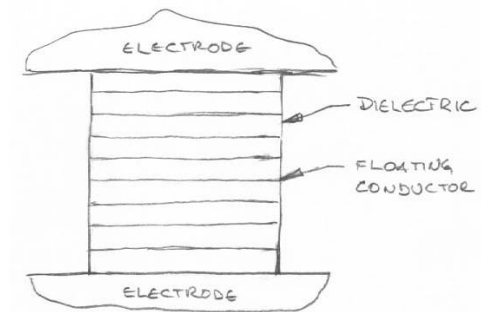
- Magnetic fields can direct charge flow to advantage
 - Has other issues, use great care
- Perfect edge termination for parallel electrodes:
 - Rogowski contour. Not practical in most cases
 - Suitable radius provides pretty close approximation
 - Edge radius = gap \Rightarrow max field only $\sim 10\%$ higher than E_0
 - Also usually not practical: too large & massive



Rogowski contours (heavy lines)
from Kuffel, Zaengl & Kuffel

Misc Comments, p2

- A perfect termination for coax cables?
 - Pretty good (“stress cone”), but not unique
 - Various trade-offs
- Avoid floating conductors that can charge up and discharge like capacitors
 - Some exceptions
 - Capacitors with floating layers control fields well



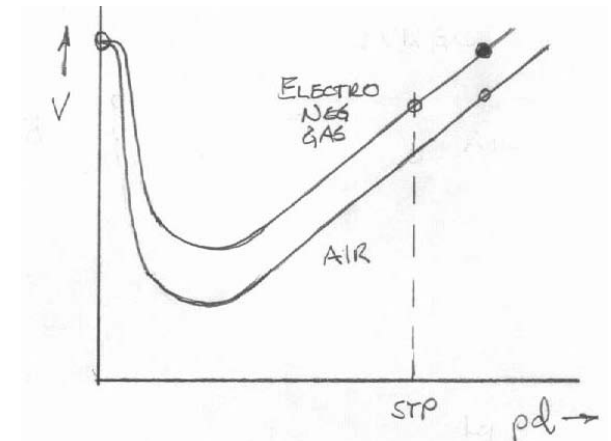
Multi-Layer ceramic capacitor stack
with floating conductive layers

HV at Atmospheric Pressure, p1

- All space HV test systems include elements
 - In vacuum, and
 - In air
- Design for both
 - Particularly at interfaces: connectors and vacuum feed-throughs
- In air
 - Minimize dust
 - Eliminate air drafts
 - Use HV rods and balls, if called for

HV in Ambient Atmosphere, p2

- Electro-negative gasses (electron collectors)
 - At STP, less prone to discharge than air
 - Characterized by “Breakdown Voltage Multiplier” (BVM)
 - Freon = 2.4
 - Sulphur hexafluoride = 2.3
 - Carbon Tetra-chloride = 6.3
 - Elevated pressure also helps
 - 5 atmospheres of SF_6 = 12
- Possible applications
 - Vacuum sealed HVPS container
 - Filled with pressurized electro-negative gas
 - Issues: leakage to Paschen minimum, electrical interfaces through walls
 - Loss of vacuum due to outgassing leaks
 - Just evacuated container – many issues



Dangers, p1

- HV is **DANGEROUS – things go wrong!**
- Life is threatened by current, not voltage:
 - Much more at shown site
- Know your power supply's characteristics
 - If it SHUTS OFF with over-current
 - Equivalent to a circuit breaker
 - This is SAFE
 - If it is power limited
 - V will sag as i continues to rise?
 - Dangerous!
- Use a protection resistor in line located immediately at the PS output, if possible
 - Old carbon resistors are better than new metal film resistors
 - Best encapsulated

| Electric Current (1 second contact) | Physiological Effect |
|--|---|
| 1 mA | Threshold of feeling, tingling sensation. |
| 5 mA | Accepted as maximum harmless current |
| 10-20 mA | Beginning of sustained muscular contraction ("Can't let go" current.) |
| 100-300 mA | Ventricular fibrillation, fatal if continued. Respiratory function continues. |

From: <http://hyperphysics.phy-astr.gsu.edu/hbase/electric/shock.html>

Dangers, p2

- Follow the standard rules:
 - Keep one hand in pocket
 - Remove conductive jewelry (rings, watches)
 - Stand away from equipment racks and other conductors
 - Wear dry, rubber soled shoes
 - Don't stand in water
 - For example, in puddles from LN2 delivery systems by vacuum chambers
 - Have a second person present

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***More: Eric Hertzberg on High Voltage
Field Analysis Techniques
and Associated Software***

Introduction to Electro-Magnetic Field Solvers

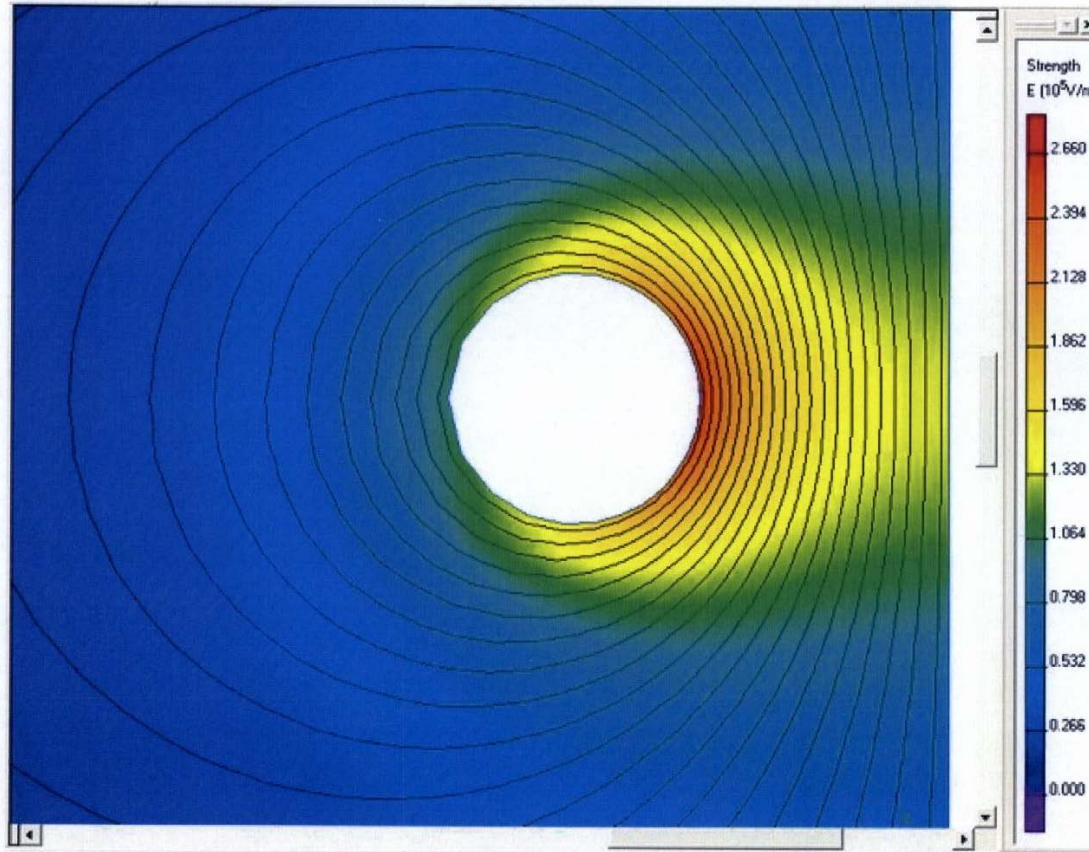
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General Comments

- Electro-Magnetic Field solvers
 - Powerful computerized analytical tools that calculate electro-magnetic field properties based on
 - Boundary conditions
 - Materials properties
 - Nearly all solution methods derive from finite element mathematics & technology
 - All are a subset of the broader category of
 - Boundary Value Problem solvers for physics
- Substantial software selection decision tree

Field Plot



Field solution for a conductive sphere near a conductive plane with voltage between.
From website: [<http://www.nessengr.com/techdata/fields/field.html>]

Boundary Considerations, p1

- Boundary Inputs
 - Scale size and physical shape
 - Sub-atomic to intergalactic
 - Atomic/molecular scales (quantum mechanical)
 - Integrated Circuit feature and component scales (10 of nm's)
 - Practical S/C instrument field sizes (1 mm - 30 cm)
 - Antennas (cm's to 10s of m's)
 - Signal transmissions (100's of km to vastly larger (radio telescope))
 - Time domain phenomena
 - Static (DC)
 - Changing, Periodic - All EM wavelengths
 - Changing, Non-Periodic - Pulsed, spiked, random, etc

Boundary Considerations, p2

- Materials properties
 - Widely variable properties
 - Temperature
 - Spin, Velocity
 - Time degradation
 - Adsorbed gas layers, etc.
 - “Constants”
 - Dielectric constant
 - Resistivity
 - Magnetic permeability
 - Index of refraction
 - Thermal expansion, stability, etc.

Engineering Issues

- Desired Outputs
 - Scalar values, 2D & 3D representations
 - Vector fields, 2D & 3D representations and matrices

Program Decisions, p1

- Developers went in many directions
 - Generalized programs:
 - Moderate capability: Field solving only, 2D RS or 3D
 - 2D RS = 2D plus Rotational Symmetry only, but NOT full 3D
 - Often called 2-1/2 D
 - High capability: 3D Field Solving
 - Higher capability: Field Solving plus ray tracing
 - Highest capability: “Multi-physics software”
 - Extremely powerful - go far beyond merely solving EM fields
 - Prepare outputs for follow-on analyses
 - » Space charge limitation studies
 - » Shock phenomena, etc

Program Decisions, p2

- Diverse specialized programs
 - Explicitly tailored and optimized to the particular problem at hand
 - Seeking ever higher speeds for increasingly complex problems
 - Commercial packages focused on certain design areas (motors, etc)
 - Combinations of above with various add-on packages

Practical Considerations, p1

- Cost
- ITAR restrictions on support for foreign products
- Learning curve; ease of use
 - Input/ Output Formatting
- Ease of customization/ adaptation of software
- Required computational hardware/web resources
 - Computer speed and memory
- Math process efficiency (speed)
- Model precision at boundaries (seldom exact)

Practical Considerations, p2

- Meshing management
 - Regular meshing
 - Cubic, tetrahedral or similar everywhere
 - Conformal meshing
 - Locally shaped to match physical boundary features
 - Adaptive meshing
 - Mesh size is automatically adjusted locally to match
 - Physical features
 - High field intensity zones
 - Meshes are finer only where needed
 - Lower memory - higher speed - greater accuracy

Practical Considerations, p3

- Entry of geometry
 - Custom hand entry
 - Commercial 3D model entry
 - Compatibility with supporting software
 - 2D or 3D CAD packages
 - AutoCad, Pro-E, SolidWorks, Katia, etc
 - Combination of custom and commercial
 - Entry of geometry-dependent field input data (thermal fields, etc)
 - Post-processing of outputs - compatibility with
 - MathCad, Mathematica, etc
- ONE SIZE DOES NOT FIT ALL!
 - User must know WANTS, tempered by NEEDS

Field Solver Software, p1

- Focused on needs for miniaturized space instruments
 - Unit size: roughly 1 to 30 cc
 - HV gap width and feature size: typically 1 to 20 mm
 - Voltages
 - Usually <10 kV, DC and/or stepped
 - Total step transition speeds: between m seconds and 1 second
 - Sometimes up to 25 kV DC
 - No RF
 - Any inclusion here is incidental and limited

Field Solver Software, p2

- Low cost, relatively easy to learn
 - QuickField (headquartered in Denmark)
 - 2D RS E or M and time variable solvers
 - Maplesoft (headquartered in Canada)
 - 2D RS E or M solvers
 - SIMION (Software Information Systems (SIS), Louisville, KY)
 - 2D RS EM and 3D E field solvers
 - SIMION combined with other extension packages
 - Such as Aston Labs, Purdue Univ.
 - 2D RS EM field solvers with ray tracing

Field Solver Software, p3

- Higher cost, more intricate to learn
 - Integrated Engineering Software (EIS) (headquartered in Canada)
 - Many levels of E or M, EM and time domain field solvers (ELECTRO, COULOMB, SINGULA, CHRONOS, MAGNETO, AMPERES, OERSTED, FARADAY, INDUCTO)
 - LORENTZ – premier E or M, EM and time domain field solvers
 - all with ray tracing
 - CST (Computer Simulation Technology), (headquartered in Germany)
 - EM Studio - static and low frequency EM field solver
 - EM Particle Studio (plus other modules) - 3D EM field solver and ray tracer
 - ANSYS
 - Maxwell - 2D & 3D EM field solver
 - Multi-physics - field solver, ray tracer and much more
 - COMSOL
 - Multi-physics - 3D EM field solver and much more
 - Multi-physics plus Particle Tracing, other modules- 3D EM field solver, ray tracing

Field Solver Services

- Dr. Arthur Ghielmetti, US citizen and resident of Switzerland,
 - Personally written field solver
 - Can incorporate SIMION
 - 2D RS EM field solving with full 3D ray tracing and some RF capability
 - Automated optimization
 - Proven high accuracy at boundaries
 - Decades long record of successes in space instrumentation

Closing Comments

- MANY MORE
 - When RF is part of the design, there is an additional long list of tailored programs
 - Search on Google
 - Many universities have in-house-developed field solvers and multi-physics packages
 - Highly specialized and optimized
 - Focused capabilities and limitations;
 - Some have incorporated iterative design-optimization capabilities
 - Compatibilities with commercial packages

Cautions

- **BEWARE:**
 - Very easy to get tripped up
 - Achieve plausible but incorrect answers
 - For confidence, one must have guidance from someone knowledgeable with the
 - Applicable physics
 - Software architecture, capabilities and limitations